

Status and perspectives of SiPMs at FBK

Alberto Gola
Chief Scientist

F. Acerbi, A. Ficarella, S. Merzi, L.P. Monreal, E. Moretti, G.
Paternoster, M. Penna, M. Ruzzarin, N. Zorzi

Fondazione Bruno Kessler

Custom Silicon Photomultipliers



Detector-grade clean-room, 6 inches, class 10 and 100



Silicon Photomultipliers account for a significant portion of the detectors fabricated here.

FBK is typically interested in R&D activities and collaborations to improve and customize SiPM technology for specific applications.

Large area productions can be carried out in FBK (up to ~5 sqm) or relying on external partners (low cost): success stories of technology transfers.



Private Research Foundation

- ~400 researchers in different fields, ranging from Microelectronics to Information Technology
- 50% funding from local government
- 50% self-funding rate
 - 25% from publicly funded research
 - 25% from collaboration with companies

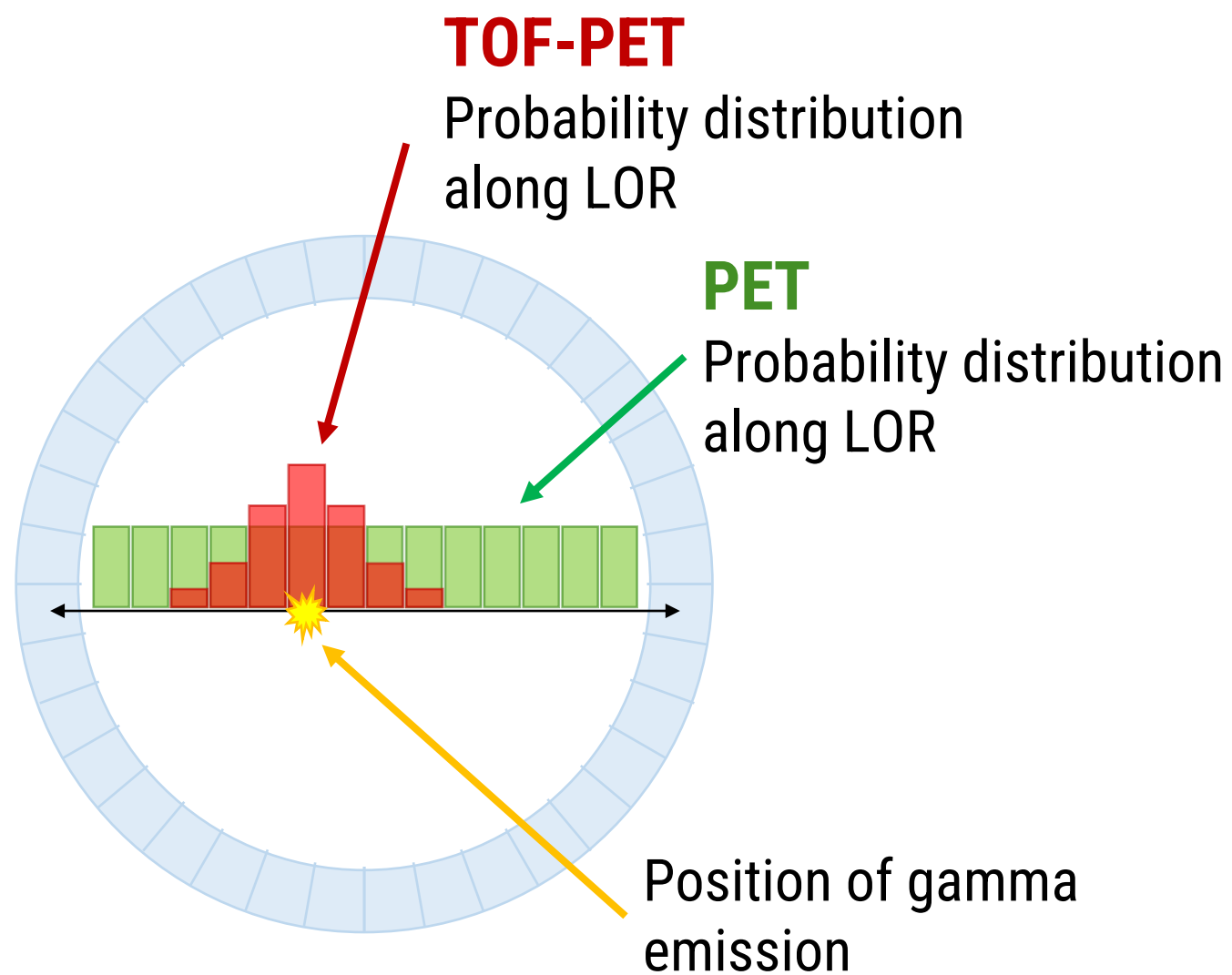


FBK SiPM technologies

Typical Applications

The traditional application of SiPMs is the ToF-PET. In addition, thanks to the *constant improvement of SiPM performance*, they are being evaluated in the *upgrade of several Big Physics Experiments*.

Positron Emission Tomography



Big Physics Experiments

This block contains several images and labels related to physics experiments:

- Cryogenic TPCs:** A 3D cutaway diagram of a detector structure with a central cylindrical volume.
- HEP experiments (CERN):** A photograph of a large detector component with labels: 'cold plate - LYSO:Ce crystal', 'CO₂ cooling loop', 'EF board', and 'SiPM'. Below it, another image shows a 'BTL detector' with '72 trays: 2(z) x 36(φ)' and '332k channels'.
- Astrophysics and space:** A photograph of a large satellite dish antenna on a hillside, with a group of people standing in front of it.

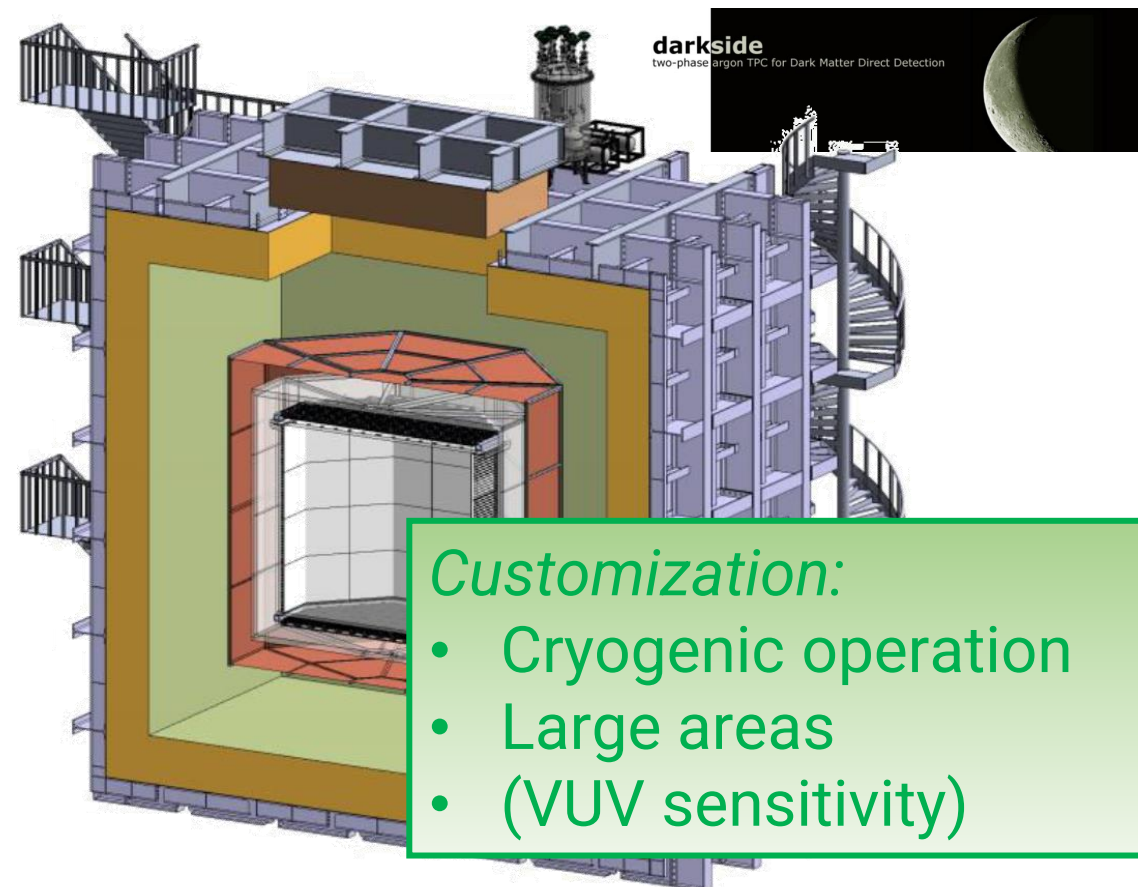
Examples of Big Physics experiments FBK is currently working on.

FBK SiPM technologies

Use in Big Physics Experiments

Especially for Big Physics Experiments, *deep customization of the detector is often required.*

Cryogenic TPCs

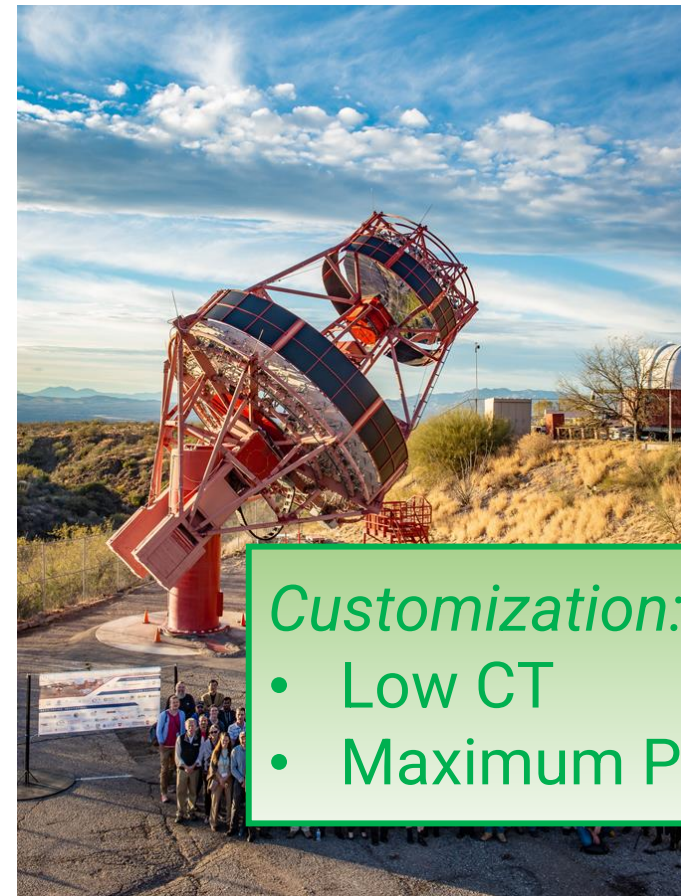


Customization:

- Cryogenic operation
- Large areas
- (VUV sensitivity)

Cryogenic SiPMs will be employed in experiments such as DarkSide-20k

CTA

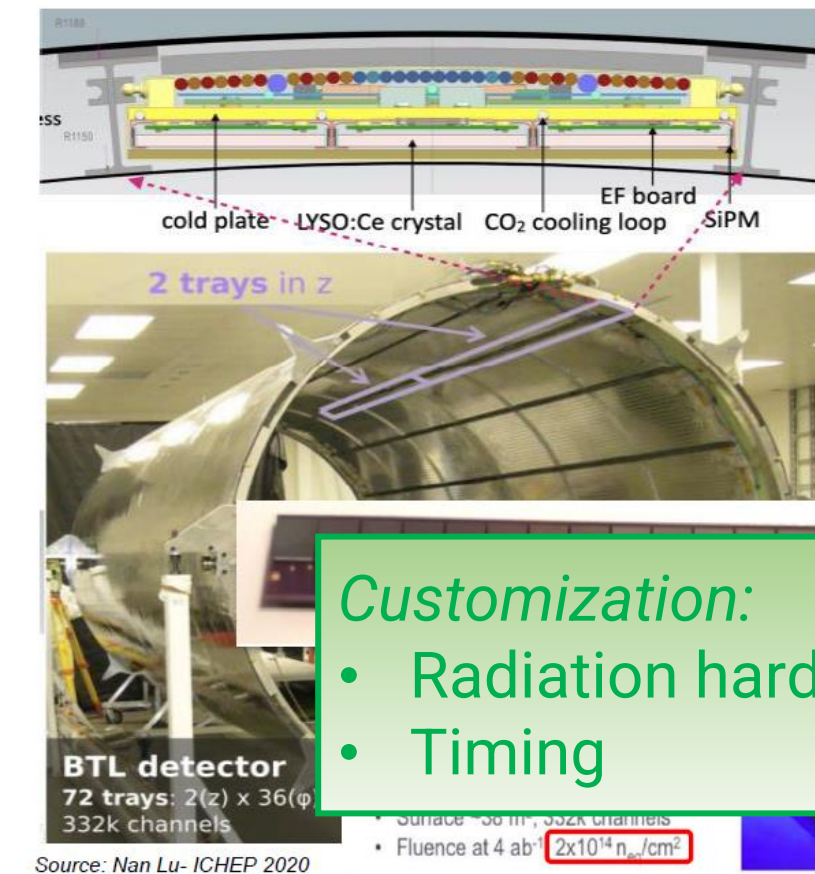


Customization:

- Low CT
- Maximum PDE

Prototype pSCT installed in the VERITAS, equipped with FBK SiPMs.

HEP



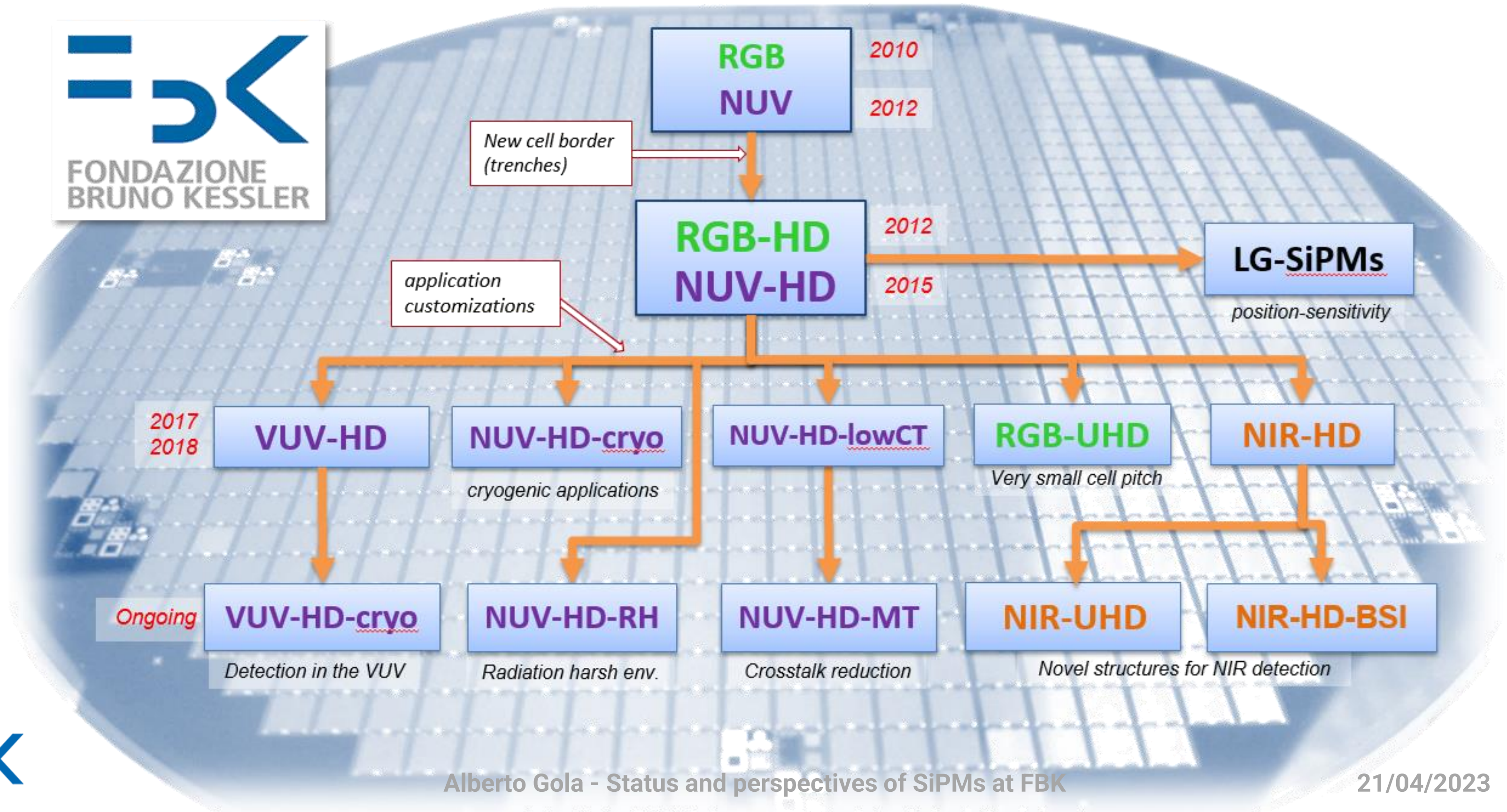
Customization:

- Radiation hardness
- Timing

NUV-HD SiPMs are being evaluated for the MIP timing detector of CMS (LYSO scintillator readout).

Fondazione Bruno Kessler

Custom SiPM technology roadmap





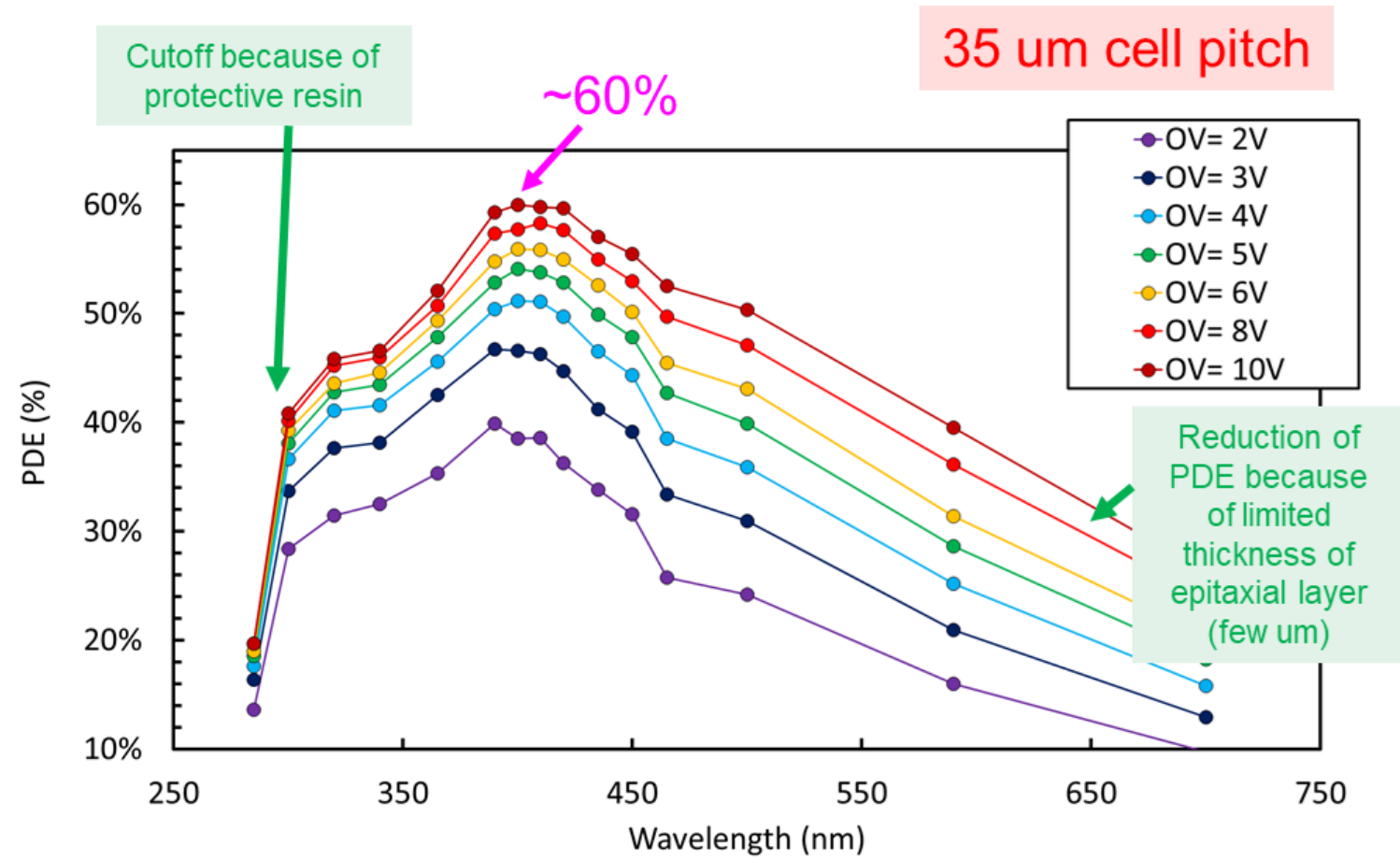
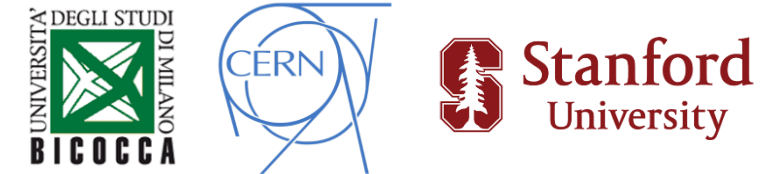
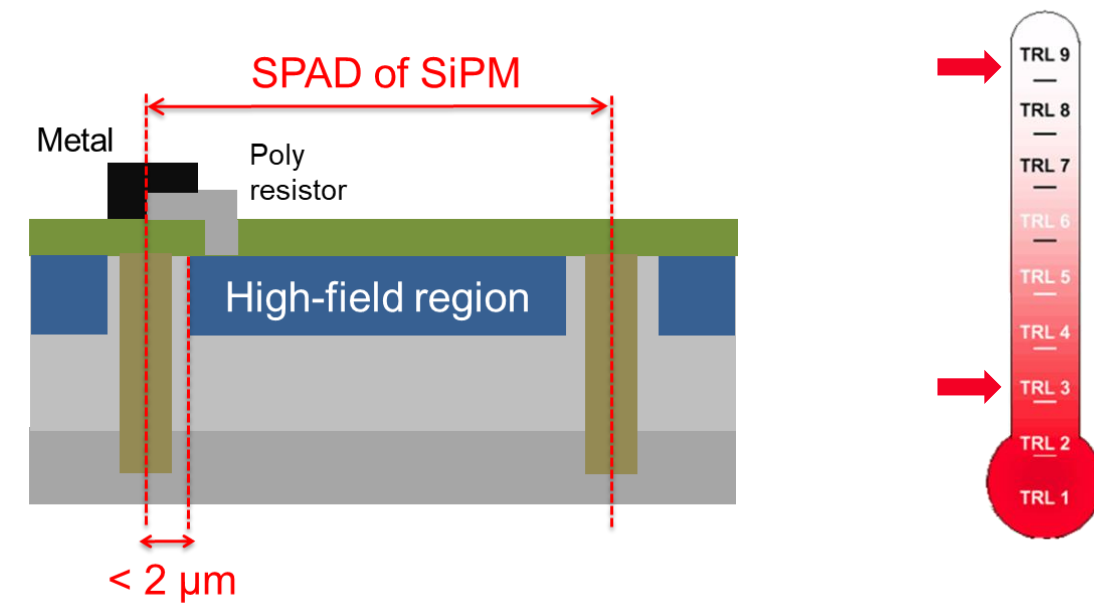
Timing performance in PET



FBK SiPM technologies

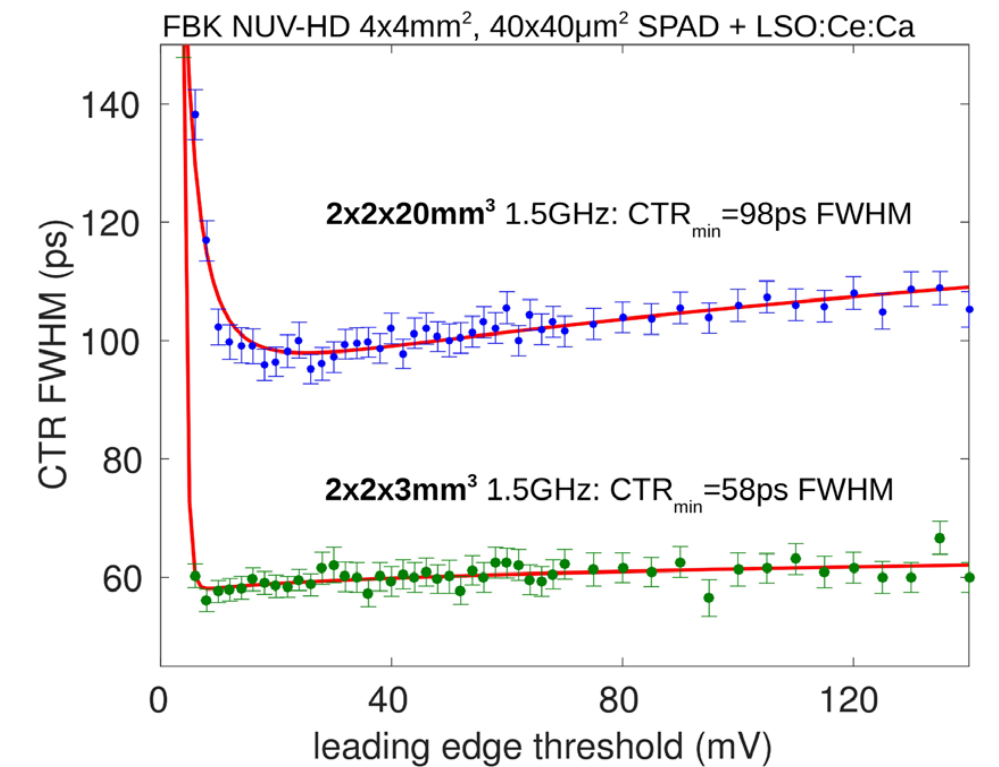
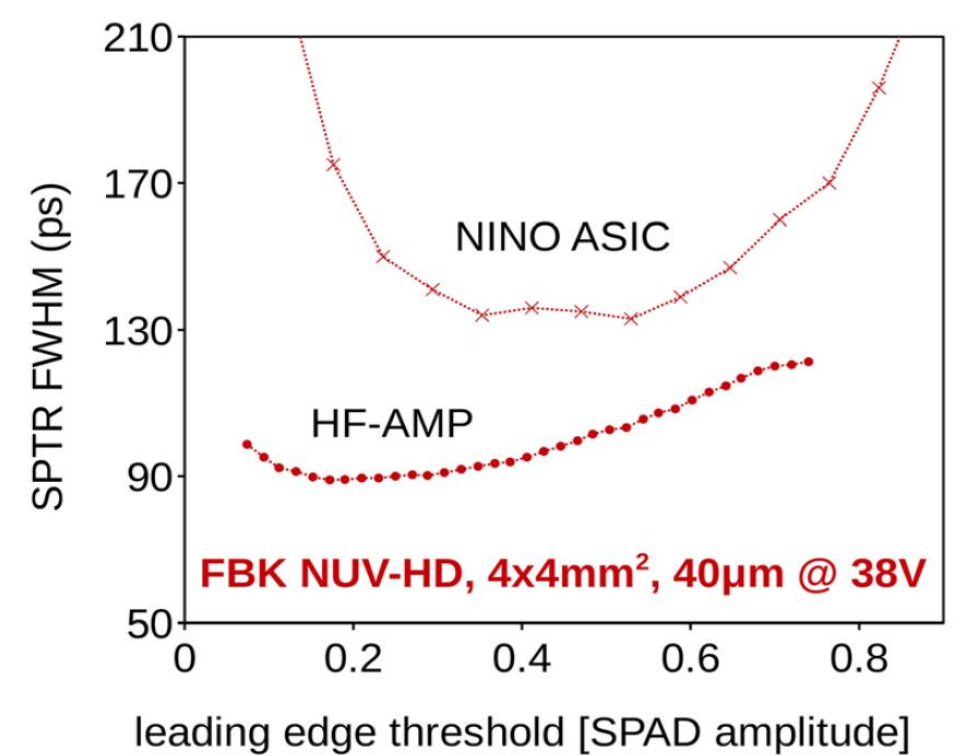
NUV-HD SiPM technology

NUV-HD SiPMs provide *state-of-the-art performance* for single photon detection, timing and for scintillation light readout.



Gola, A et al. (2019). "NUV-Sensitive Silicon Photomultiplier Technologies Developed at Fondazione Bruno Kessler." *Sensors*, 19(2), 308.

Timing with High-frequency readout (FWHM)



World record timing resolution: Single Photon Time resolution (SPTR, left) and Coincidence Resolving Time (CRT) in LYSO readout (right).

Gundacker, Stefan, et al. "High-frequency SiPM readout advances measured coincidence time resolution limits in TOF-PET." *Physics in Medicine & Biology* 64.5 (2019): 055012.

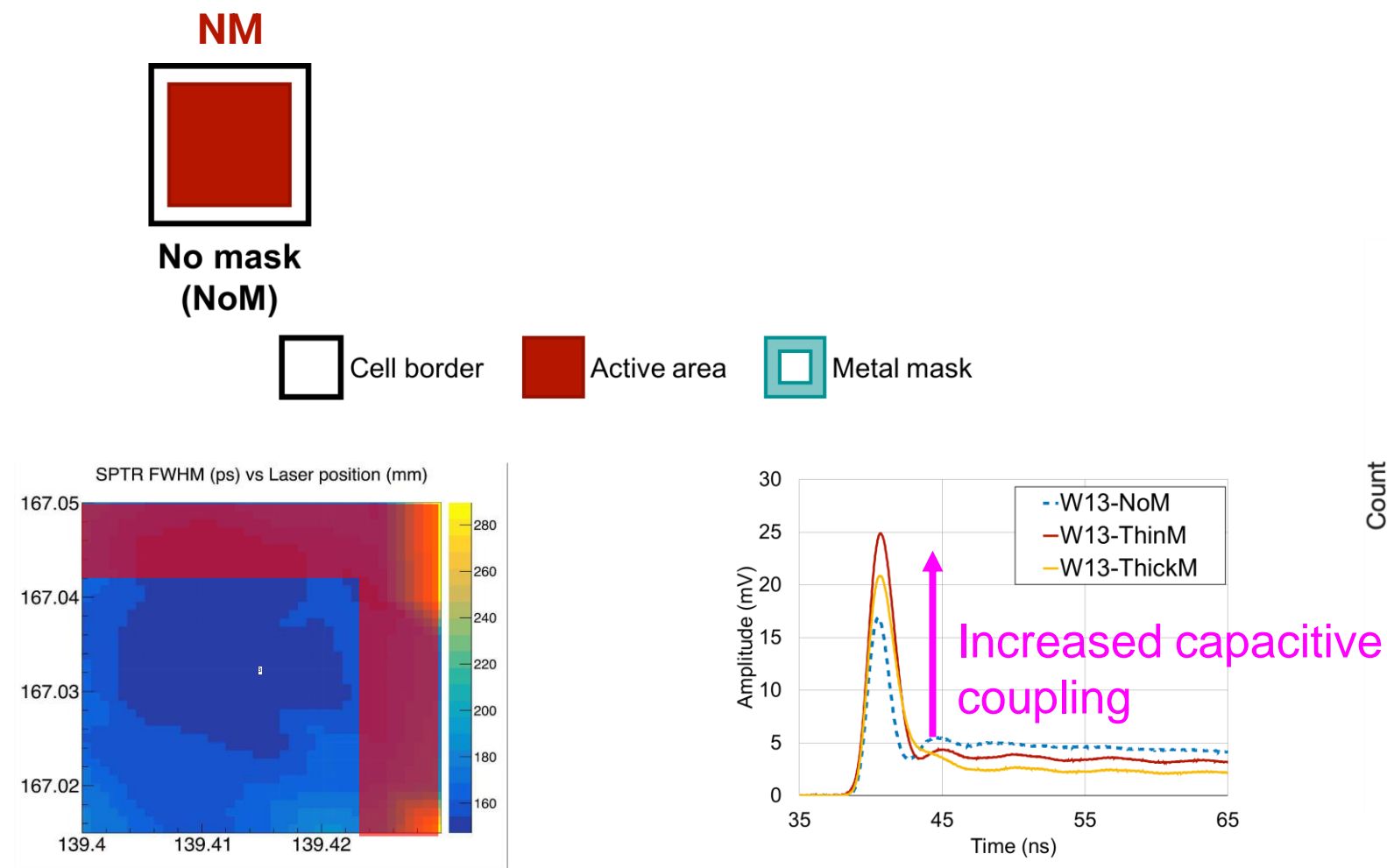


Masking

Optimization of SPTR with masking: CHK-HD

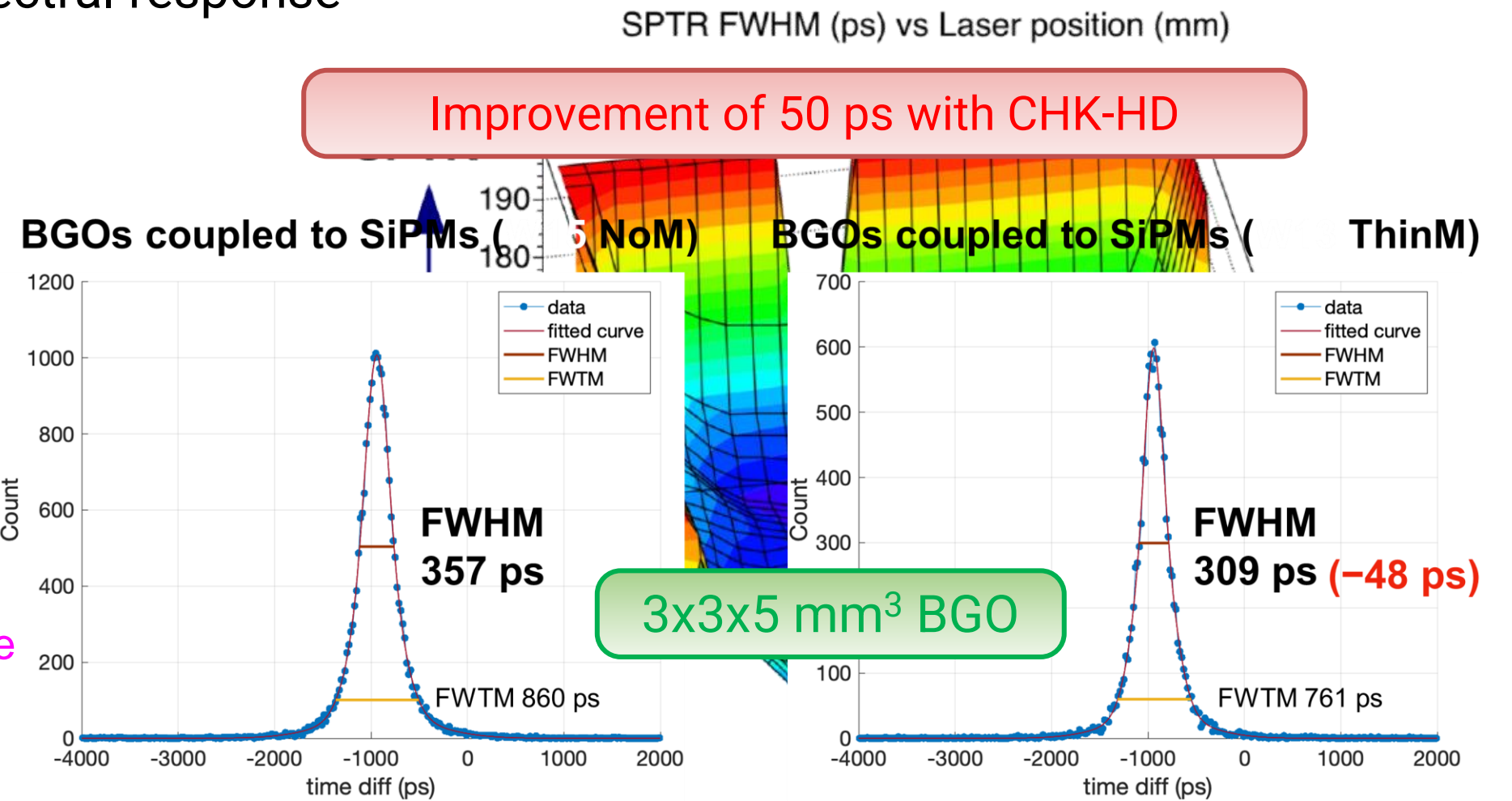
CHK-HD SiPMs is a variant of the NUV-HD SiPMs built to *experiment solutions to improve SPTR and detection efficiency* in applications where it matters the most, such as Cherenkov light readout.

- **Masking of outer regions of SPAD:** Improve signal peaking and mask areas of SPAD with worse SPTR
- Changes to the **Electric field:** low-field + different spectral response



Masking of outer regions of the SPAD that have worse "local" SPTR.

Increase of fast component of single photoelectron signal in accordance with masking extension.



CRT measured at UC Davis using 3x3 mm² CHK-HD SiPMs with 40 um cell, reading out a 3x3x5 mm³ BGO crystal.

Measured with standard FBK transimpedance amplifier.

Presented by Sun Il Kwon at NSS/MIC 2021

Traditional readout



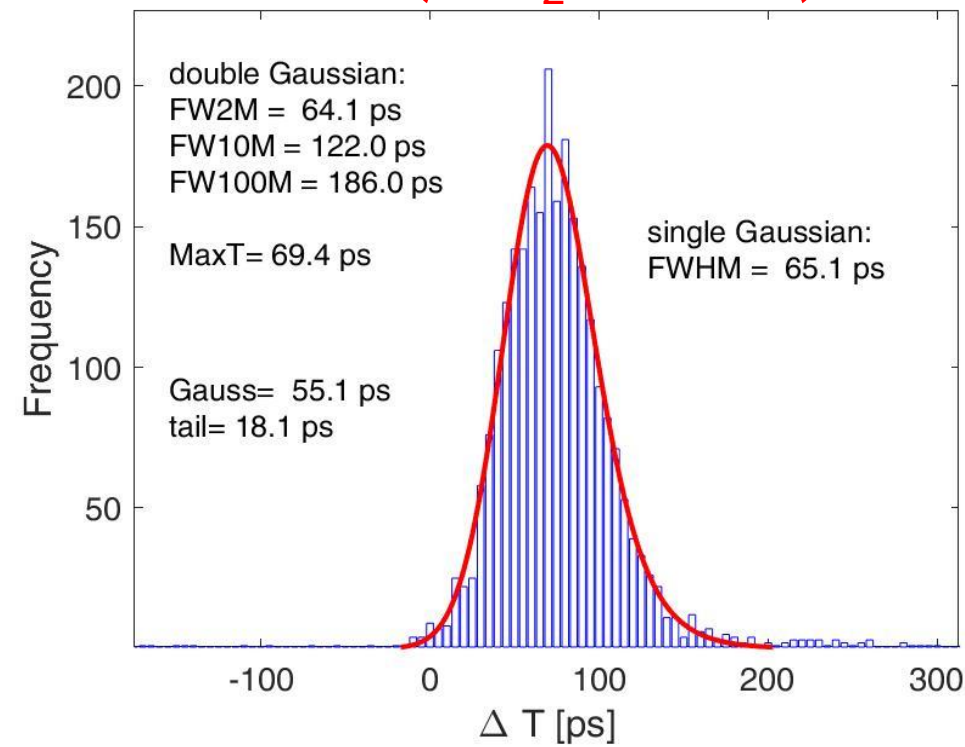
Nemallapudi, M. V., et al. "Single photon time resolution of state of the art SiPMs." *Journal of Instrumentation* 11.10 (2016): P10016.

Masking CHK-HD measurements with upgraded amplifiers

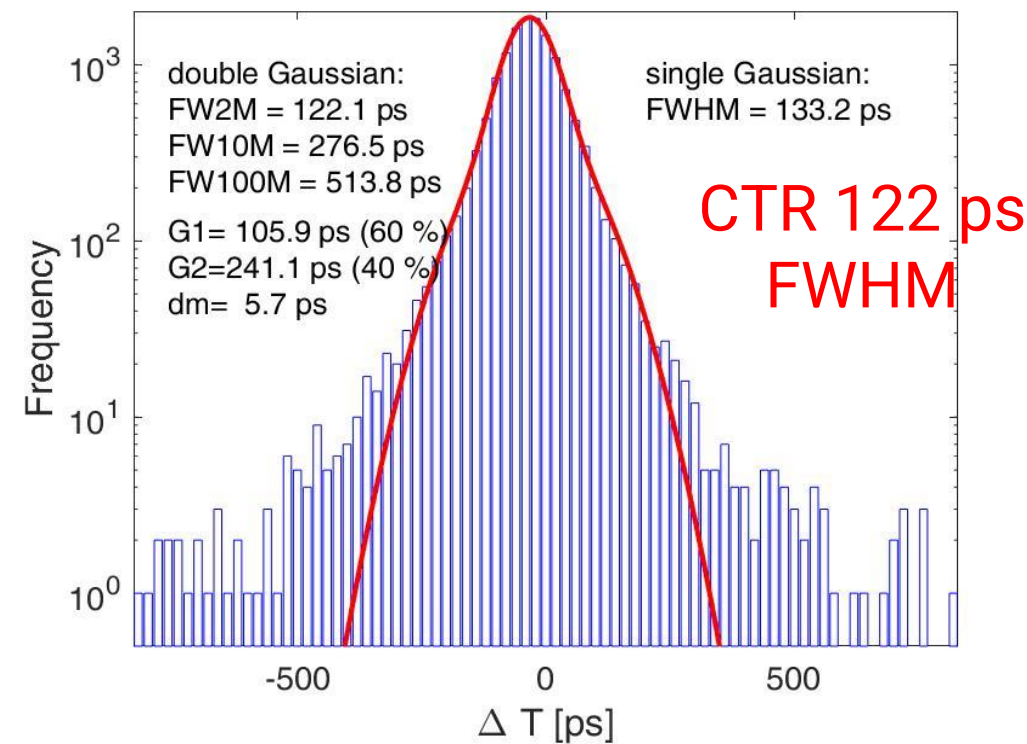
SPTR performance is *highly affected by the front-end electronic performance*: studies with different readout electronics.
3x3 mm² CHK-HD SiPMs, 40 um cell.

High-frequency readout

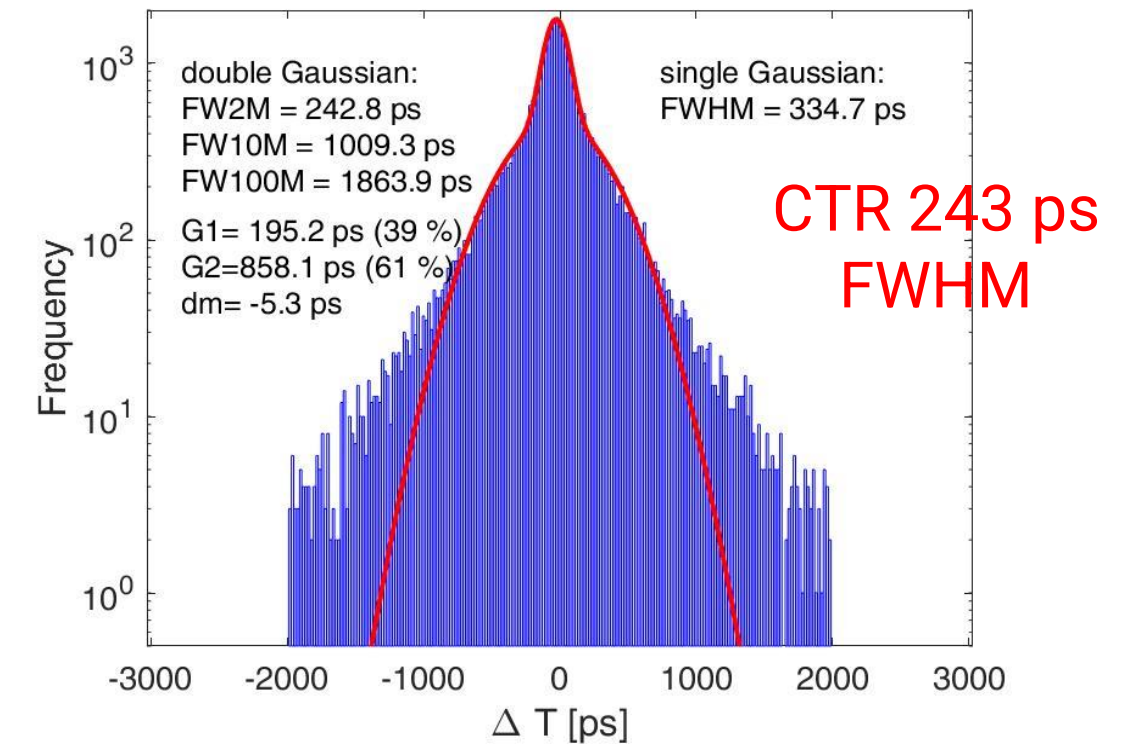
SPTR (PbF₂ method)



2x2x3 mm³ BGO (Epic)



3x3x20 mm³ BGO (Epic)



$$SPTR_{intrinsic} = \sqrt{65^2 - 47^2 - 21^2} = 39.6 \text{ ps}$$

Measurements by S. Gundacker, presented at FTMI 2022 workshop



Effect of electronic noise on SPTR is deconvolved.

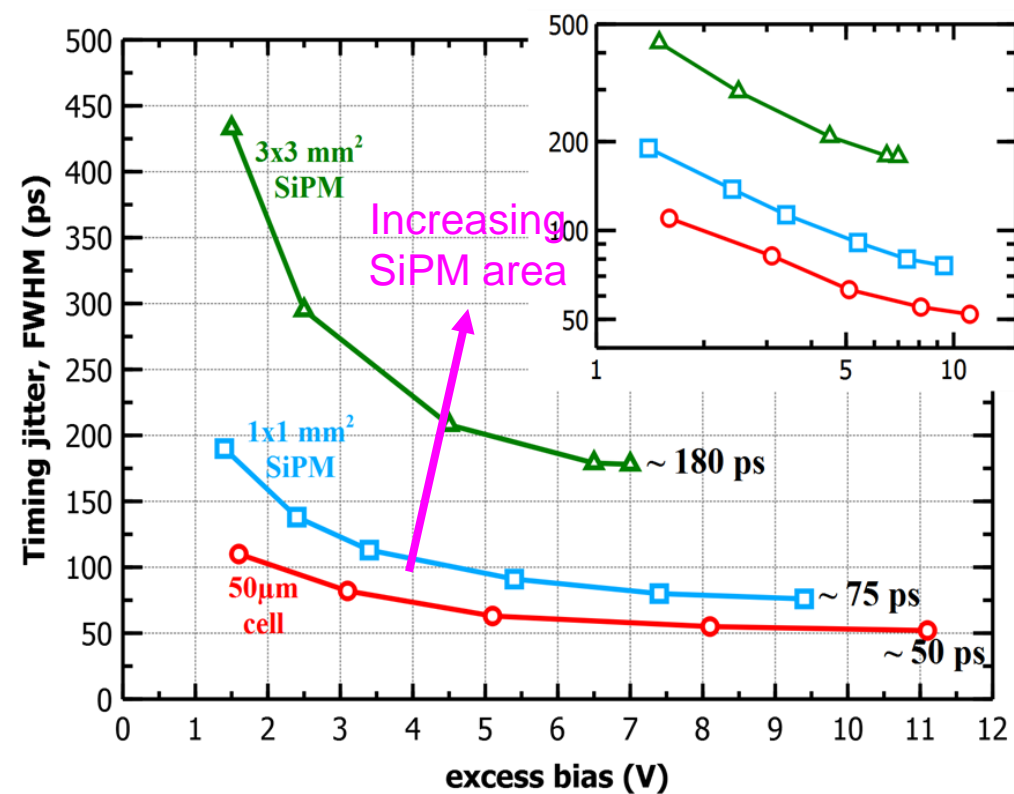
Timing performance

Effect of SiPM area on SPTR

SPTR and CRT performance is degraded when reading out SiPMs with *large areas*.

A possible solution can be the *segmentation of the active area into small pixels*, with separate readout, followed by signal summation or combination of time pick-off information.

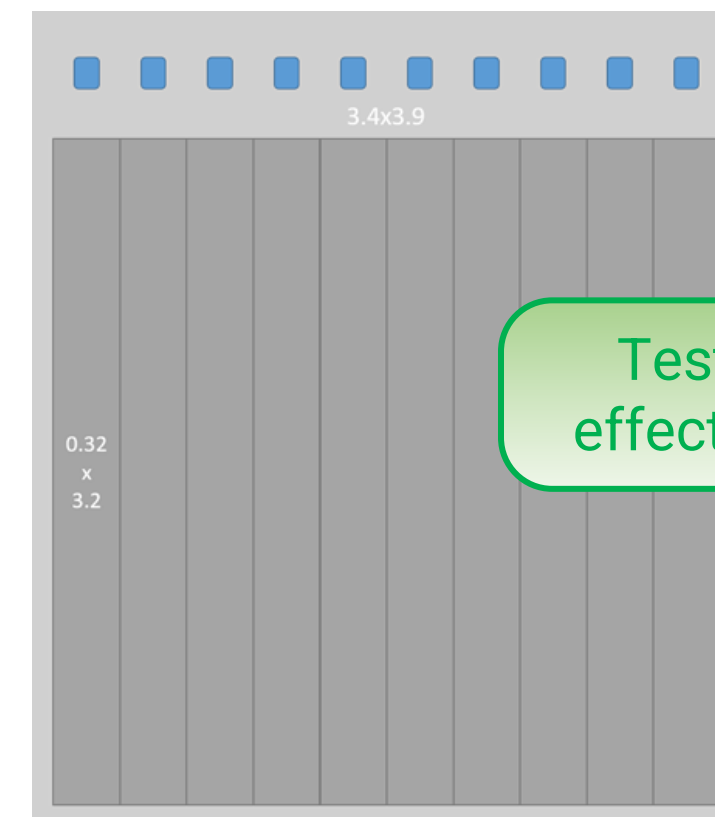
SPTR with standard FBK amplifier



SPTR vs. excess bias for different SiPM sizes, *with traditional amplifier*.

Acerbi, Fabio, et al. "Characterization of single-photon time resolution: from single SPAD to silicon photomultiplier." *IEEE Transactions on Nuclear Science* 61.5 (2014): 2678-2686.

Strip SiPMs



10 strips
0.32 x 3.2 mm²
each, no dead border
between strips

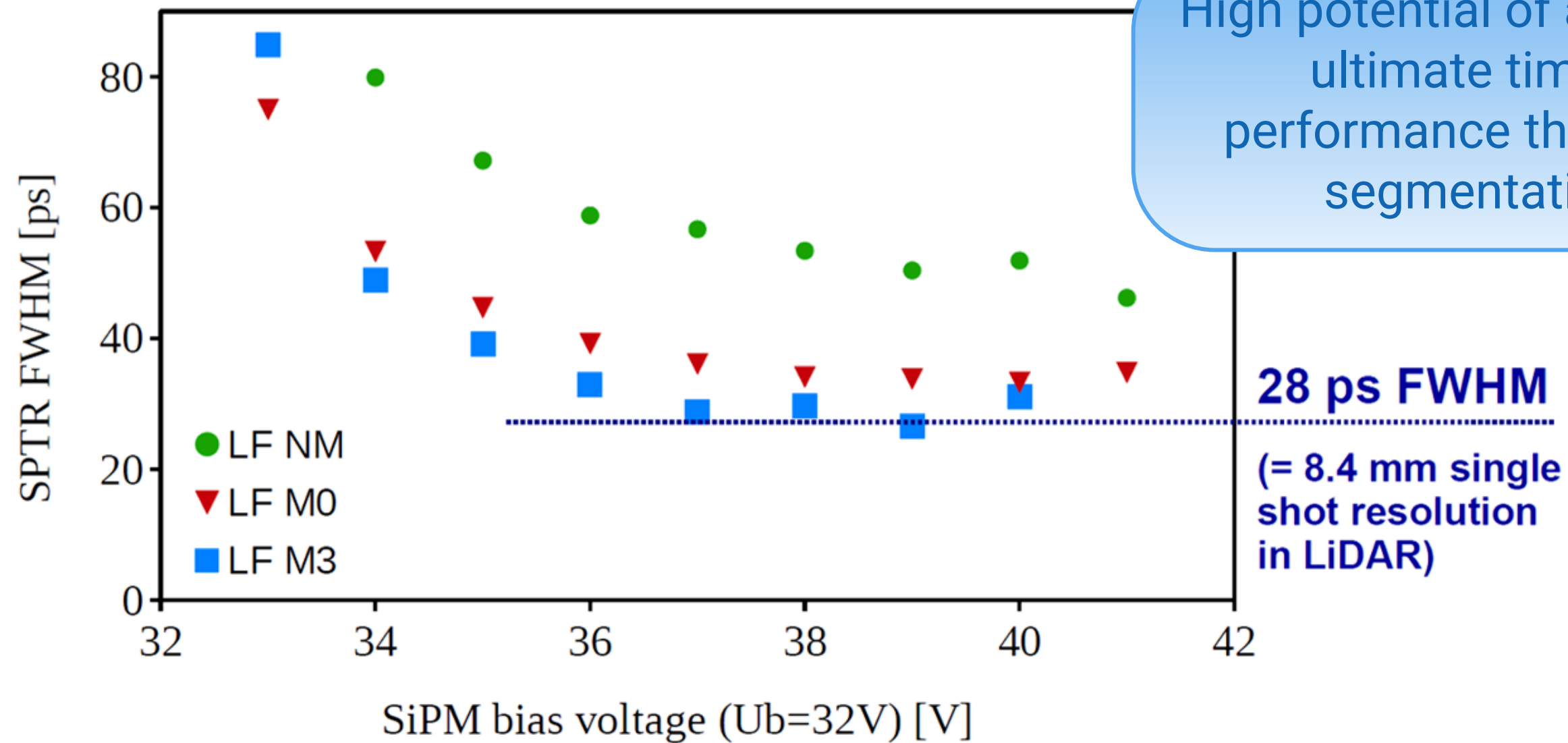
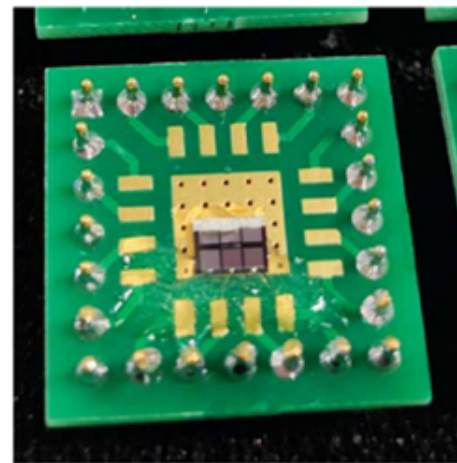
Example of segmented SiPM layout: a 3x3 mm² active area is divided in 10 0.3x3 mm² strip-SiPMs.



Segmentation

SPTR of a 1x1 mm² CHK-HD with masking

A 1x1 mm² CHK-HD, with masking, was measured at Aachen (S. Gundacker) with *high-frequency readout*, achieving a *remarkable Single Photon Time Resolution of 28 ps FWHM*.



High potential of achieving ultimate timing performance thanks to segmentation

28 ps FWHM
 (= 8.4 mm single shot resolution in LiDAR)

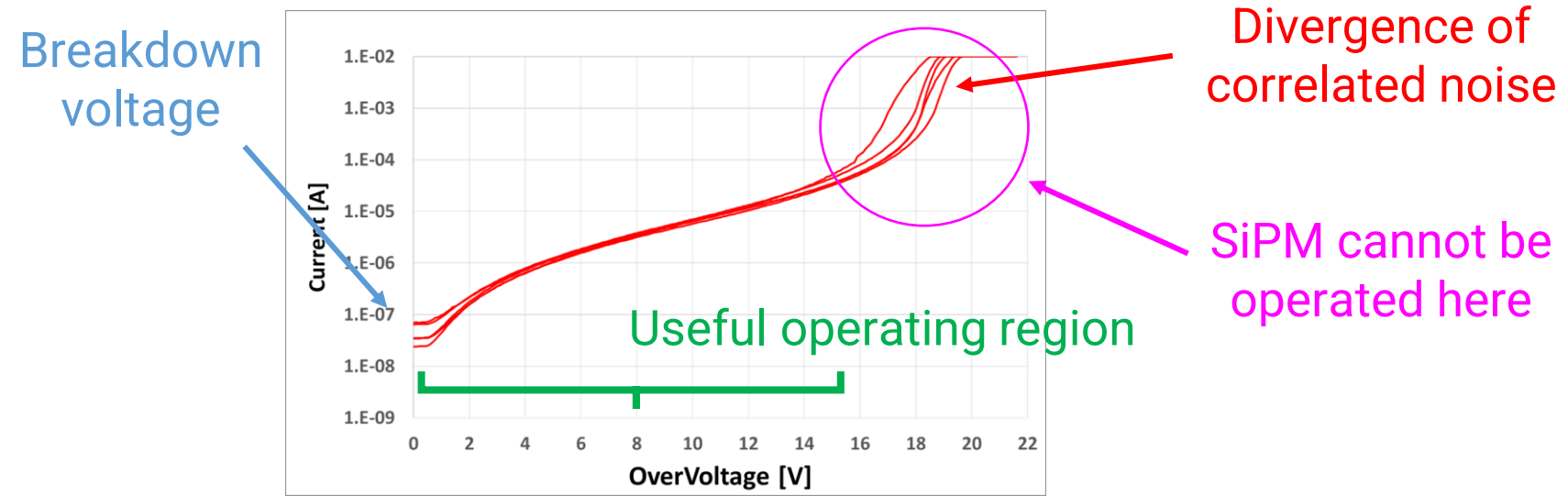
Not corrected for electronic noise

Optical Crosstalk

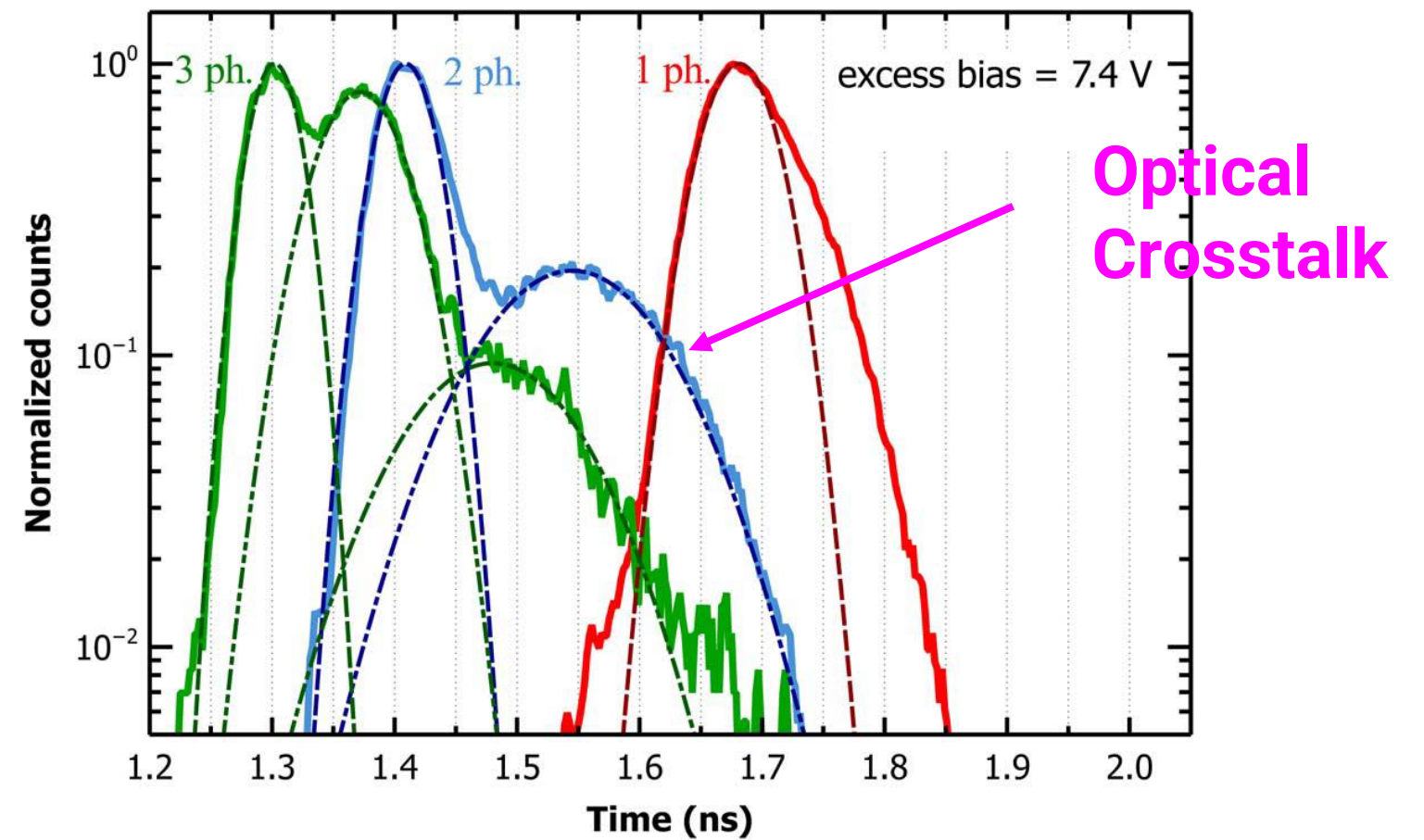
Worsening of the performance of the detection system

Optical Crosstalk worsens the performance of the detection system both by *limiting the maximum excess bias* that can be applied to the SiPM and by *worsening the photon time of arrival statistics*.

Limiting the maximum excess bias



Worsening of the Few Photons Time Resolution



Above a certain over-voltage the number of dark counts and, thus, the reverse current diverge.

- Lower PDE, Gain.
- Worse SPTR

$$ECF \cong \frac{1}{1 - P_{CN}}$$

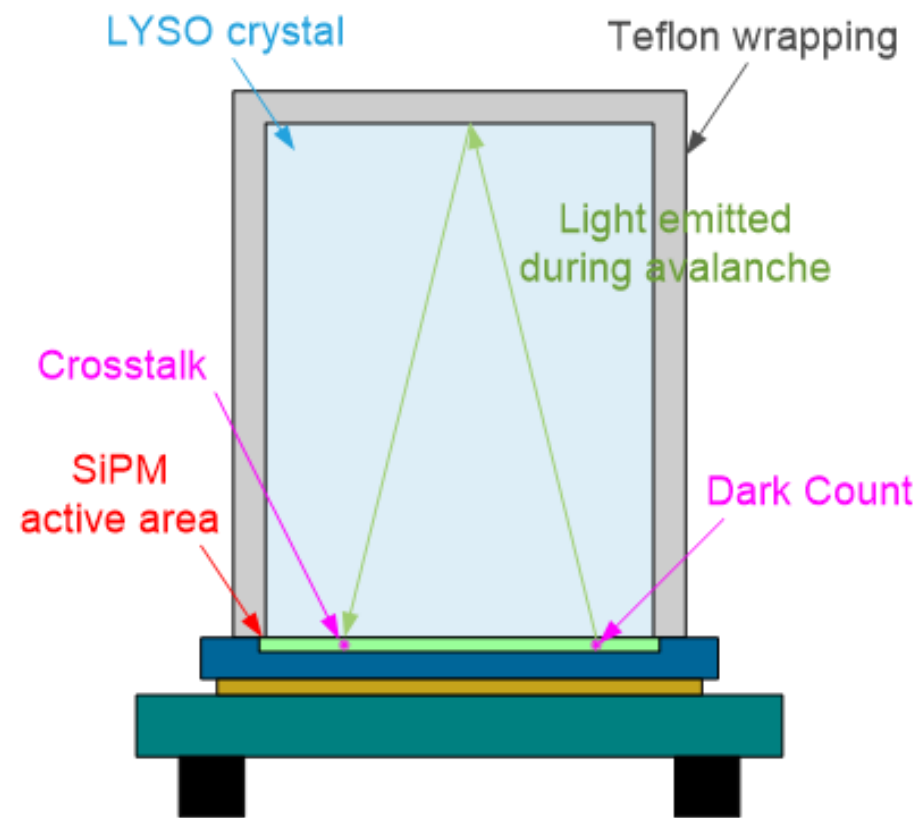
Geometric series approximation of the **Excess Charge Factor**.



Optical crosstalk

External Crosstalk

Optical crosstalk probability is enhanced by the presence of the scintillator: external crosstalk.

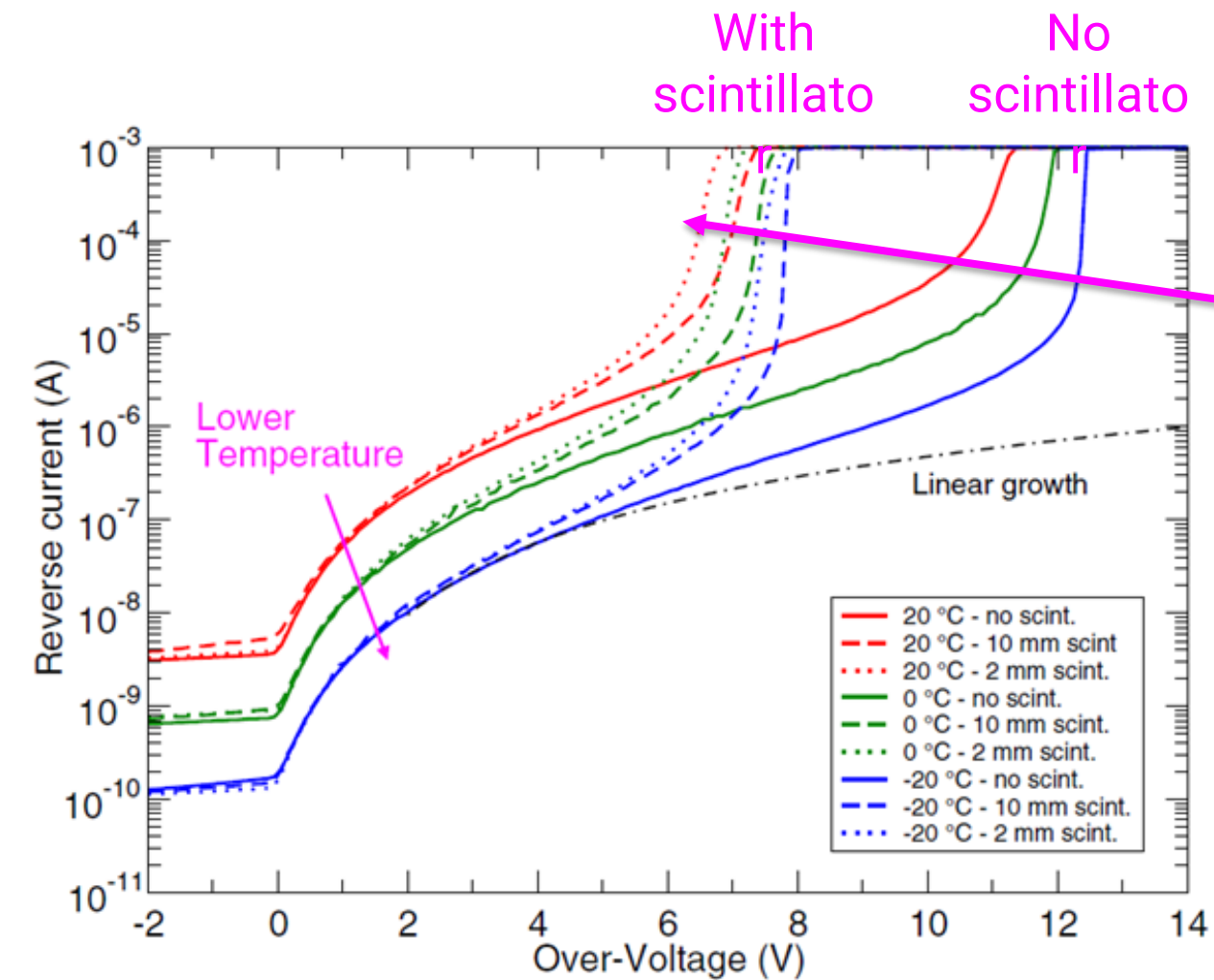


Mechanism of optical crosstalk probability enhancement because of the scintillator.

Gola, Alberto, et al. "SiPM optical crosstalk amplification due to scintillator crystal: effects on timing performance." *Physics in Medicine & Biology* 59.13 (2014): 3615.

$$ECF \cong \frac{1}{1 - P_{CN}}$$

Geometric series approximation of the **Excess Charge Factor**.

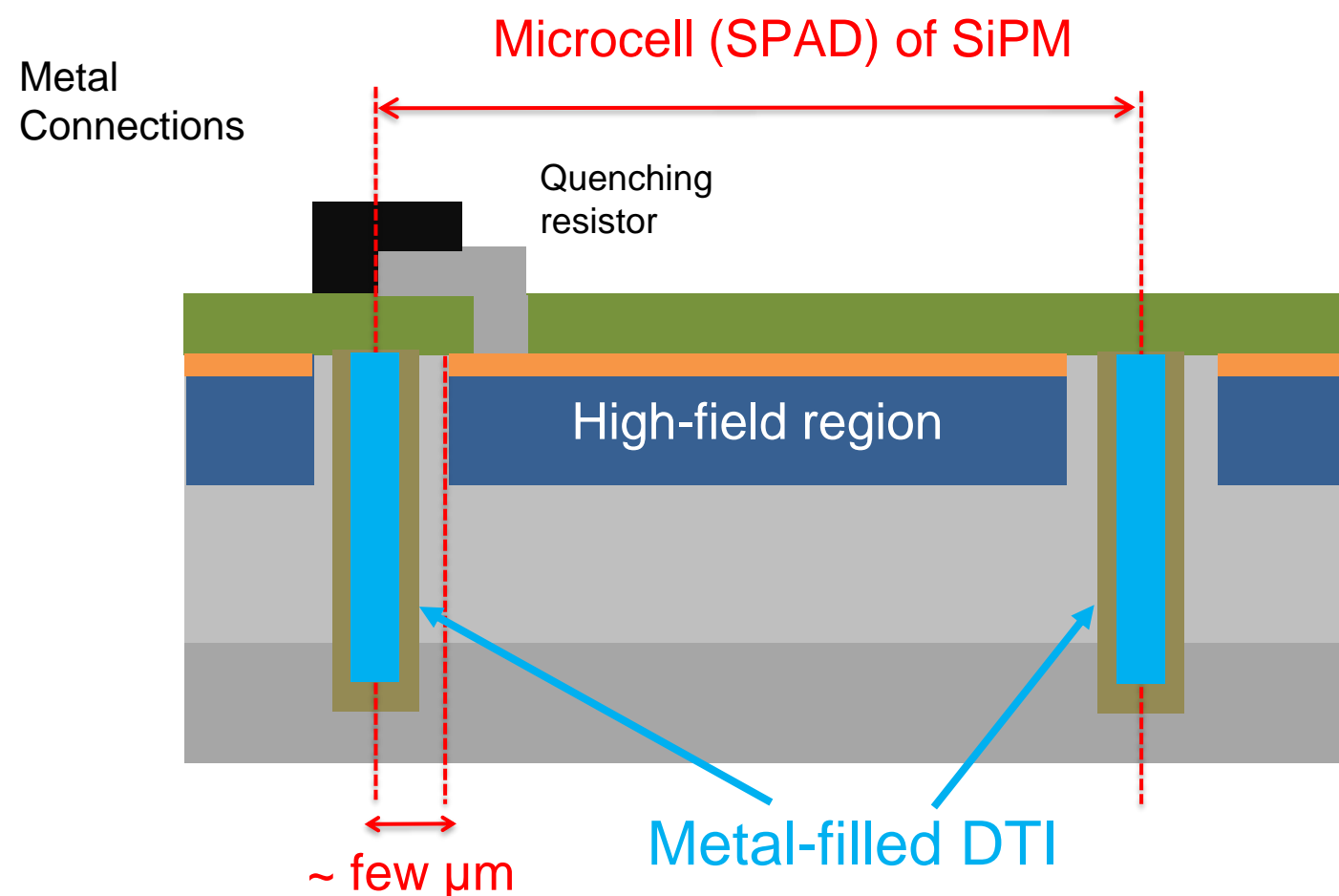


Comparison of SiPM IV with different scintillator sizes placed on top of them, at different temperatures.

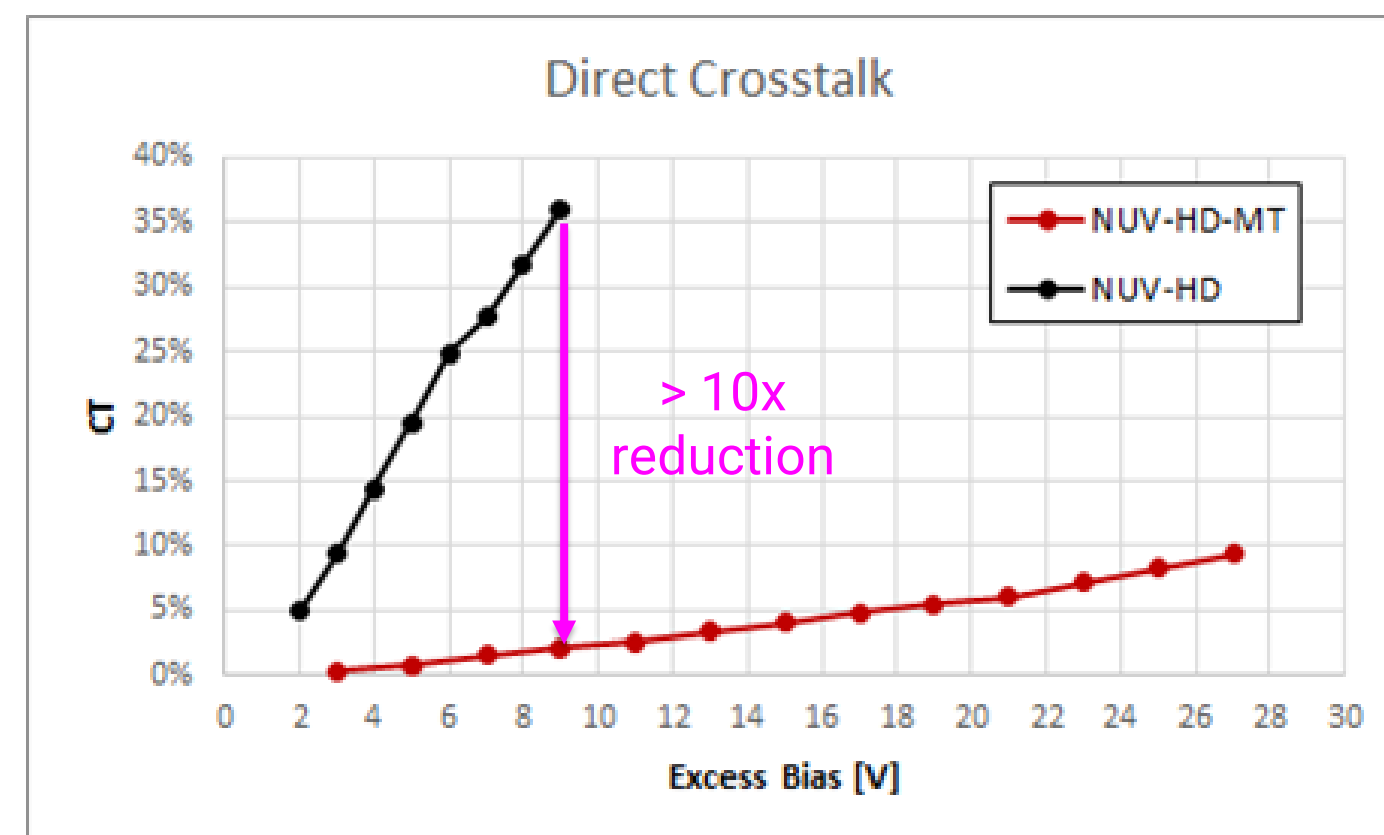
Reduction of optical crosstalk NUV-HD-MT development

Starting from the NUV-HD technology, FBK and Broadcom jointly developed the NUV-HD-MT technology, adding *metal-filled DTI isolation to strongly suppress optical crosstalk*.

Other changes: low electric field variant, layout optimized for timing.



Conceptual drawing of the NUV-HD-MT, with the addition of metal-filled Deep Trench Isolation.

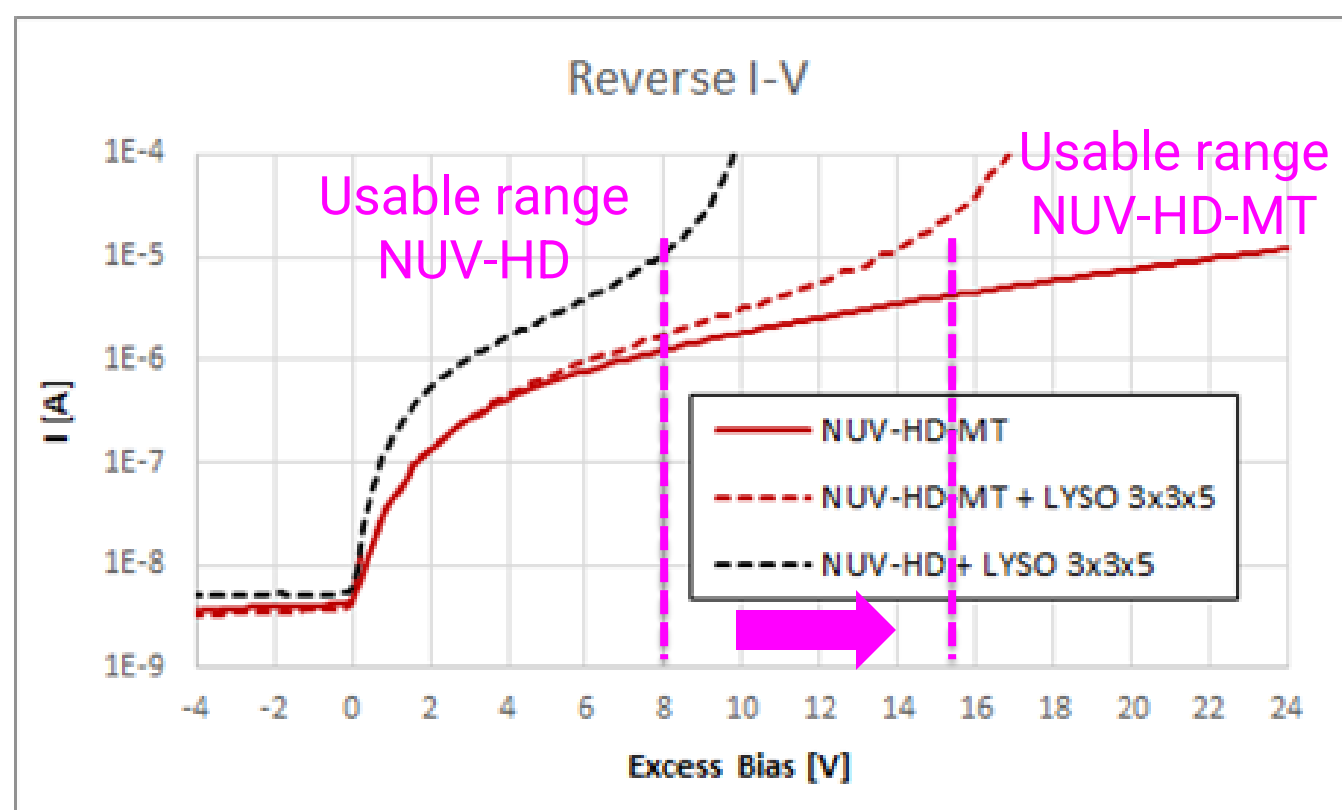


Reduction of optical crosstalk probability in NUV-HD-MT, compared to the "standard" NUV-HD. Measurement without encapsulation resin, i.e. *only considering internal crosstalk probability*.

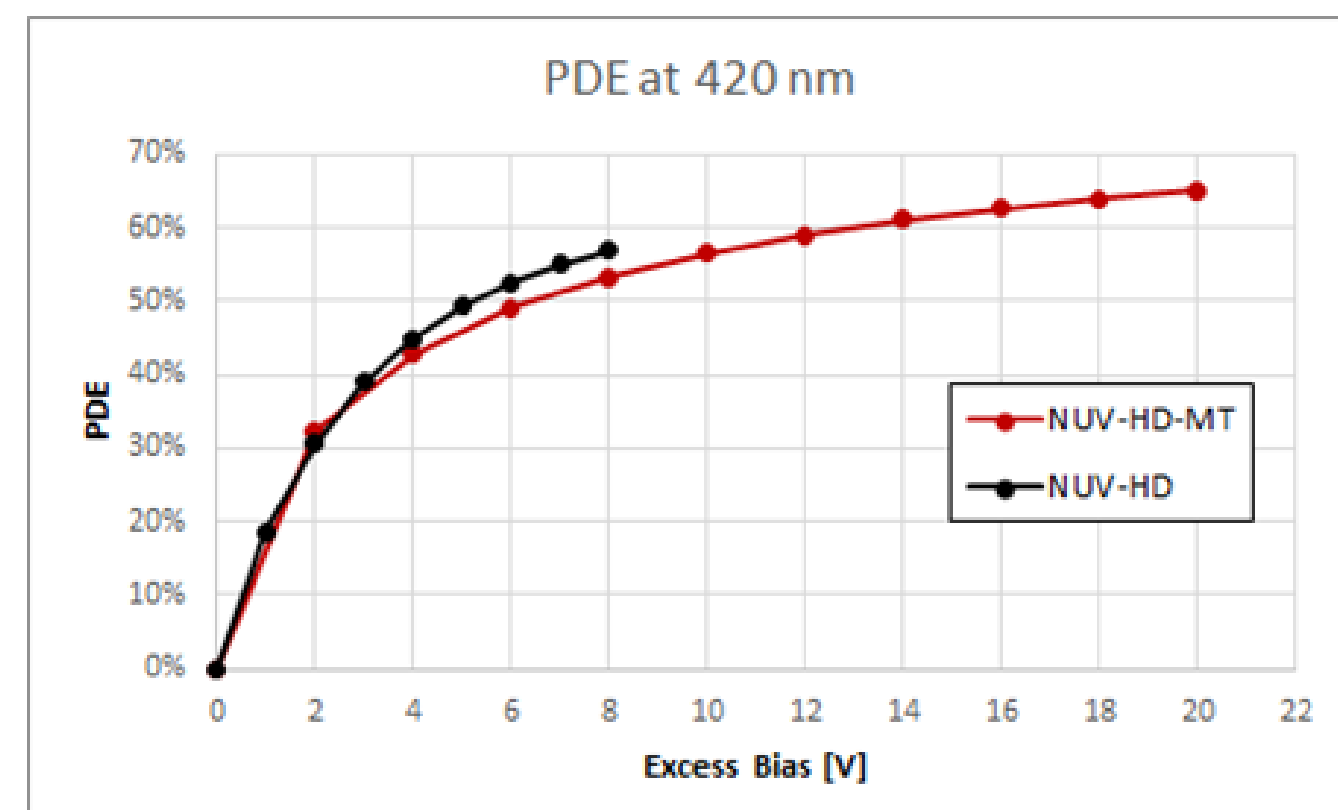
Reduction of optical crosstalk NUV-HD-MT bias range

Reduction of optical crosstalk probability *increases maximum usable excess bias of SiPM*, also with the scintillator on top of the SiPM.

Increase of excess bias *more than compensates the slight reduction of Fill Factor* caused by the addition of metal inside the DTI.



Reverse IV measured on a 4x4 mm² NUV-HD-MT SiPM with 45 μ m cell pitch under different conditions.



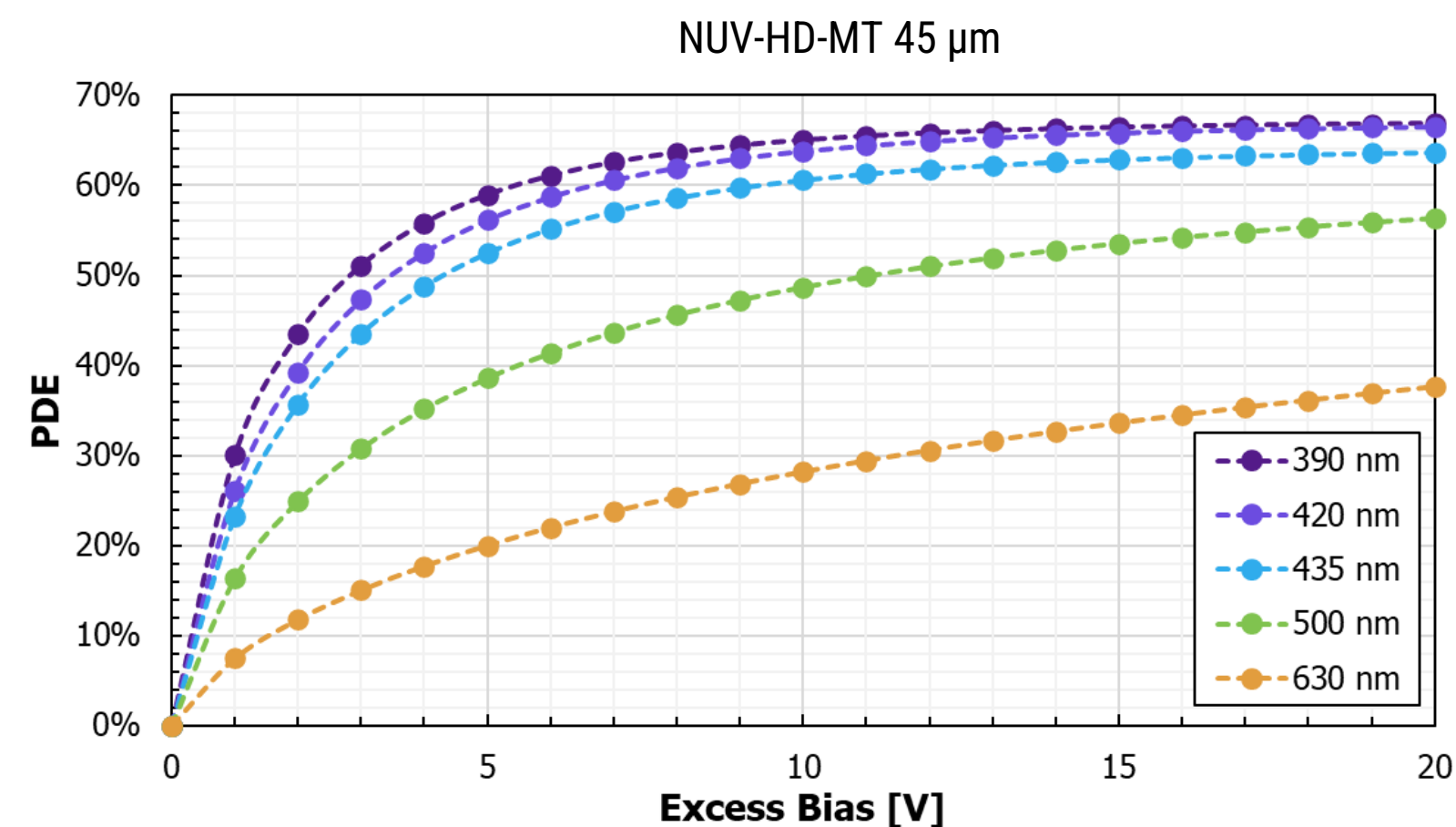
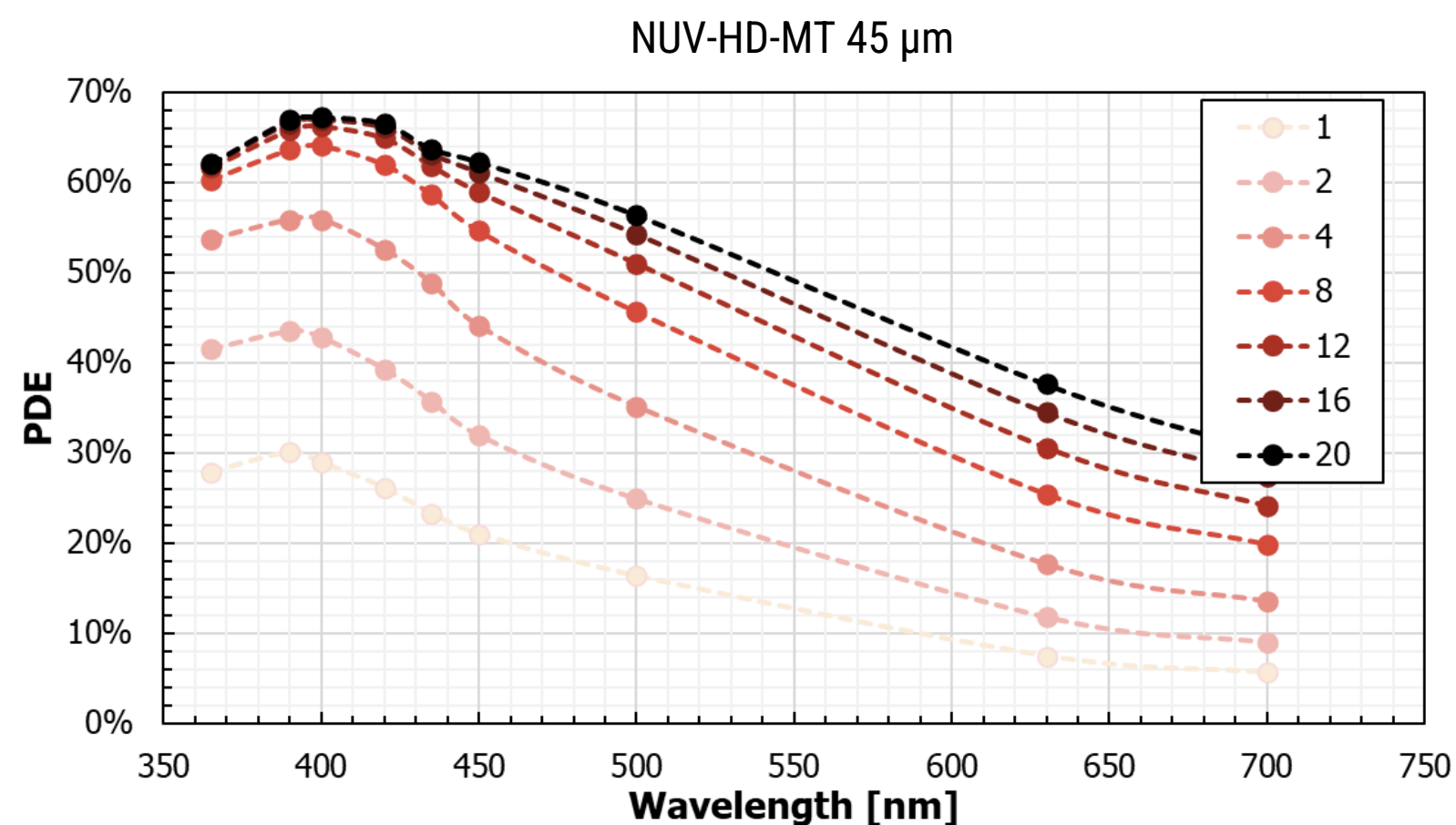
PDE at 420 nm measured on a NUV-HD-MT SiPM with 45 μ m cell size.

Reduction of optical crosstalk

NUV-HD-MT PDE

NUV-HD-MT is *based on a p-on-n junction*, thus peak PDE is around 390 – 420 nm.

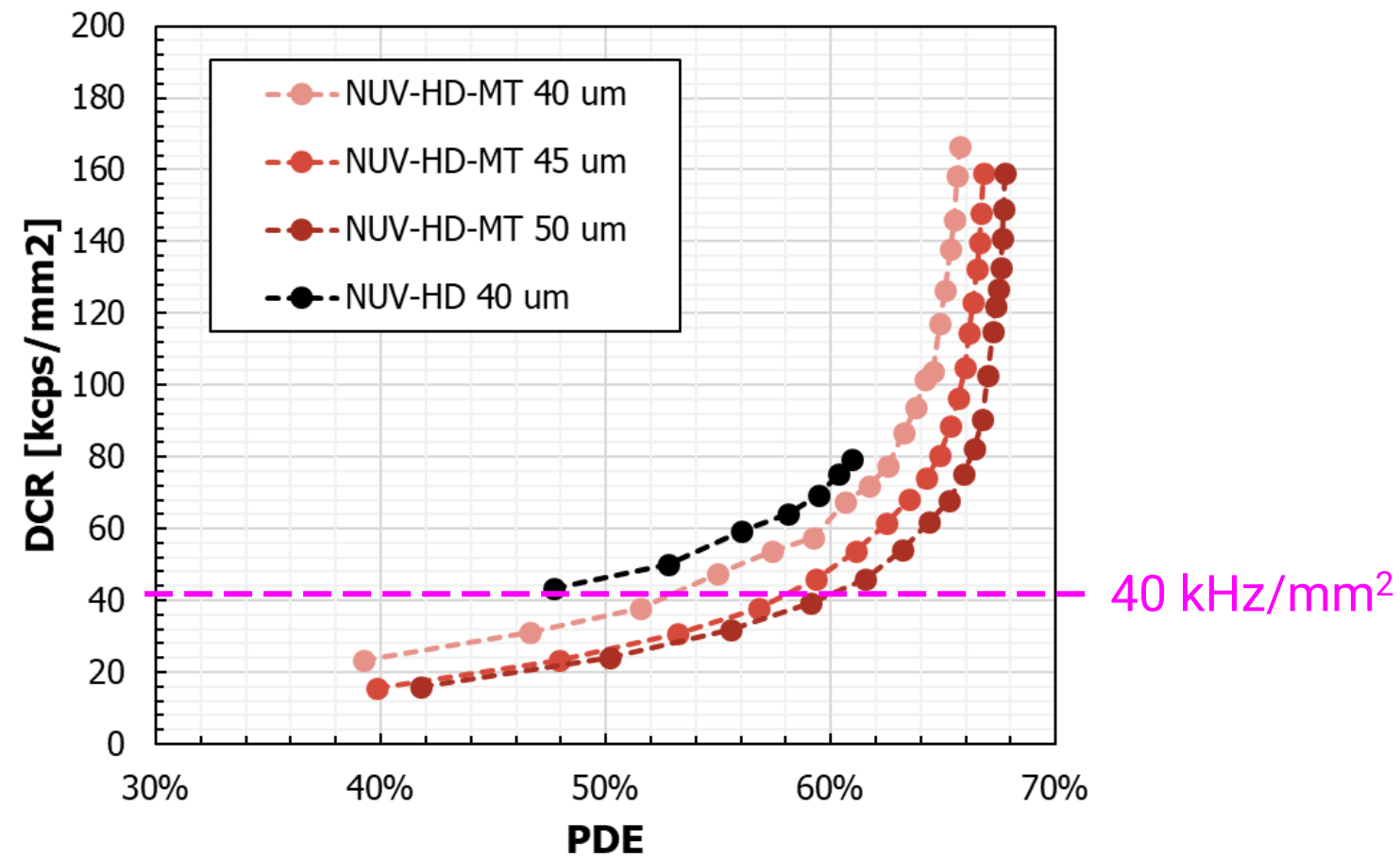
Thanks to the very high maximum excess bias, *also PDE in the red (avalanche triggering by holes) approaches saturation*.



Reduction of optical crosstalk NUV-HD-MT electro optical performance

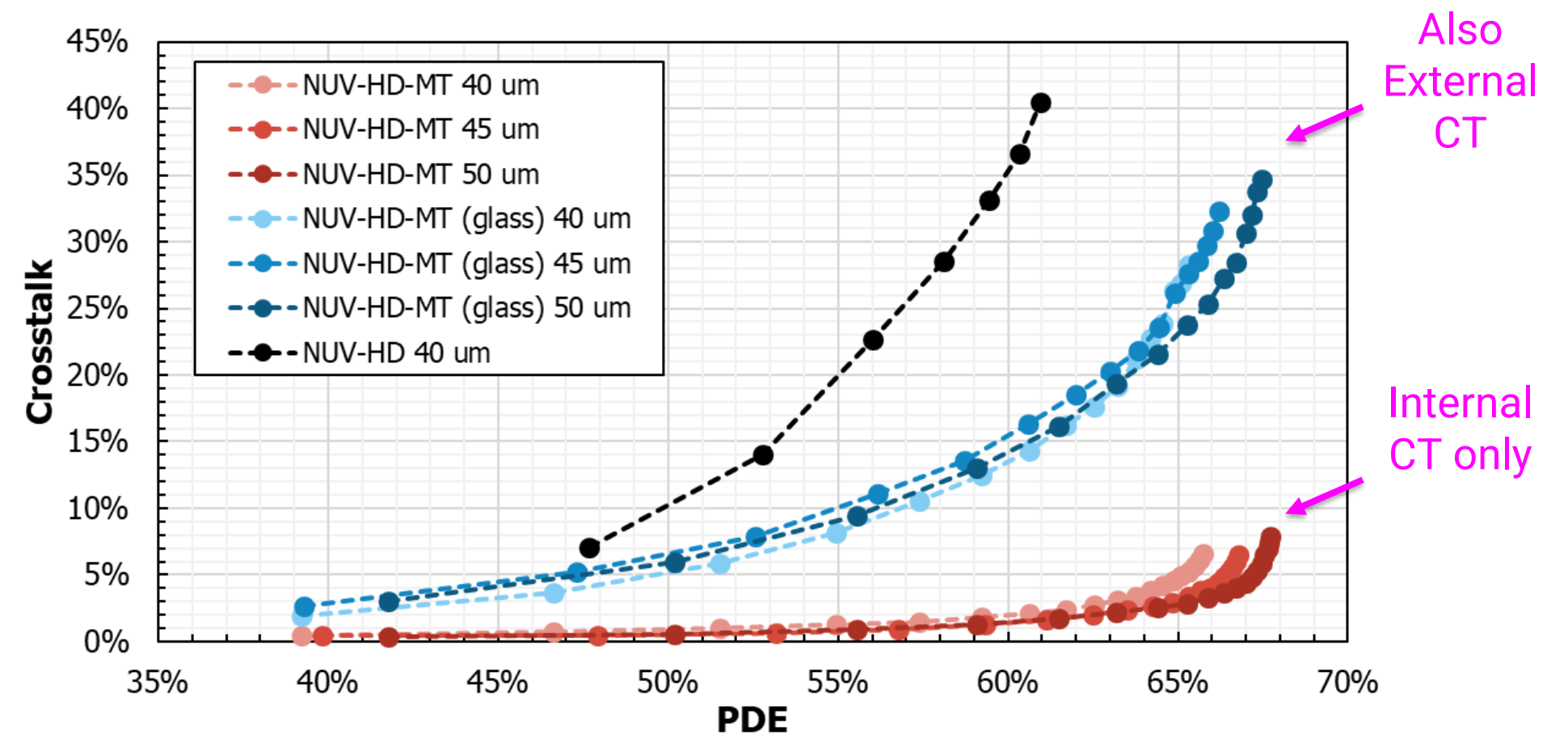
NUV-HD-MT *nuisance parameters are better represented and compared as a function of the PDE.*

DCR vs. PDE



DCR vs. peak PDE (measured at 420 nm) for different cell sizes of the NUV-HD-MT technology.

Direct Optical CT vs. PDE

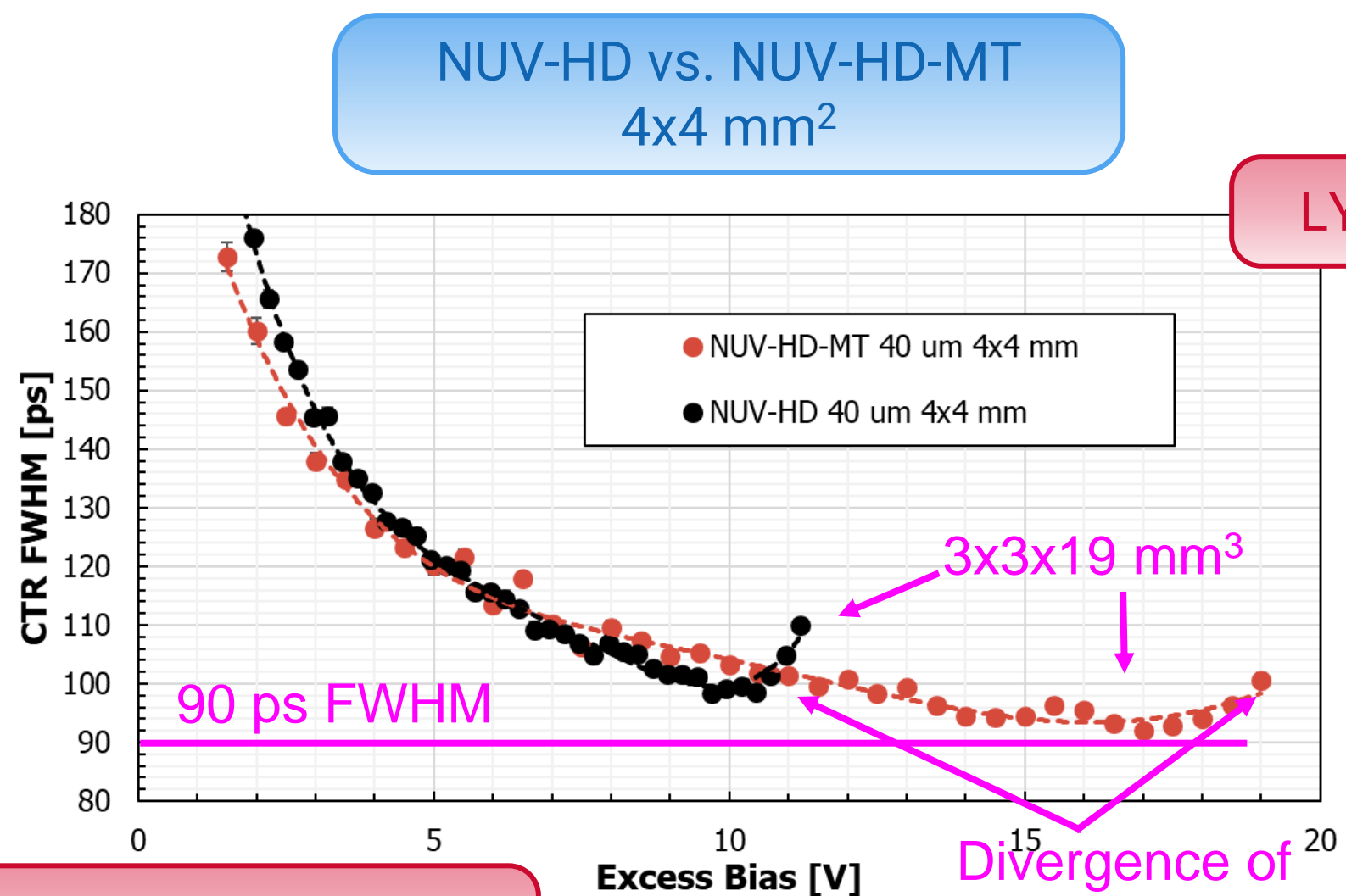


DiCT vs. peak PDE (measured at 420 nm) for different cell sizes of the NUV-HD-MT technology, with and without protective glass on top of the SiPM (used for TSV)

NUV-HD-MT

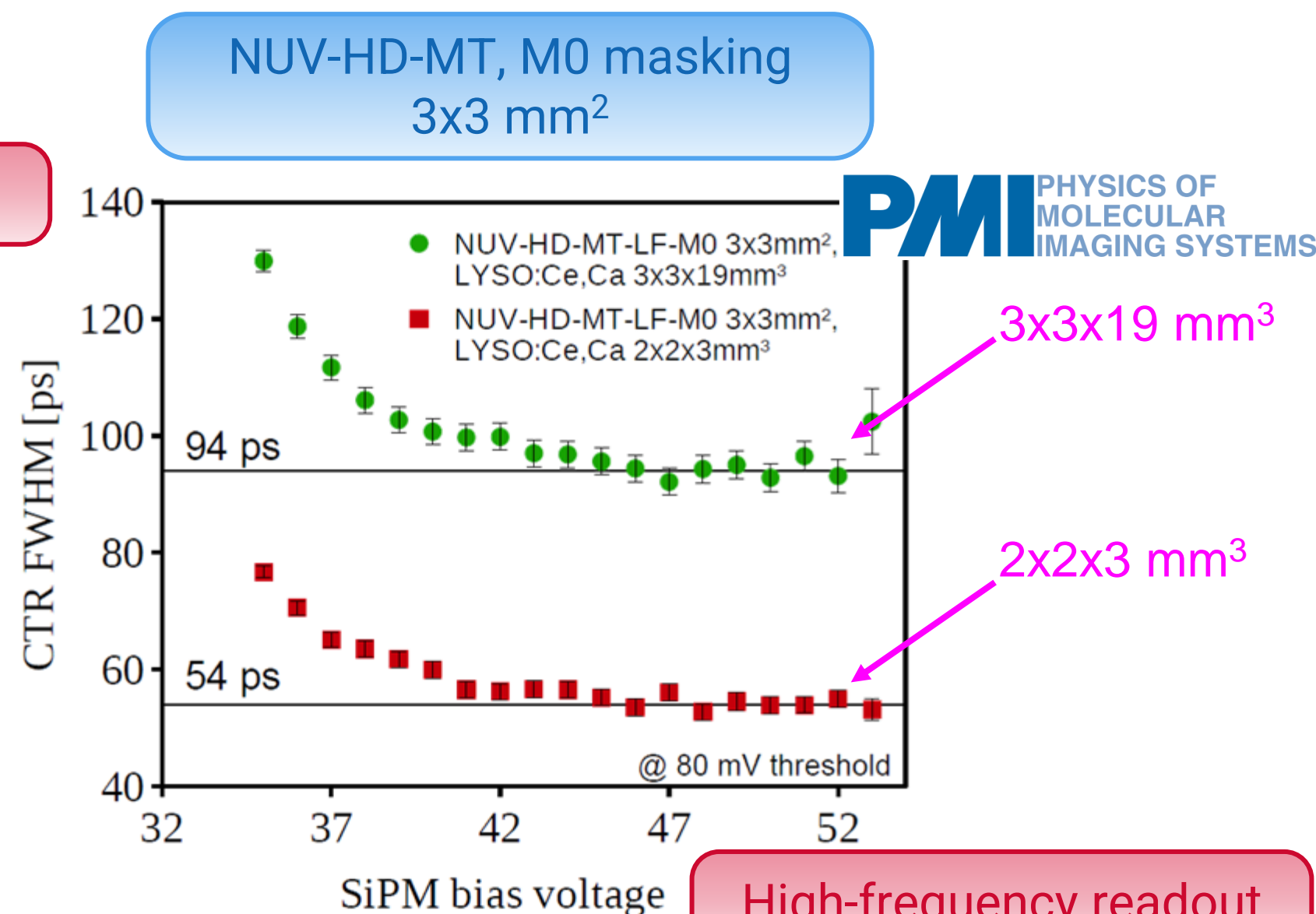
CTR with LYSO:Ce,Ca

The increase of usable excess bias with scintillator allows *better exploiting the maximum PDE* of the detector and *achieving higher Gain* and *lower SPTR*.



Standard FBK amplifier

Comparison of CTR measured with 3x3x5 mm³ LYSO:Ca,Ce coupled to NUV-HD and NUV-HD-MT using the standard FBK transimpedance amplifier.



High-frequency readout

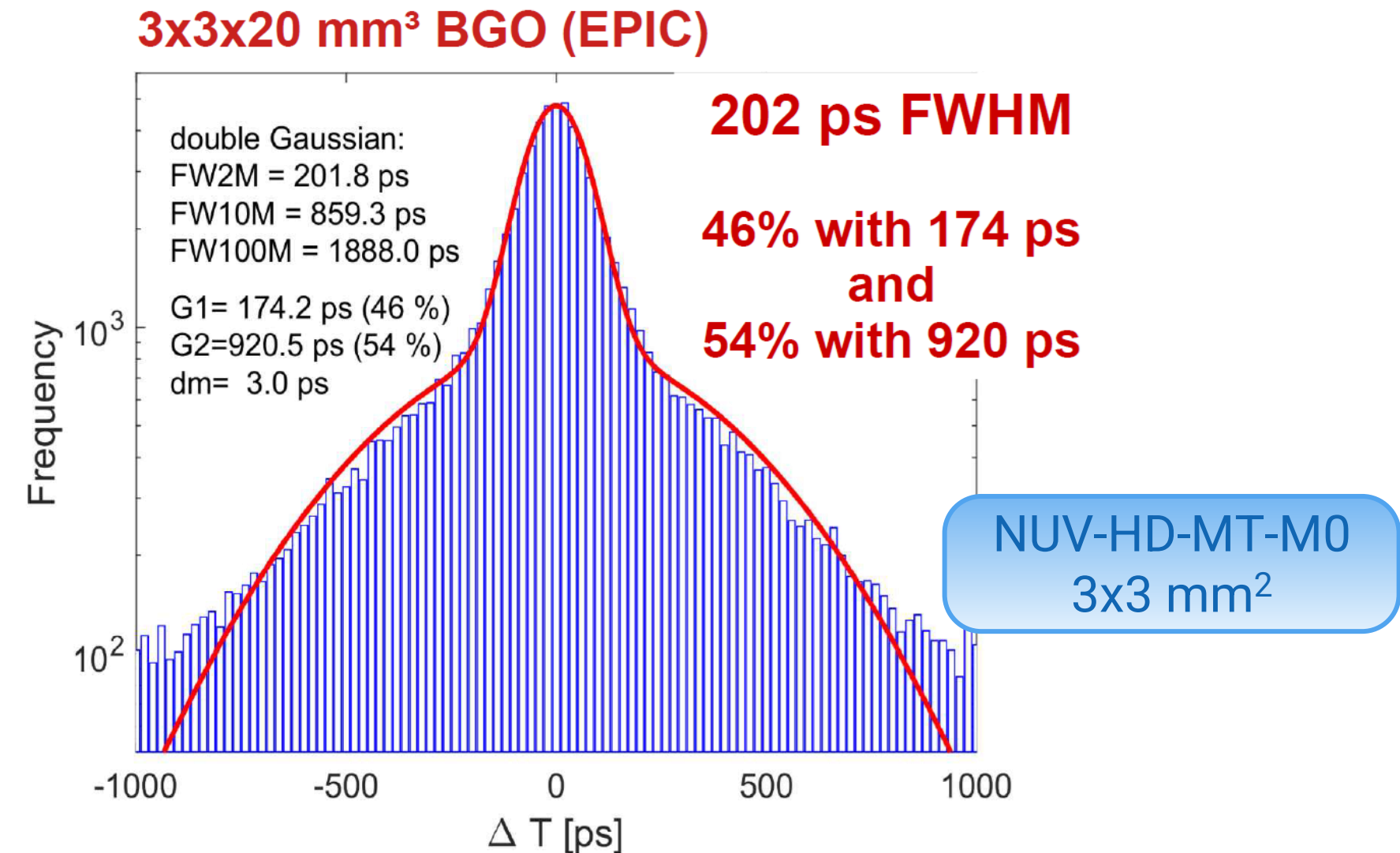
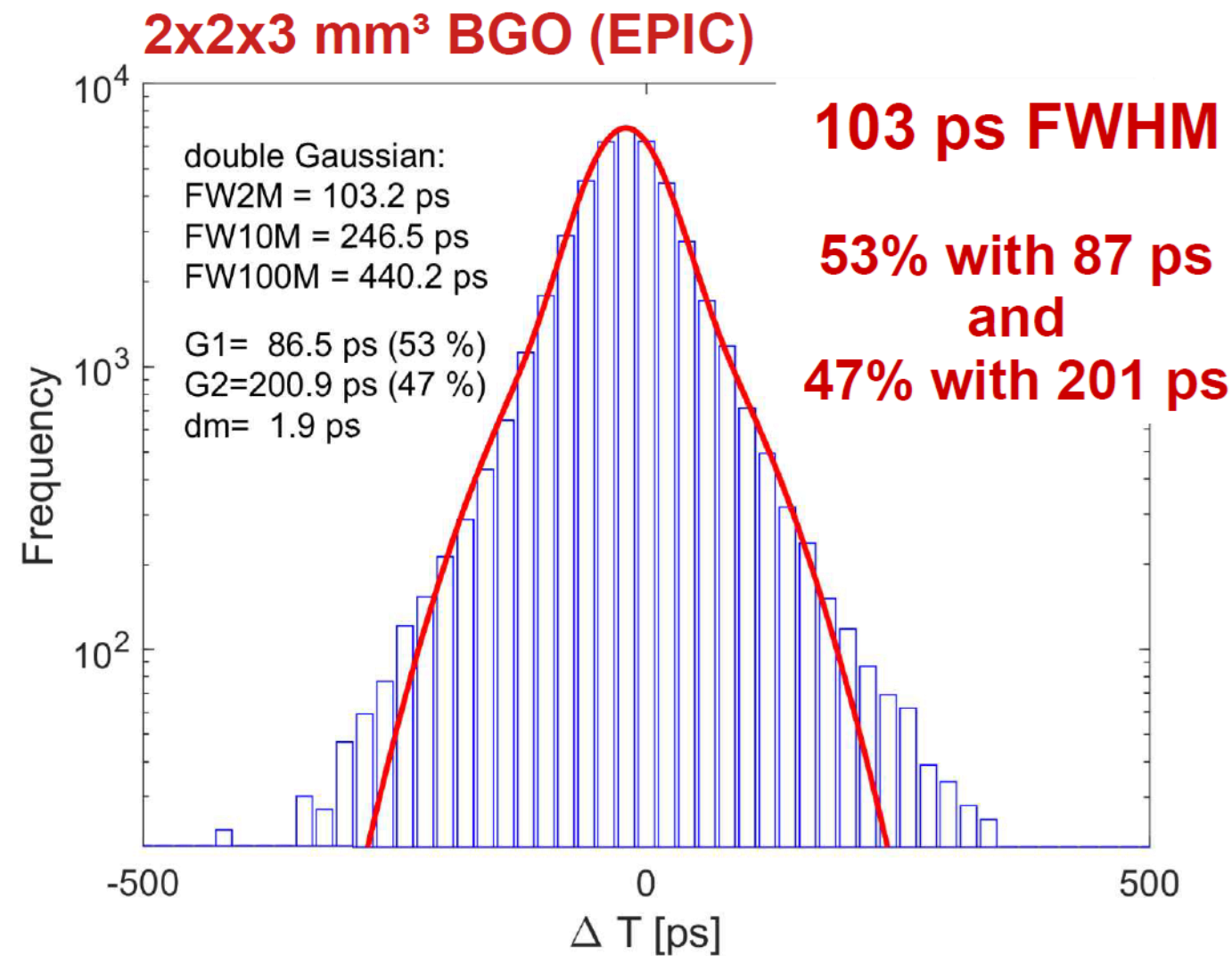
CTR measured with a 3x3 mm² NUV-HD-MT SiPM, with M0 masking, COUPLED TO 2X2X3 mm³ and 3X3X19 mm³ LYSO:Ce,Ca, using the high-frequency readout.



NUV-HD-MT BGO CTR with masking and high-frequency readout

SPTR optimization is even more *important in photon-starved applications*, such as Cherenkov-enhanced BGO readout.

SPTR is improved thanks to *high-gain, masking, high-frequency readout*. In addition, *high PDE* allows the collection of more prompt photons.





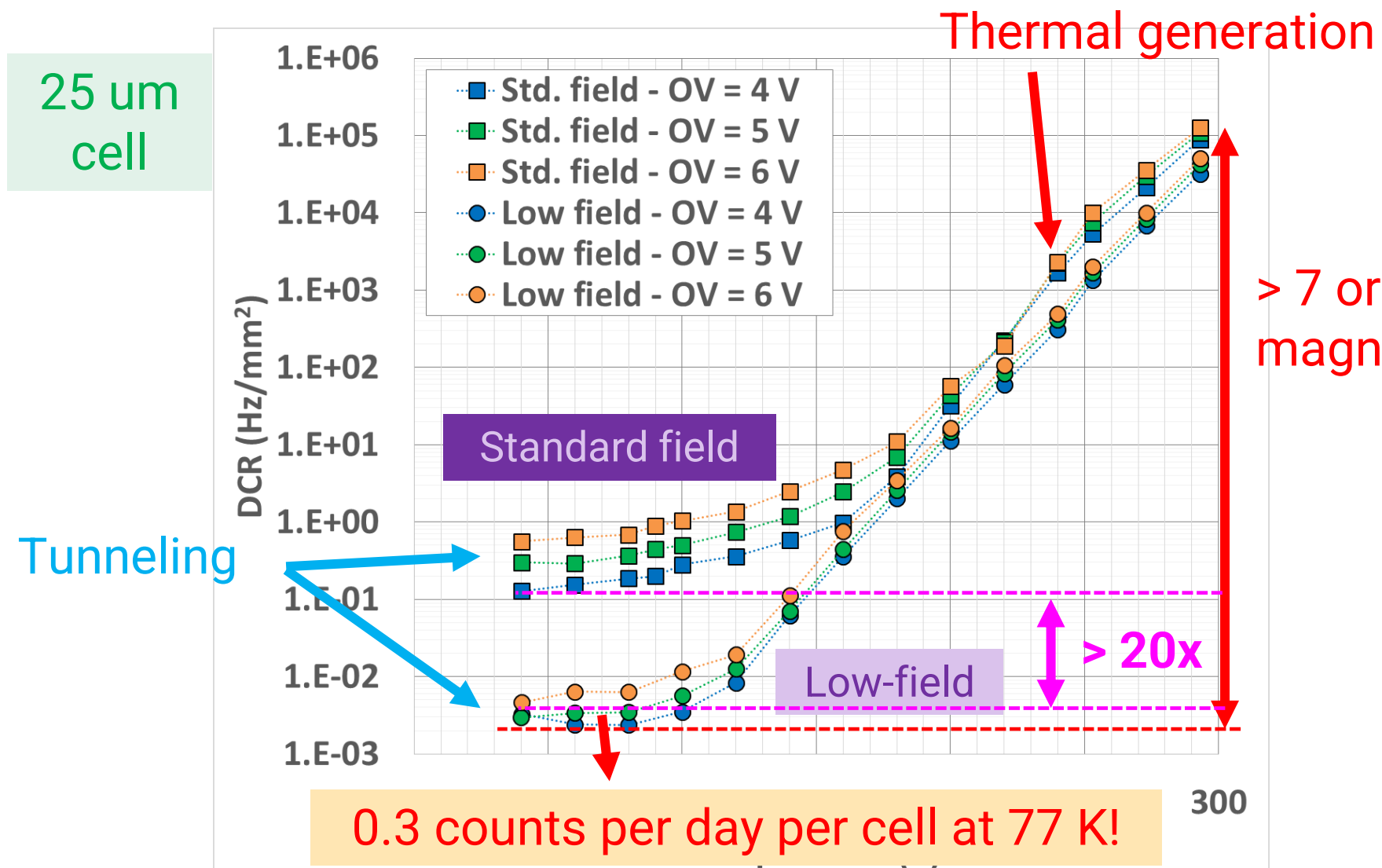
Cryogenic Time Projection Chambers



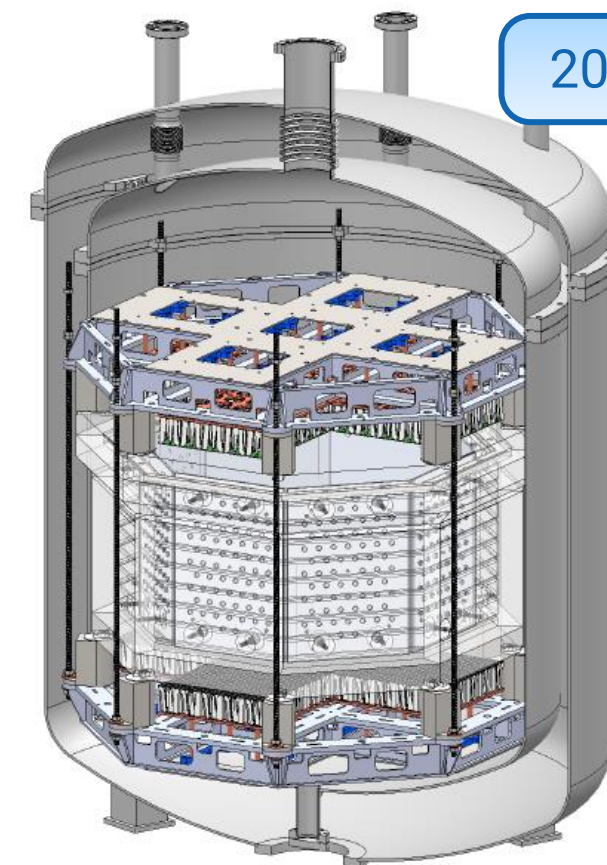
Cryogenic operation DarkSide-20k SiPMs



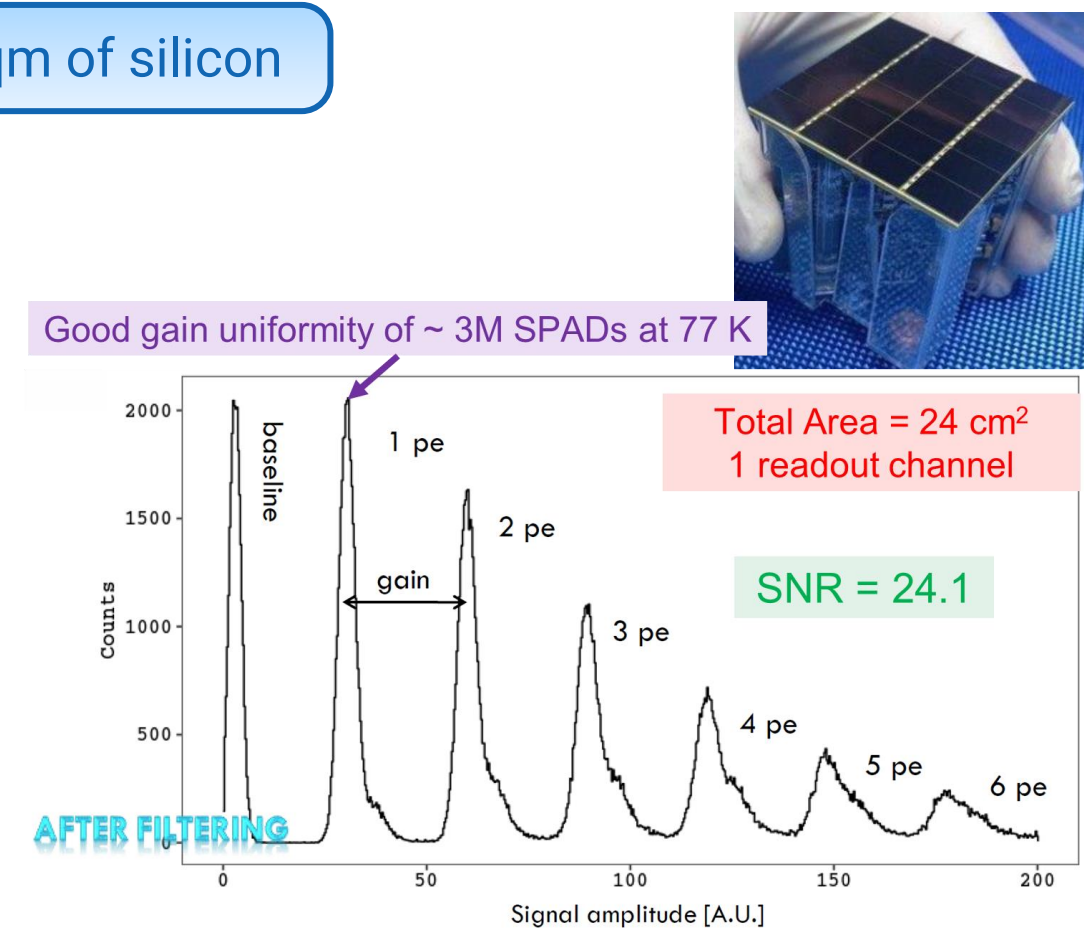
NUV-HD-Cryo SiPM technology is an *enabling technology for the DarkSide-20k* experiment, currently under construction.



> 7 orders of magnitude !



Darkside-20k experiment under construction at LNGS using FBK SiPMs fabricated at Lfoundry: 20 m^2 of SiPMs operated at 87 K.



Photon counting at 77 K with a single, 24 cm^2 SiPM Tile.

A $10 \times 10\text{ cm}^2$ SiPM array would have a total DCR < 100 cps!

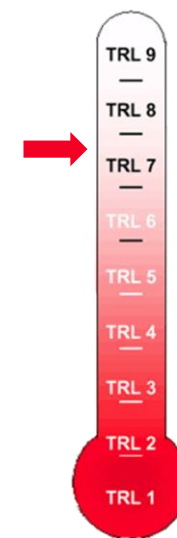
Reduction of Dark Count Rate at cryogenic temperature thanks to electric field engineering in FBK SiPMs.



Acerbi, Fabio, et al. "Cryogenic characterization of FBK HD near-UV sensitive SiPMs." *IEEE Transactions on Electron Devices* 64.2 (2017): 521-526.

Flagship Research Lines

DUNE mass production

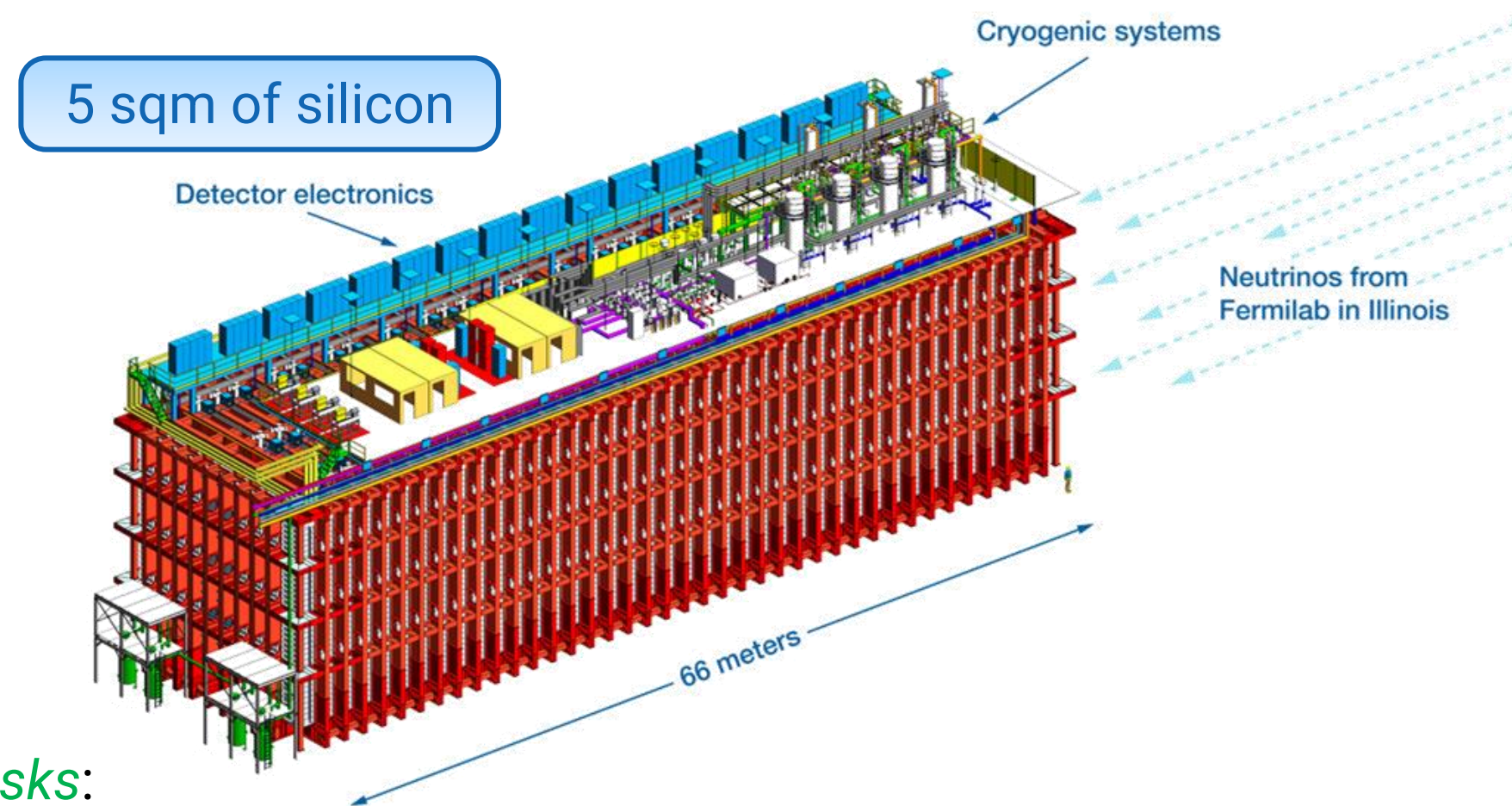


FBK will carry out approximately *half of the production for the DUNE horizontal drift detector*.

FBK will supply a *large volume of SiPMs in a package, capable of operating at cryogenic temperatures*

DUNE mass production @ FBK – Fact sheet

Technology	NUV-HD-Cryo – 54um triple trench
Silicon production	LFoundry
Silicon area	5 sqm
Number of channels	140k – 160k
Number of arrays	23k – 27k
Number of 8" wafers	290 – 330
Duration	2.5 years



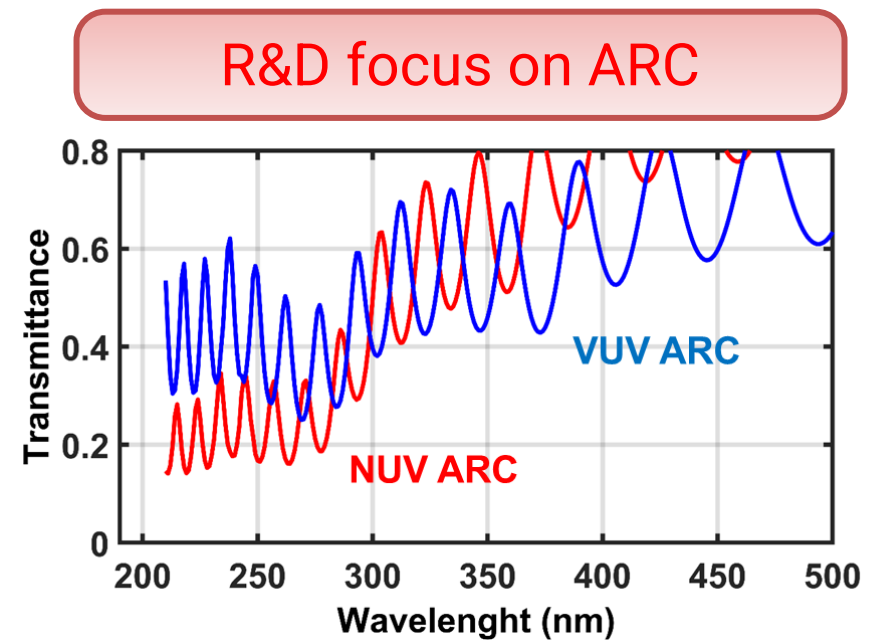
FBK tasks:

- Scientific coordination, Provide technical solutions, Project management, Subcontractor management, design, qualification, microfabrication steps, testing of wafers, of CSPs and of Arrays, cryogenic testing, QA, Warranty

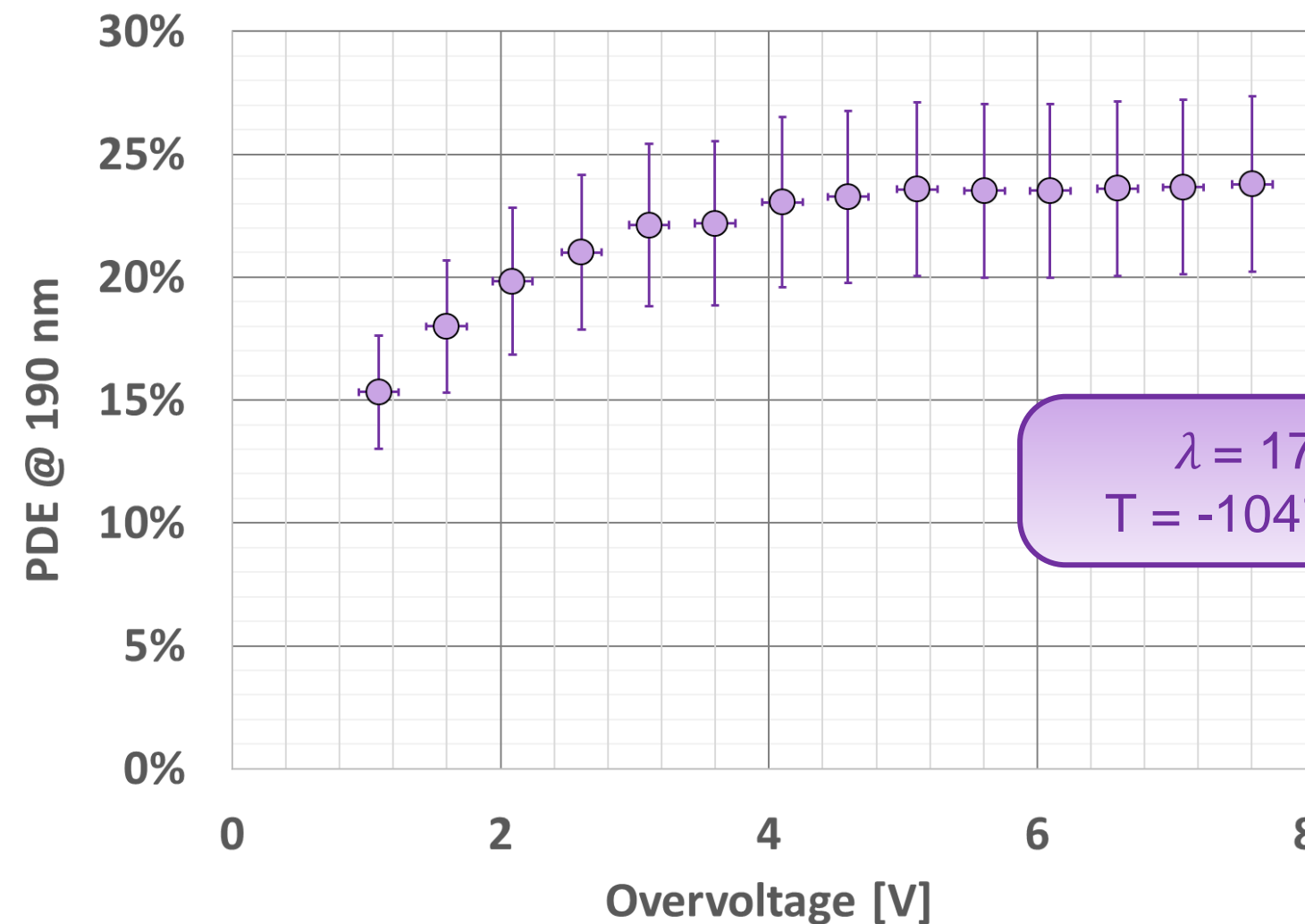


Extended sensitivity range VUV-sensitive SiPMs: VUV-HD

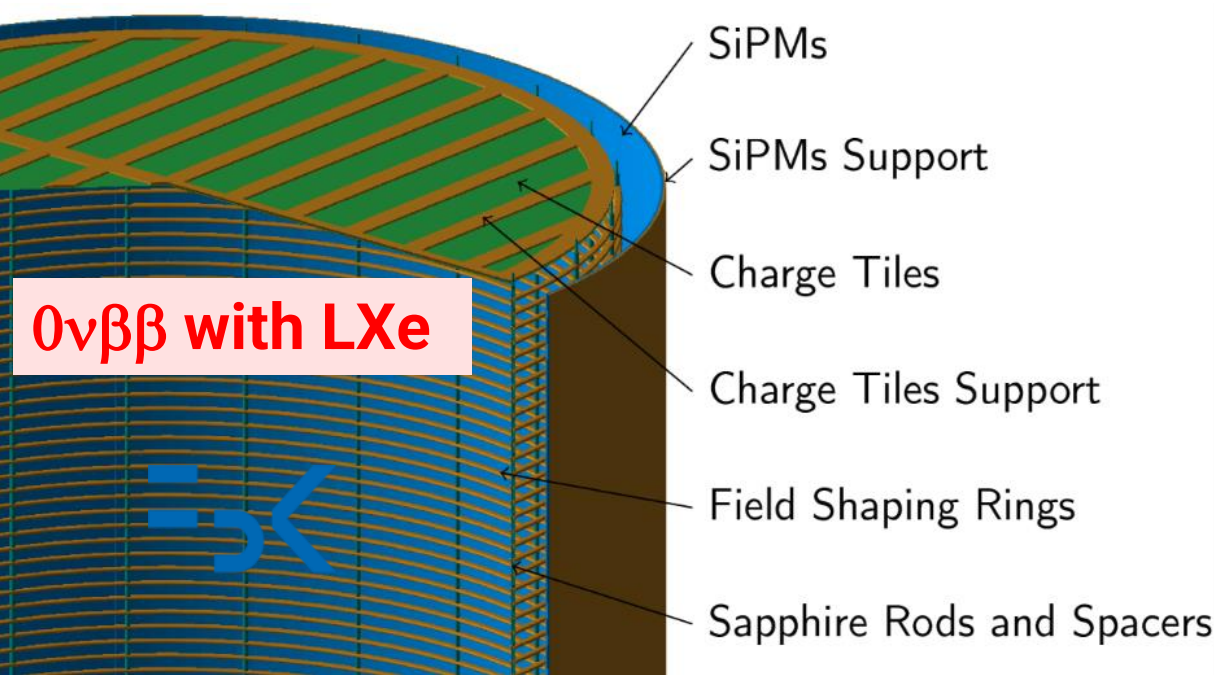
FBK has developed a *VUV-sensitive SiPM technology based on the NUV-HD*, for big physics experiments (nEXO @ Stanford - $0\nu\beta\beta$ with LXe).



R&D was focused on enhancing the transmission of the ARCs, by removing Si_3N_4 .

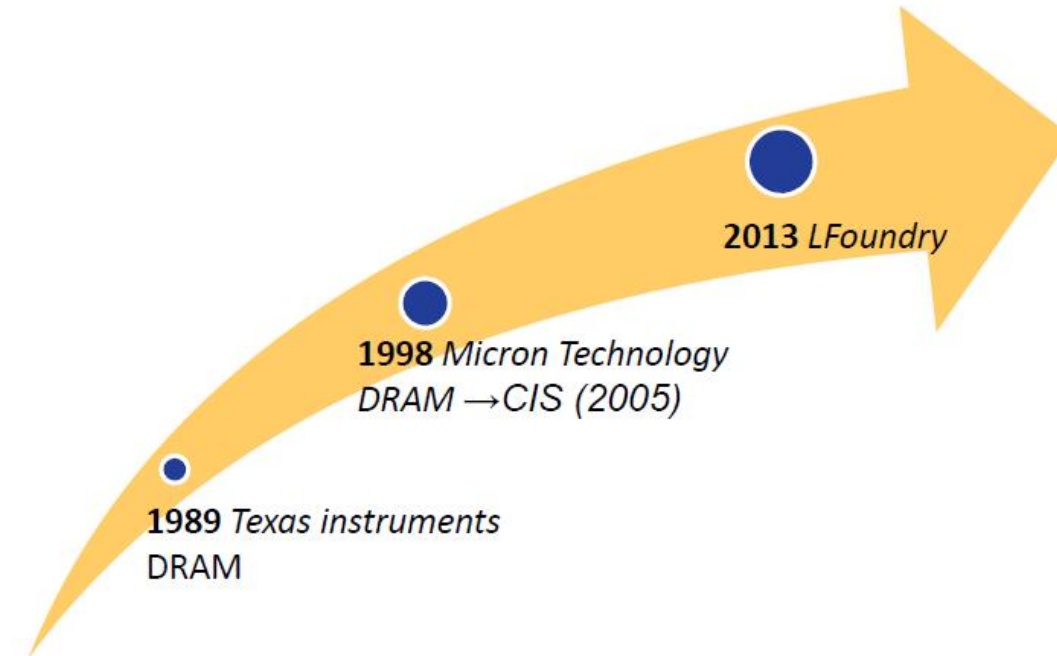
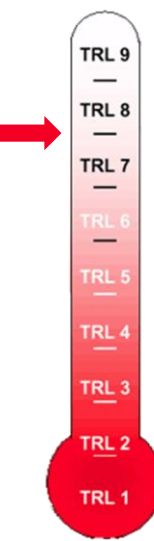


Gallina, G., et al. "Characterization of SiPM avalanche triggering probabilities." *IEEE Transactions on Electron Devices* 66.10 (2019): 4228-4234.



Ecosystem Technology Transfer

When the experiment / customer needs *very large production volumes* (> 5 sqm) and / or *special certification* (e.g. automotive) it makes sense to transfer FBK SiPM technologies to an external foundry.

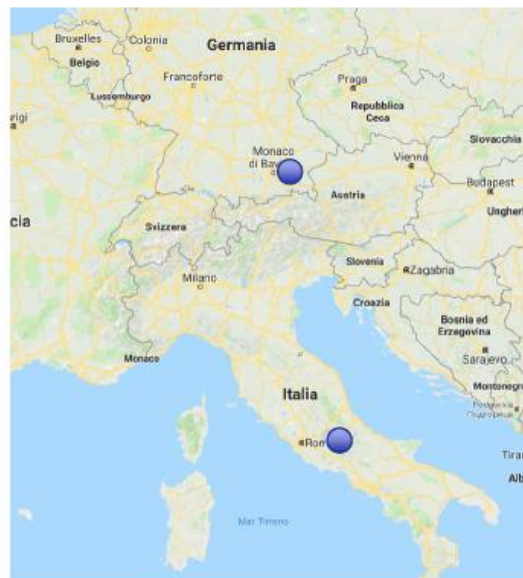


Success Stories:

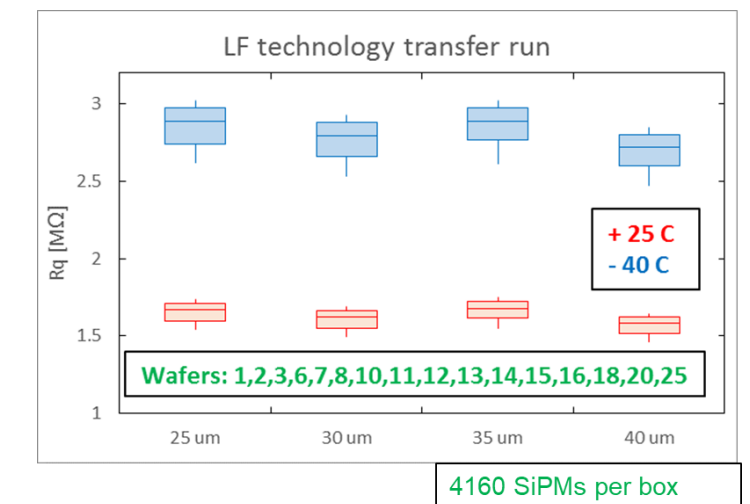
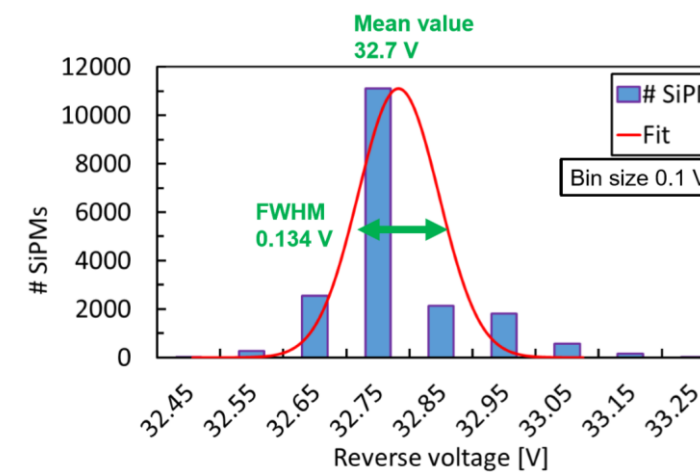
NUV-HD-Cryo successfully transferred for the production for DarkSide-20k and DUNE experiments.
 NUV-HD-RH currently being evaluated: first results are promising.

Private-public Partnership:

R&D on detectors, scientific management of project, scouting for new opportunities is carried out by FBK.
 Volume production is carried out by LF.
Careful management of the IPR and of licensing is needed.



- Open silicon foundry, based in Italy and Germany
- 200mm Fab located in Avezzano, (L'Aquila), Italy
- Capacity of 40.000 wafer/month
- Specialized in Optical Sensor Production:
 - CIS (since 2005)
 - Discrete PD (since 2014)
 - SiPM (since 2017)



Example of the results from technology transfer runs at LFoundry for DarkSide.





Cryogenic Time Projection Chambers



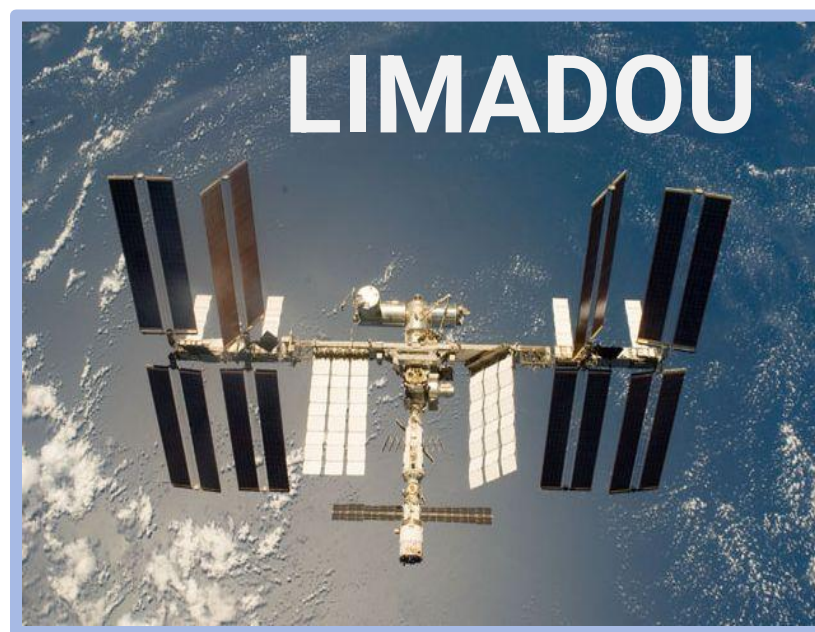
Radiation Hardness Motivation for R&D

Improving radiation hardness of SiPMs is *one of the next frontiers of development at FBK* for very important applications, both in big science experiments and in space.

Detectors for collider experiments: from 10^{10} neq/cm² to $>10^{14}$ neq/cm²



Geostationary orbit space experiments: $\sim 5 \cdot 10^{10}$ neq/cm²



What is the definition of radiation hardness for SiPMs?

R&D approach:

- *Qualification* of radiation tolerance of current SiPM technologies.
- Development of a *highly customized SiPM technology* for optimal performance after irradiation is likely needed.

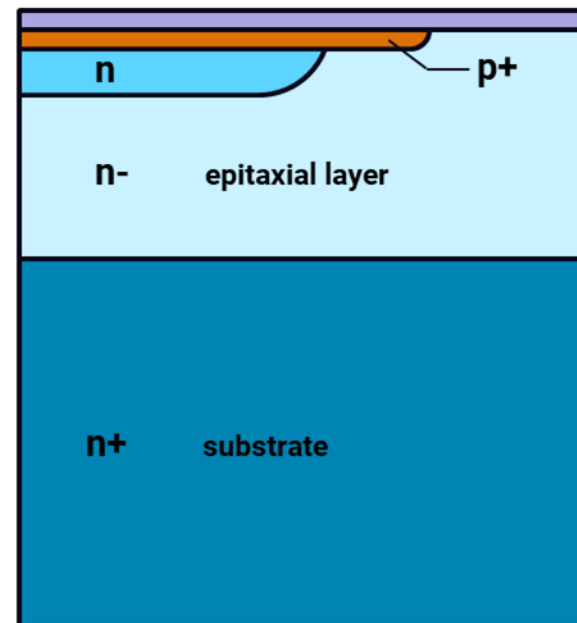
Test Beam 1 – Trento Proton Therapy

Tested Technologies

We tested a relatively *wide range of different customized SiPM technologies*, fabricated in FBK internal R&D clean-room, looking for differences, general trends, etc..

VUV-HD^[2]

Vacuum Ultraviolet



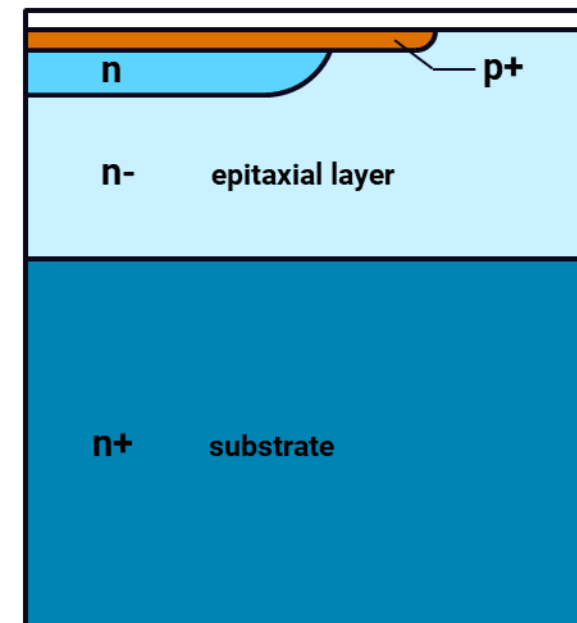
Peak PDE = 420 nm

- Different ARC
- High sensitivity in VUV

[2] Capasso (2020)
<https://doi.org/10.1016/j.nima.2020.164478>

NUV-HD^[3]

Near Ultraviolet



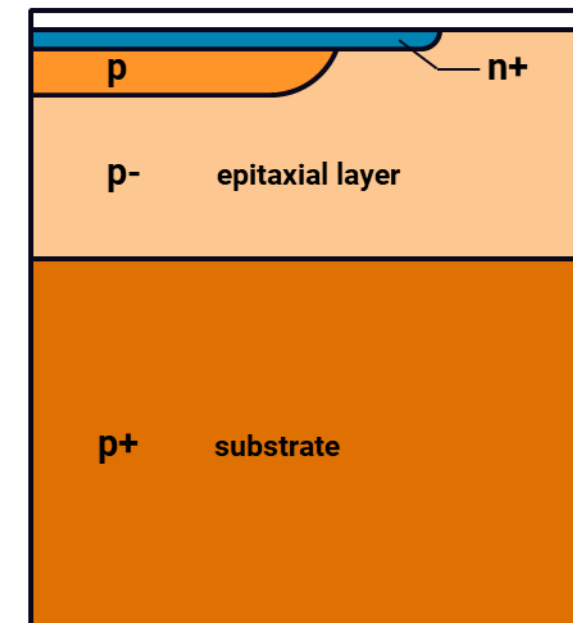
Peak PDE = 420 nm

- CRYO = Cryo temp opt.
- RH = High radiation opt.

[3] Gola (2019)
<https://doi.org/10.3390/s19020308>

RGB-HD^[4]

Visible

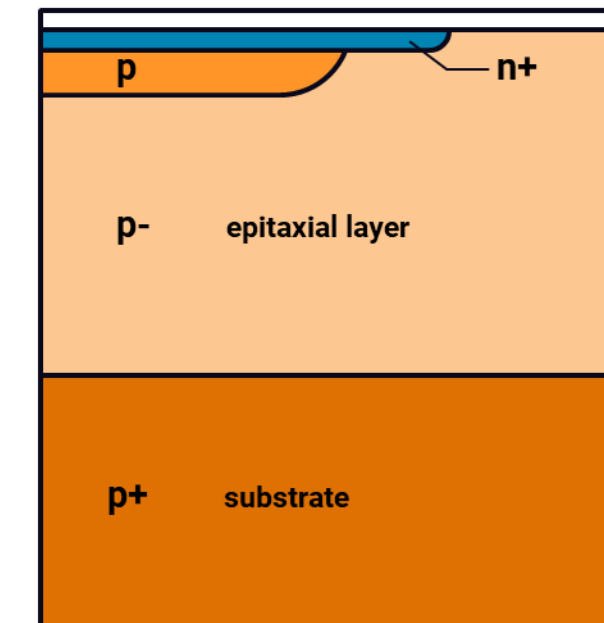


Peak PDE = 530 nm

[4] Ferri (2015)
<https://doi.org/10.1186/2197-7364-2-S1-A86>

NIR-HD^[5]

Near Infrared



Peak PDE = 530 nm

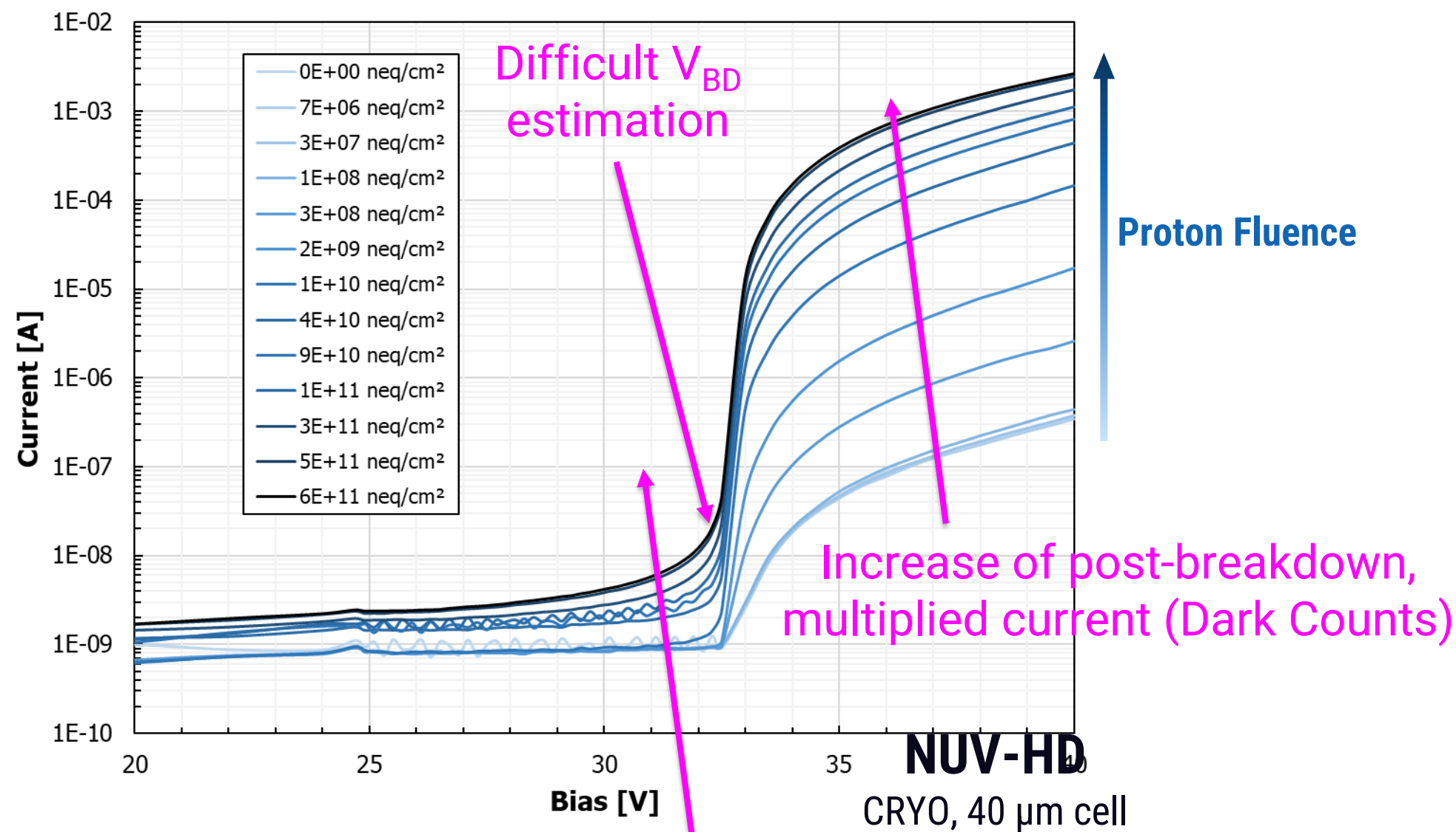
- Thick epitaxial layer
- High sensitivity in IR

[5] Acerbi (2018)
<https://doi.org/10.1016/j.nima.2017.11.098>

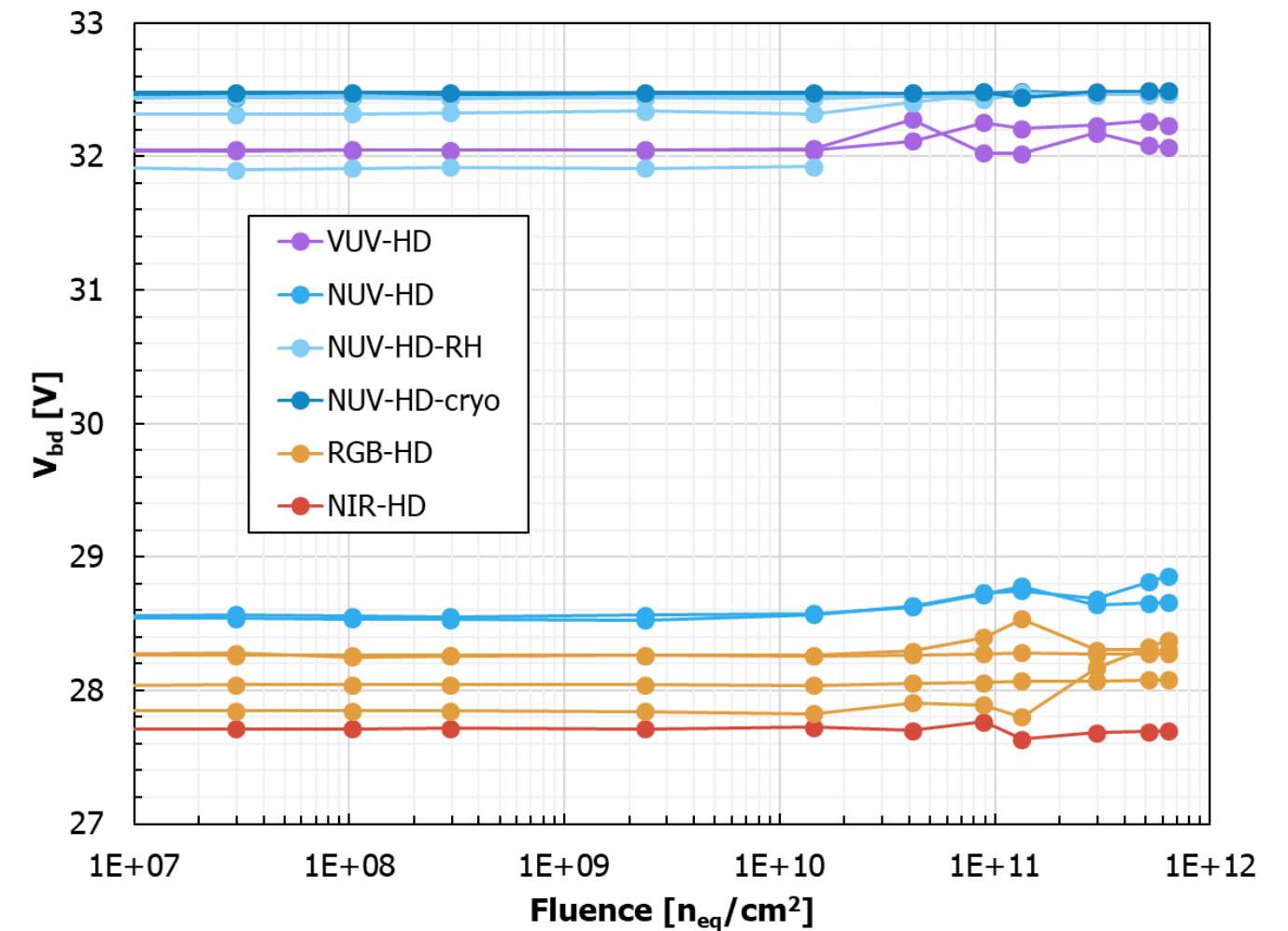
Test Beam 1 – Trento Proton Therapy

Online IV measurements

Effects of irradiation on reverse IVs



Breakdown Voltage Estimation

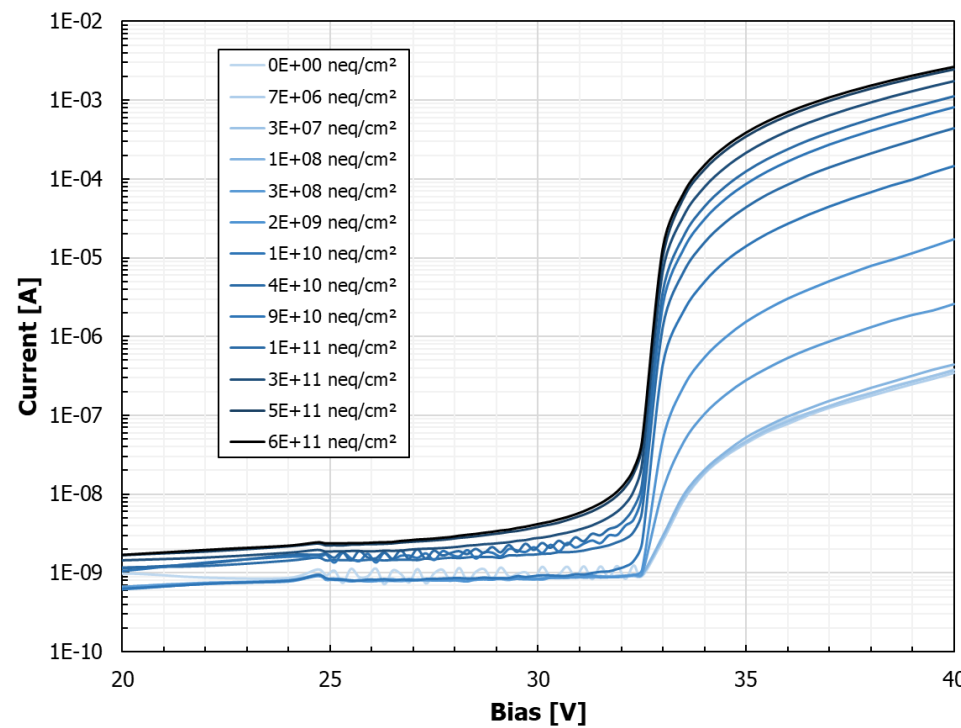


No change observed in V_{BD} up to fluence $6 \cdot 10^{11}$ n_{eq}/cm^2 (2nd derivative method, faint illumination)

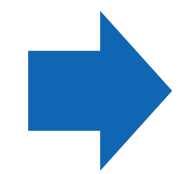
Test Beam 1 – Trento Proton Therapy

Dark Count Rate Estimation from reverse IV

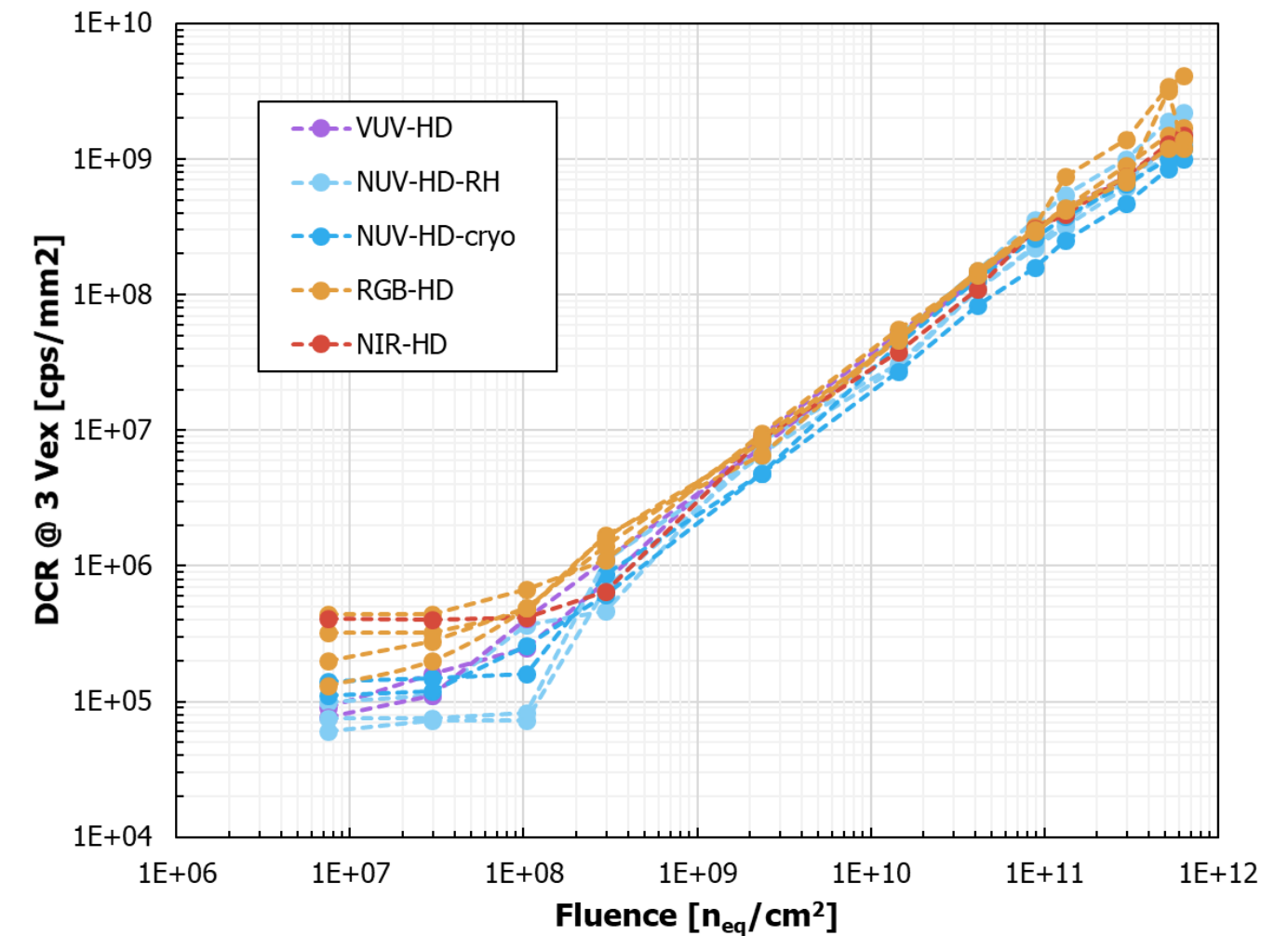
Comparison of radiation hardness of different SiPM technologies *cannot be done directly from their IVs* because they usually have different Gain and correlated noise (ECF).



$$DCR = \frac{I_{dark}}{q * G * ECF} = \frac{I_{dark}}{q * G_C}$$



$G_C = G * ECF = \text{Current Gain}$
 $ECF = \text{Excess Charge Factor}$



Assumption: ECF and Gain do not change with irradiation (will be shown later)

DCR estimation for different FBK SiPM technologies.



Test Beam 1 – Trento Proton Therapy

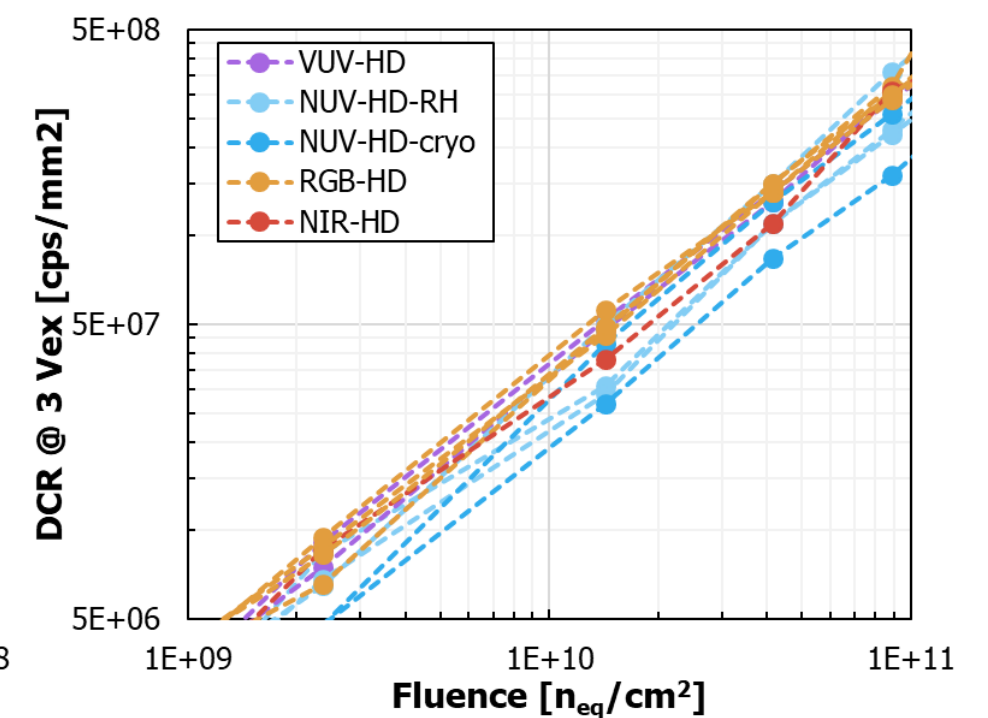
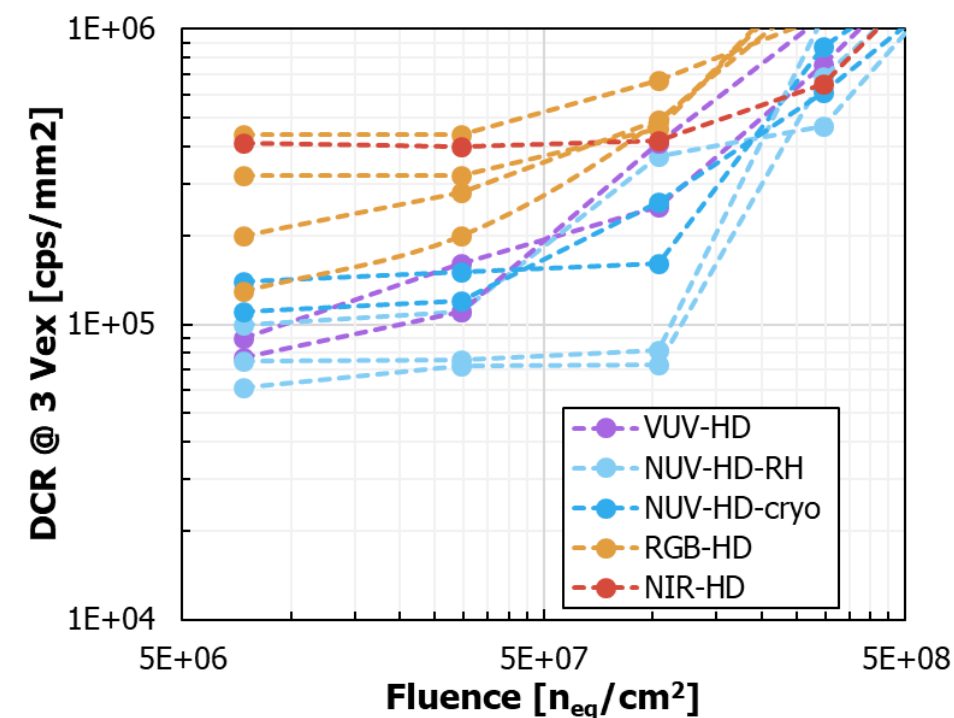
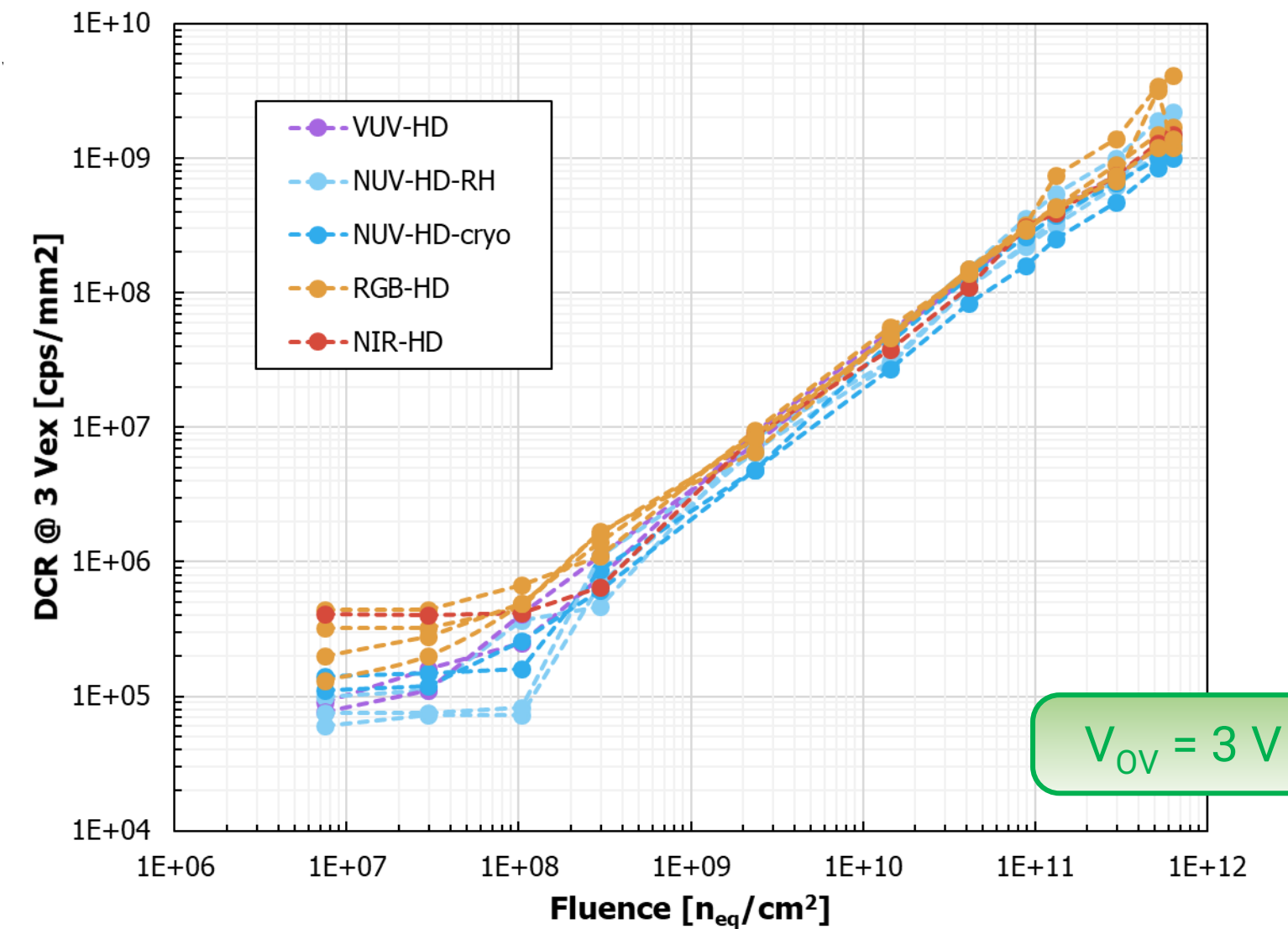
Dark Count Rate vs. Fluence

There is *little correlation between the DCR before and after irradiation*:

- All technologies seem to “converge” towards similar values
- Knee between $10^7 \div 10^8$ n_{eq}/cm^2
- Independence of bulk damage from contaminants in the SiPM starting material?

DCR variation after irradiation is reduced:

- from ~ 1 OoM to $< \sim 0.5$ OoM
- Still worth investigating *differences between technologies*

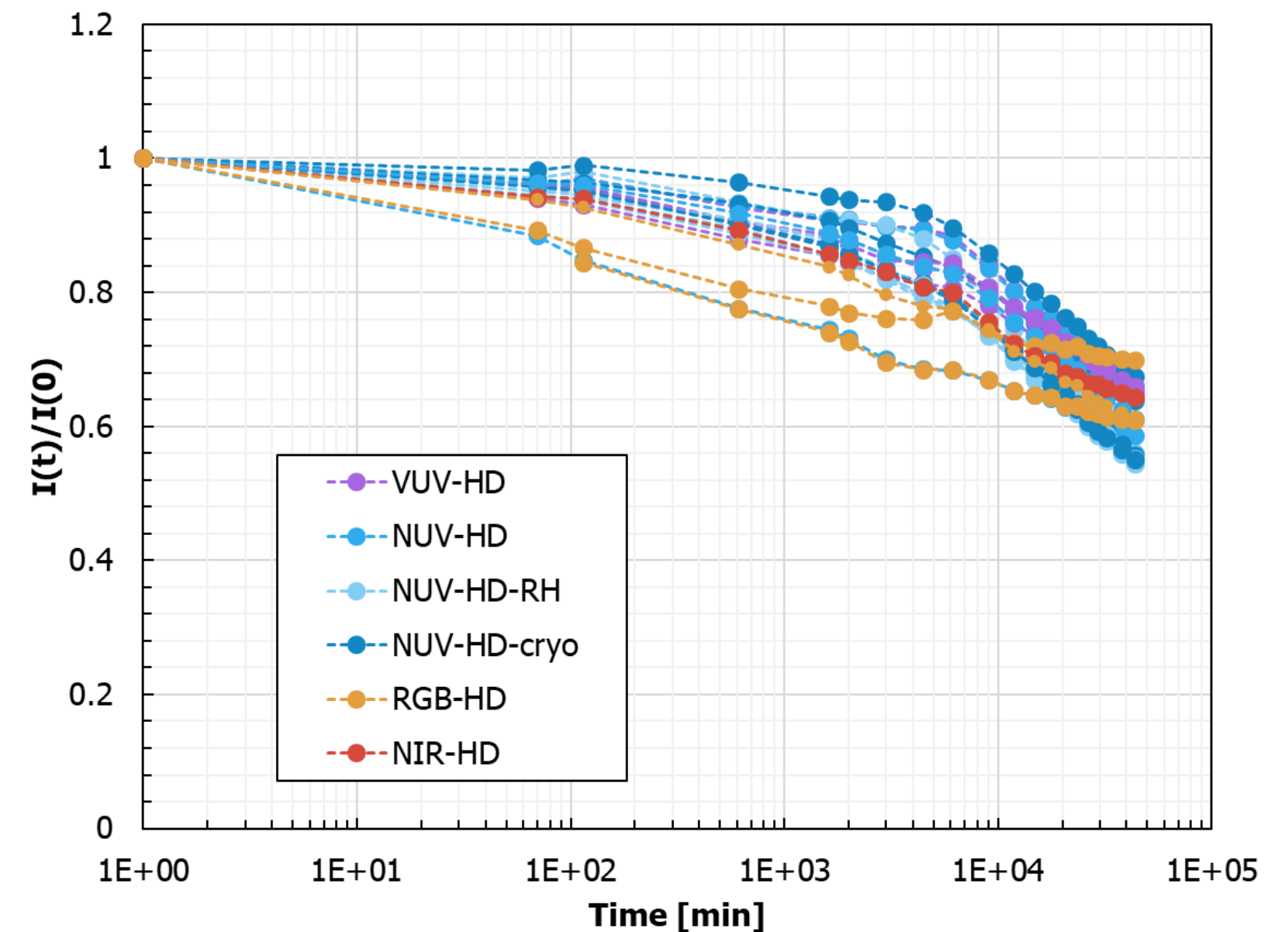


Test Beam 1 – Trento Proton Therapy

First Annealing studies

Annealing can be a *powerful means of reducing DCR after irradiation* to recovers single-photon resolution.

- *Room temperature* annealing (20-25°C) on the highest dose only ($6.4 \cdot 10^{11}$ 1 MeV n_{eq}/cm^2)
- *Two slopes observed*: knee point at around $1.5 \cdot 10^3$ min (~ 1 day)
- Minor dependence on excess bias for a few samples.
- *Higher annealing temperatures* have demonstrated better annealing:
 - *Factor > 10 after $1 \cdot 10^{11} n_{eq}/cm^2$ is reported in M. Calvi - <https://doi.org/10.1016/j.nima.2019.01.013>*
 - *Is there a threshold temperature* for the annealing of certain defects?



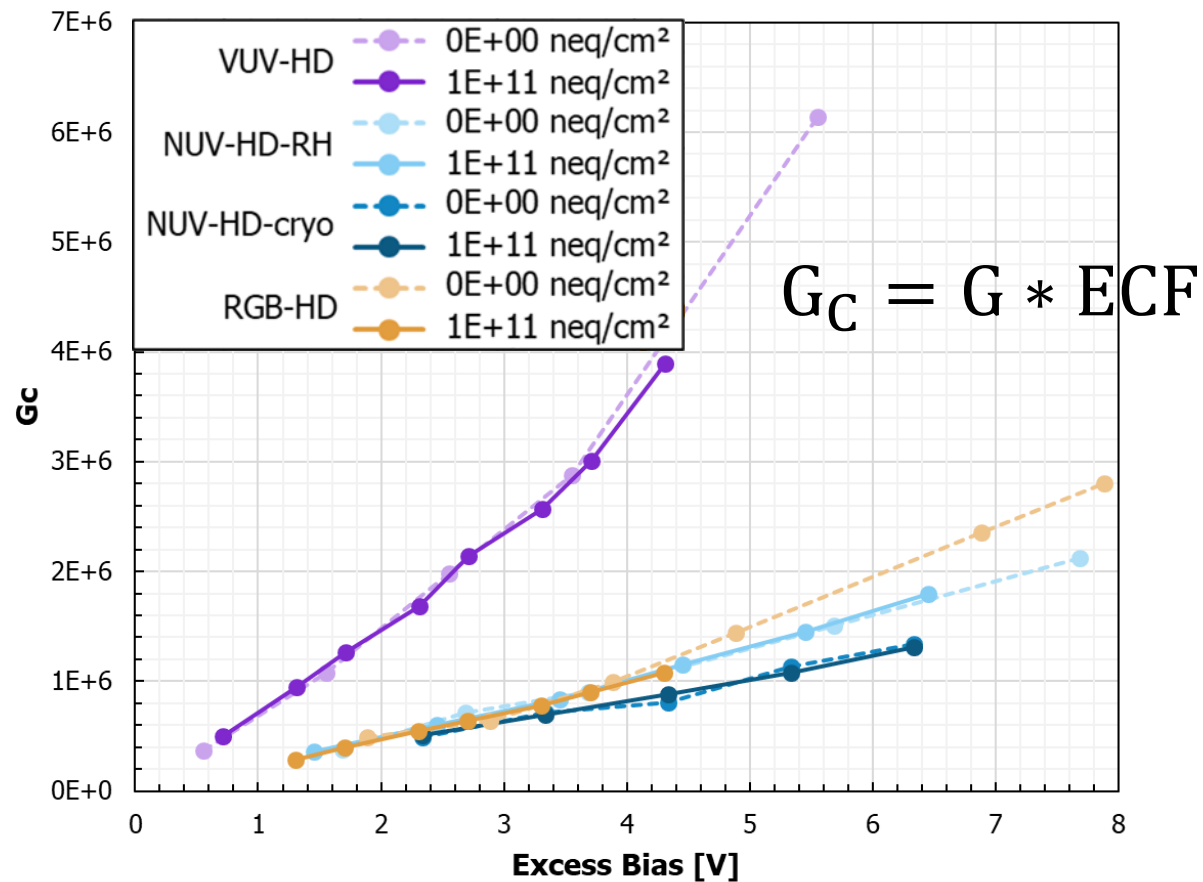
Test Beam 1 – Trento Proton Therapy

Variation of the other SiPM parameters

Waveform analysis carried out at -40°C to reduce pile-up on the highest irradiation dose ($1 \cdot 10^{11}$ 1 MeV n_{eq}/cm^2).

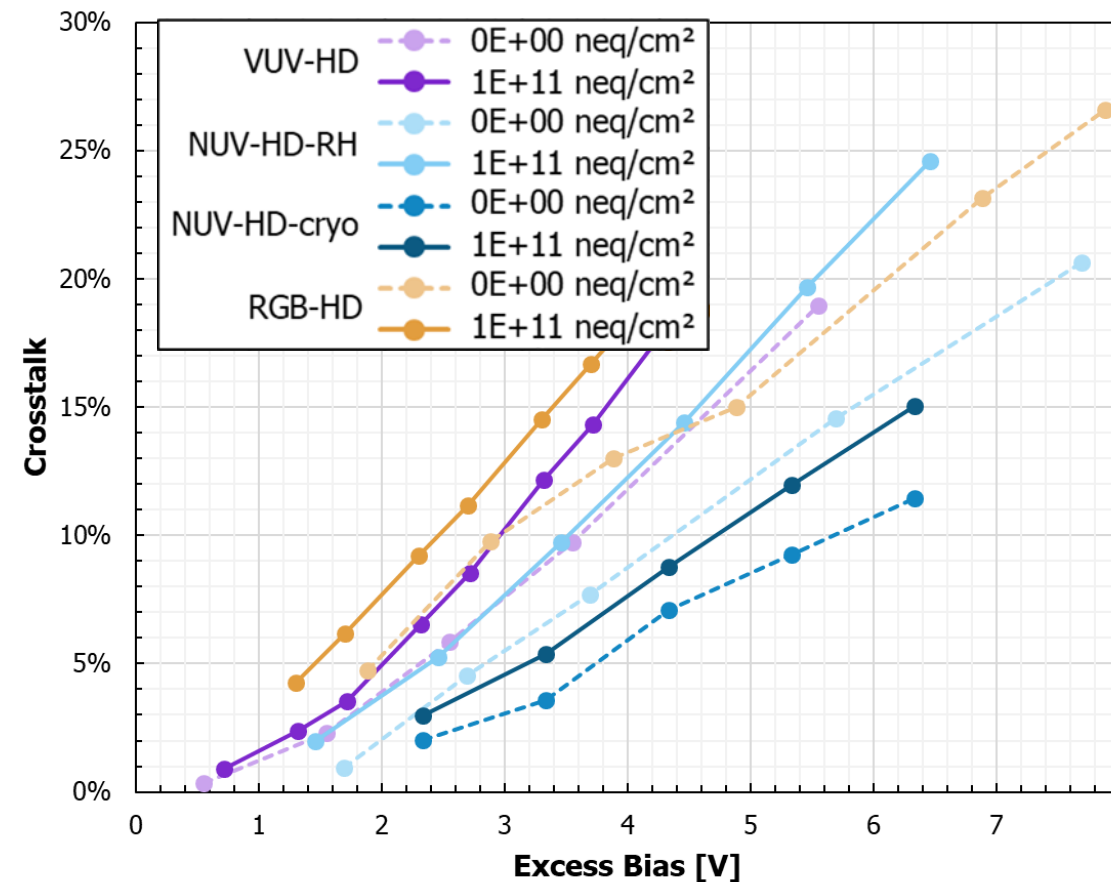
No relevant change of the other SiPM parameters, except for the DCR.

Current Gain



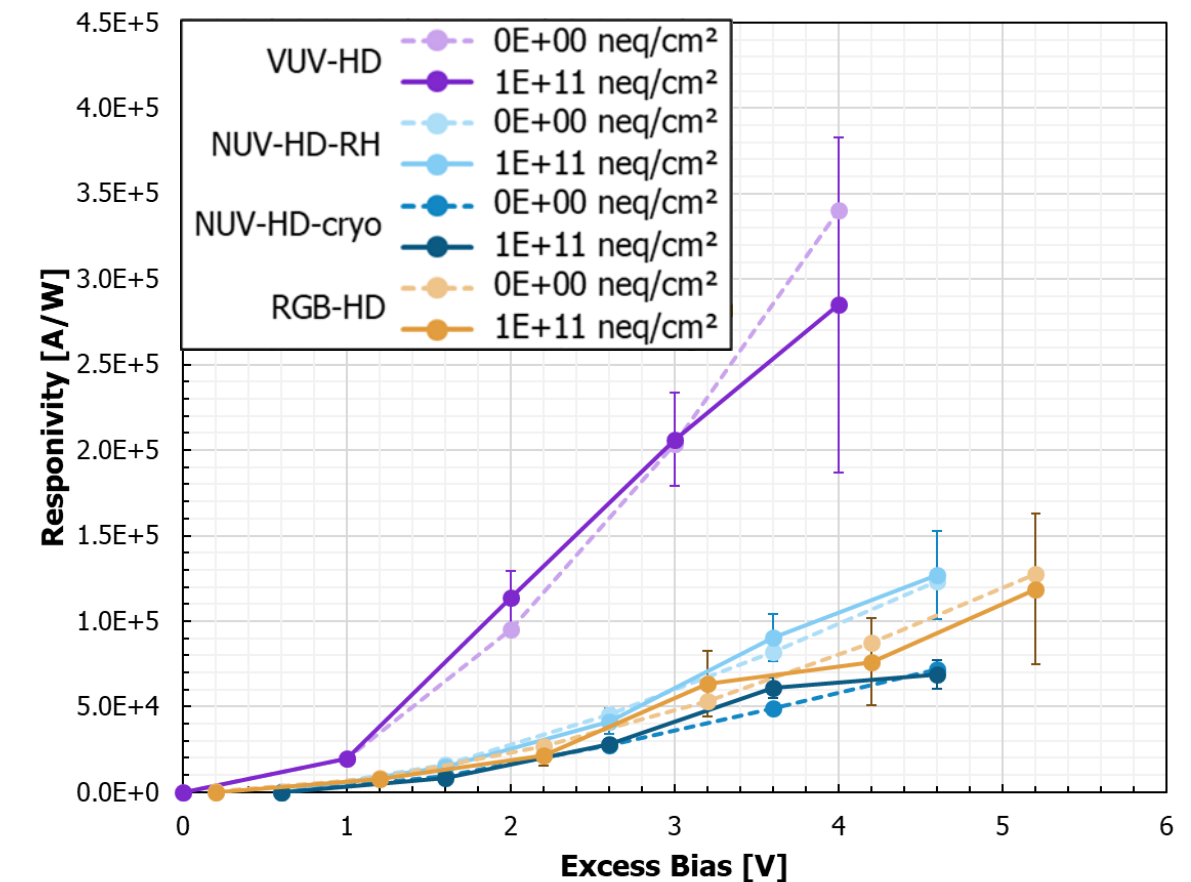
*No change in Gain * ECF* up to $1 \cdot 10^{11}$ n_{eq}/cm^2

Optical Crosstalk



Minor increase of CT is most likely an artifact caused by pile-up.

PDE



No change in PDE, measured as responsivity (loss of single photon resolution).

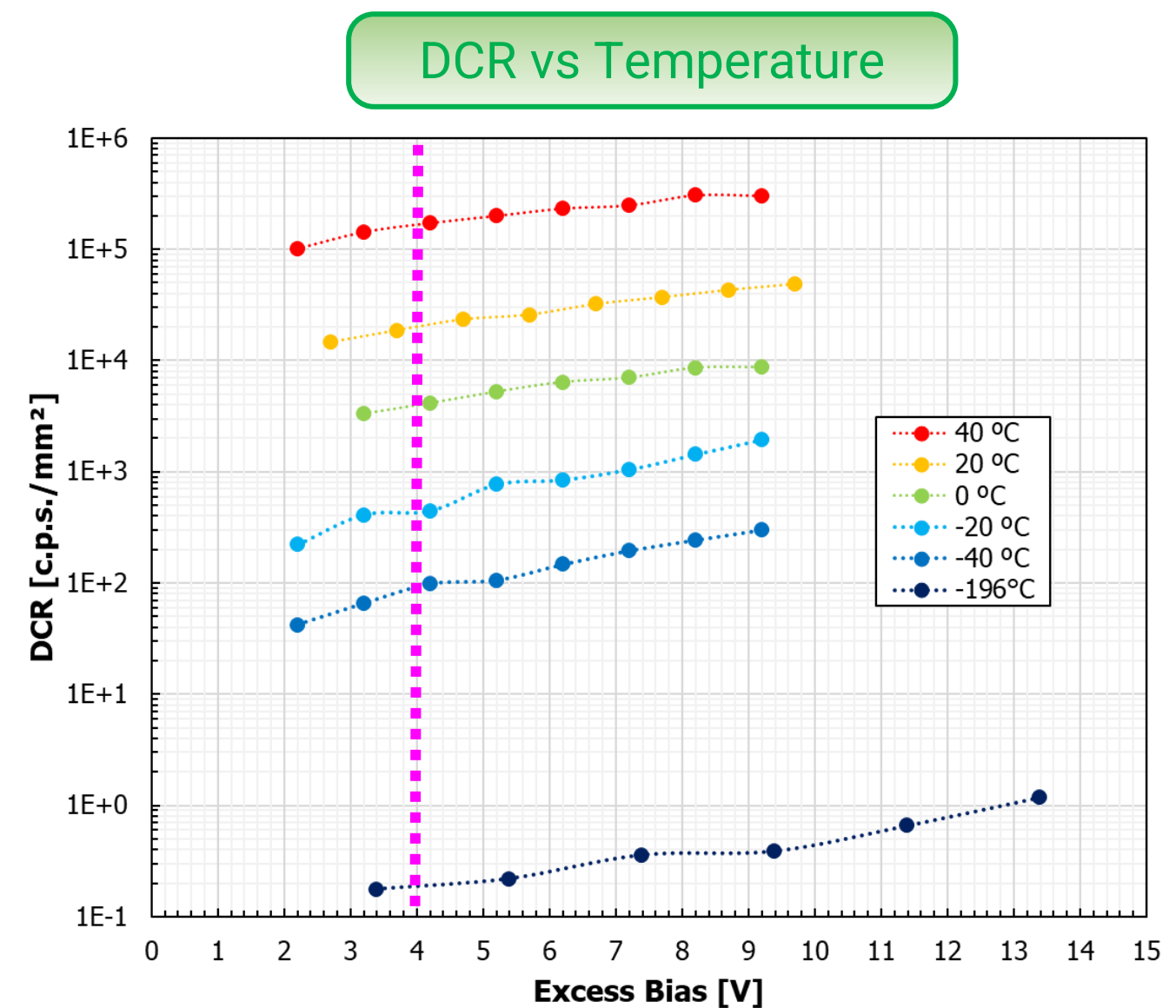
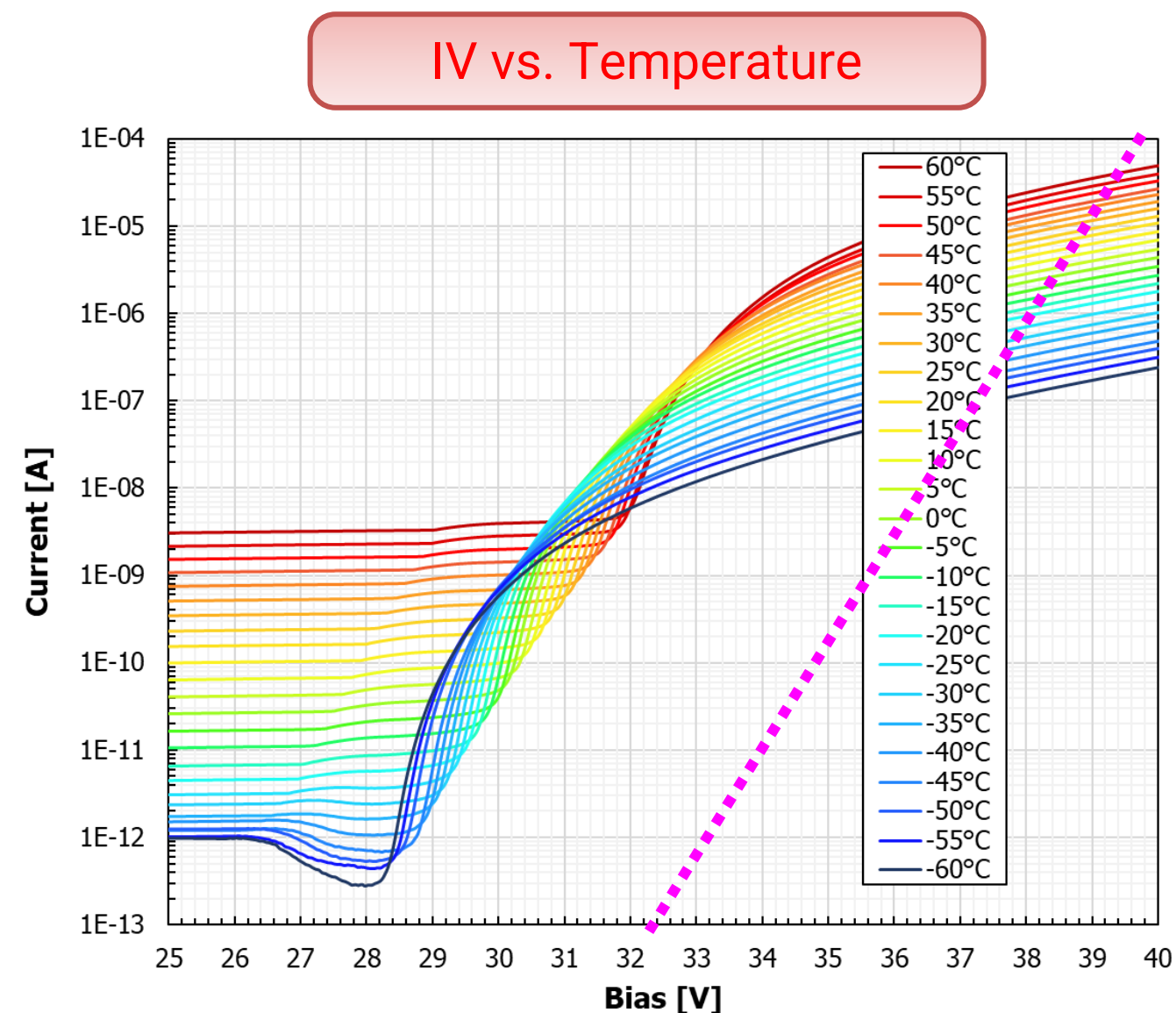
Test Beam 2 – LNS Catania

DCR Analysis



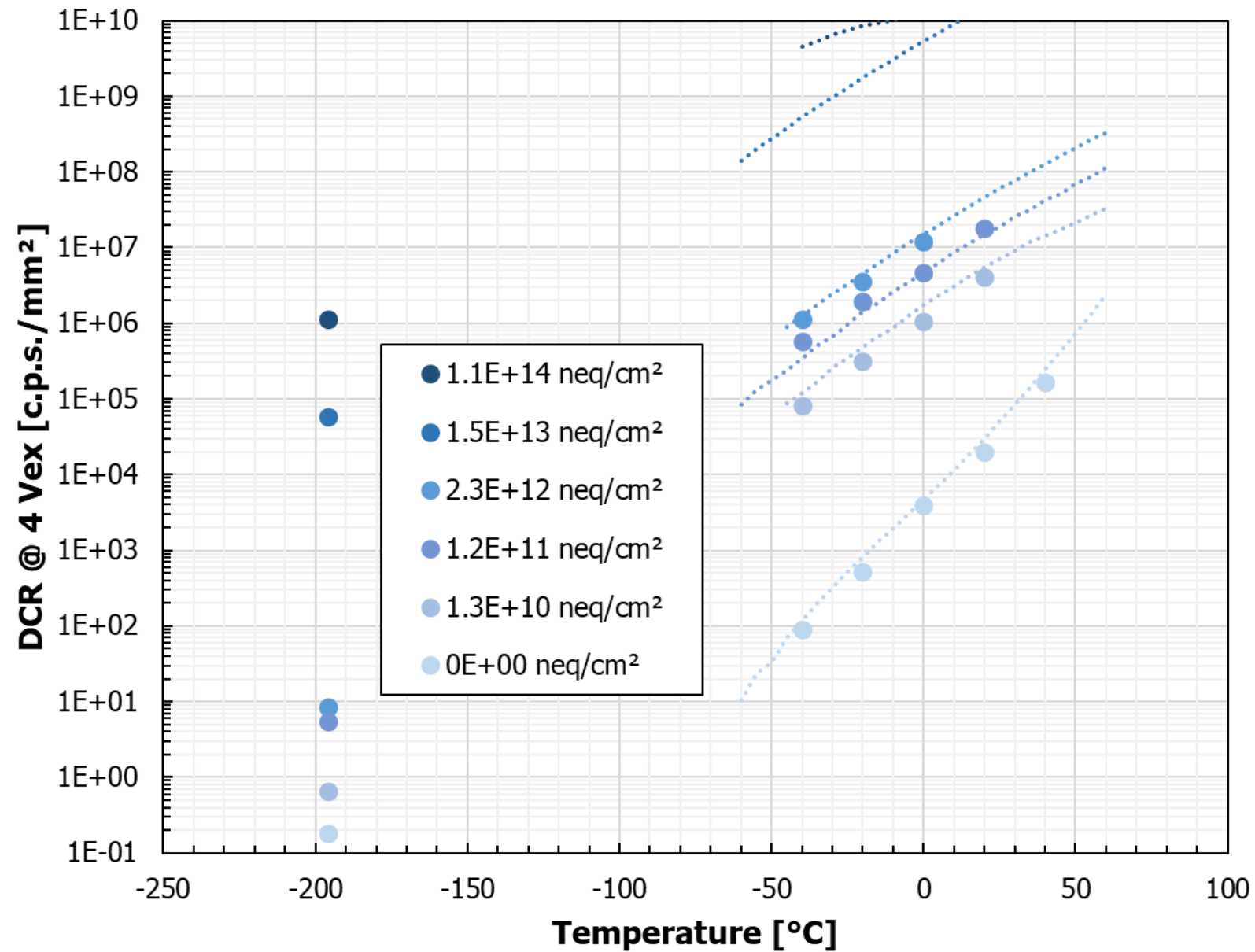
Study of *DCR after irradiation extended to cryogenic temperatures (preliminary)*.

- *IV vs Temperature*: +60°C → -60°C
- *DCR vs Temperature*: +40°C → -40°C, LN₂ (waveform analysis, when possible)



Test Beam 2 – LNS Catania

DCR vs. Temperature and Dose

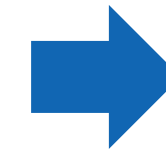


Lines: DCR from IV

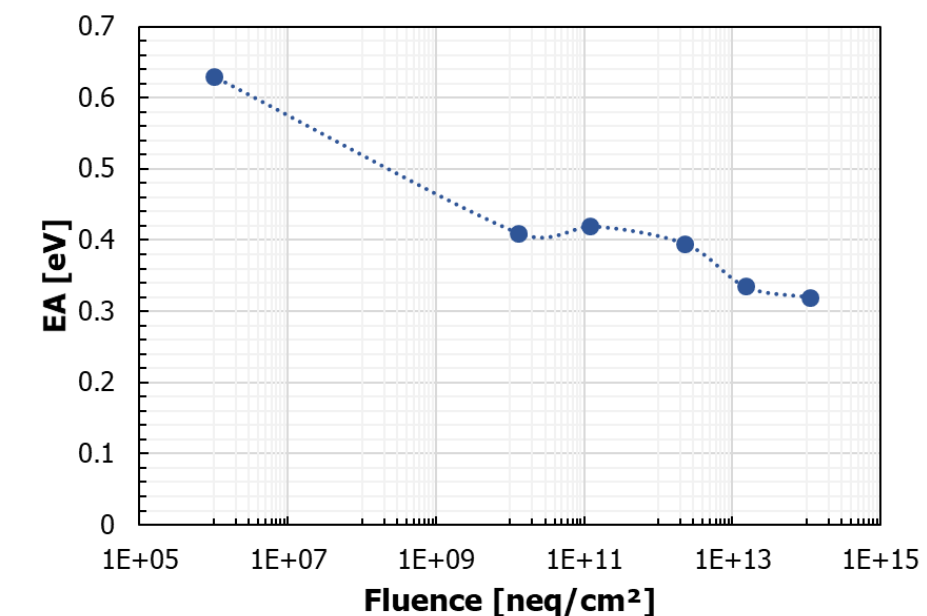
Dots: DCR from waveform analysis

Reduction of DCR activation energy near room temperature after irradiation was observed.

→ Cooling becomes less effective in reducing DCR.

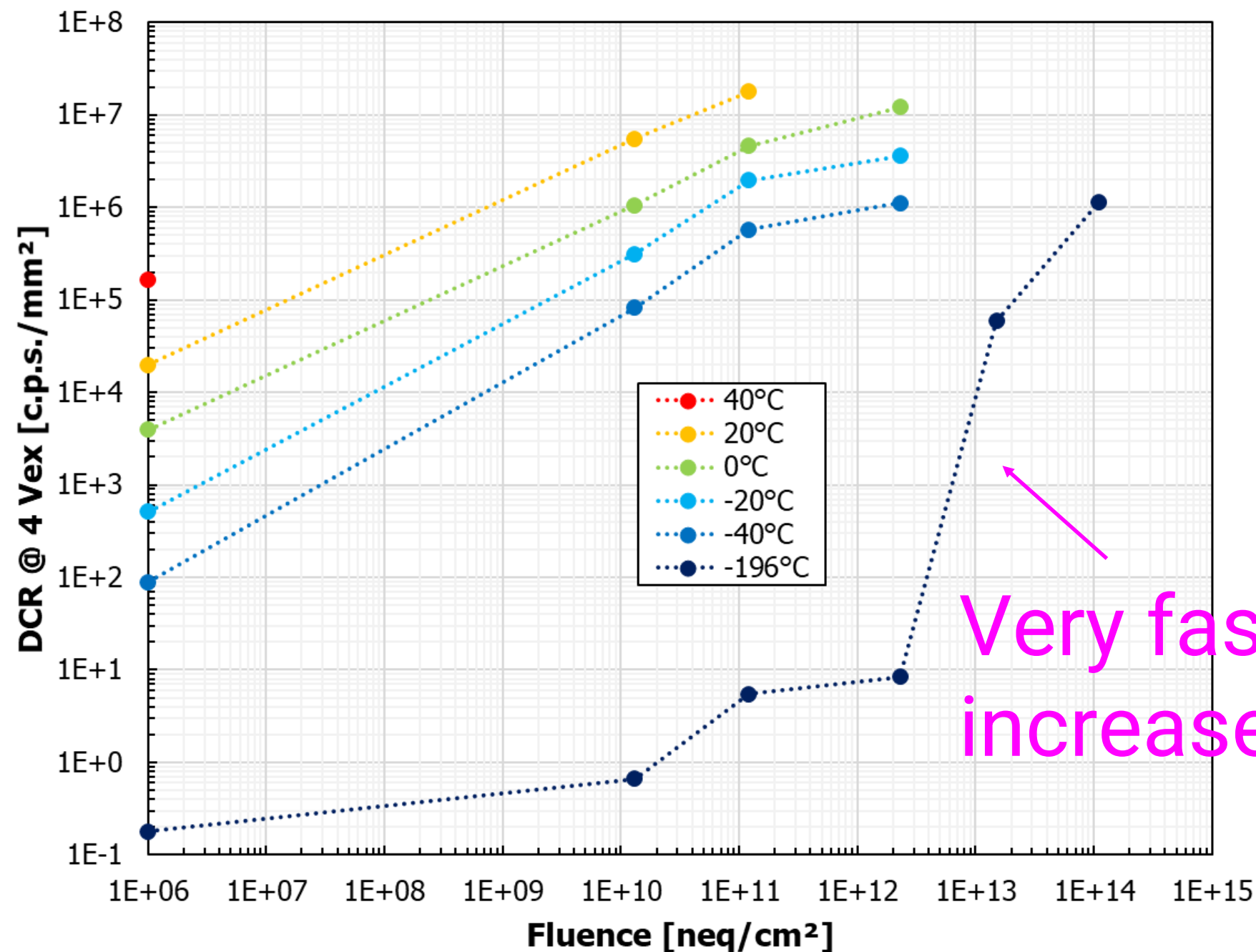


Fluence [n _{eq} /cm ²]	E _A [eV]
0E+00	0.63
1.3E+10	0.41
1.2E+11	0.42
2.3E+12	0.40
1.5E+13	0.34
1.1E+14	0.32



Test Beam 2 – LNS Catania

DCR at LN after irradiation



- Cooling is *extremely effective in reducing DCR after irradiation up to $\sim 1 \cdot 10^{12} n_{eq}/cm^2$*
- Further investigations needed to understand what happens at the higher doses
- Worth checking different / new SiPM structures
- Check possible effect of annealing

Radiation Hardness

Definition + Mitigation strategies

It is rather obvious that *we cannot prevent the bulk damage from increasing the DCR* of the SiPM.

A *possible definition of Rad-Hardened / tolerant SiPM* is a *SiPM that retains its target performance in a given application* even after radiation damage.

- Depends on the application!
- *Radiation damage mitigation strategies* (+ annealing)

Use of small cells + Engineering of electric field

Issue / Hypothesis	Technical Solution	Mitigation
Increase of primary DCR	Electric field engineering	Better DCR temperature coefficient High PDE at lower bias (to reduce field-enhanced effects)
PDE loss due to cells busy triggering dark counts.	Smaller Cells	More cells and faster recharge: lower PDE loss.
Increased power consumption due to higher DCR.	Smaller Cells	Lower gain: less current (for a given DCR).

Important for very high fluences!

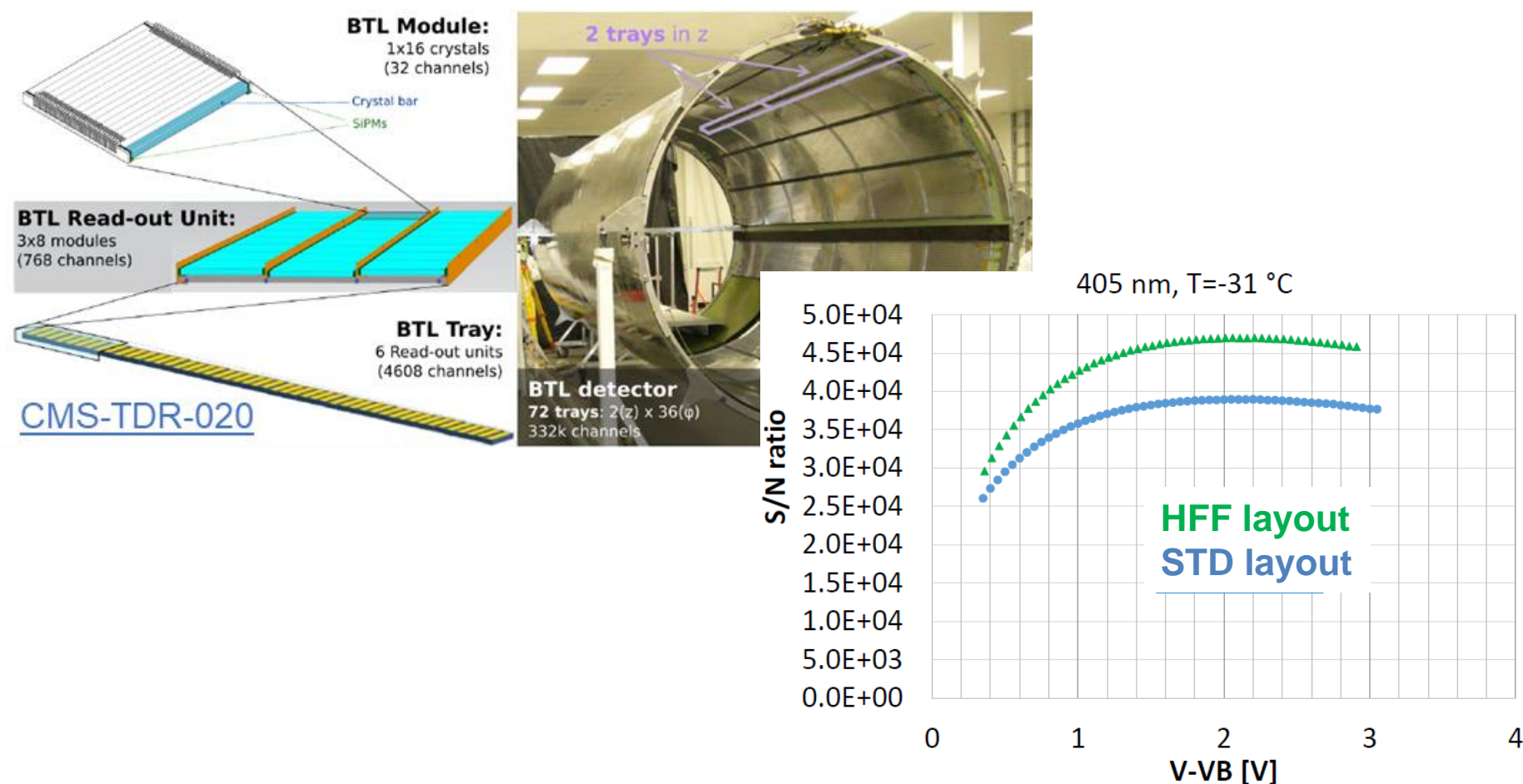
.. But, at the same time, we need high PDE!

Mitigation of Radiation Damage

NUV-HD-RH SiPMs for CMS-BTL

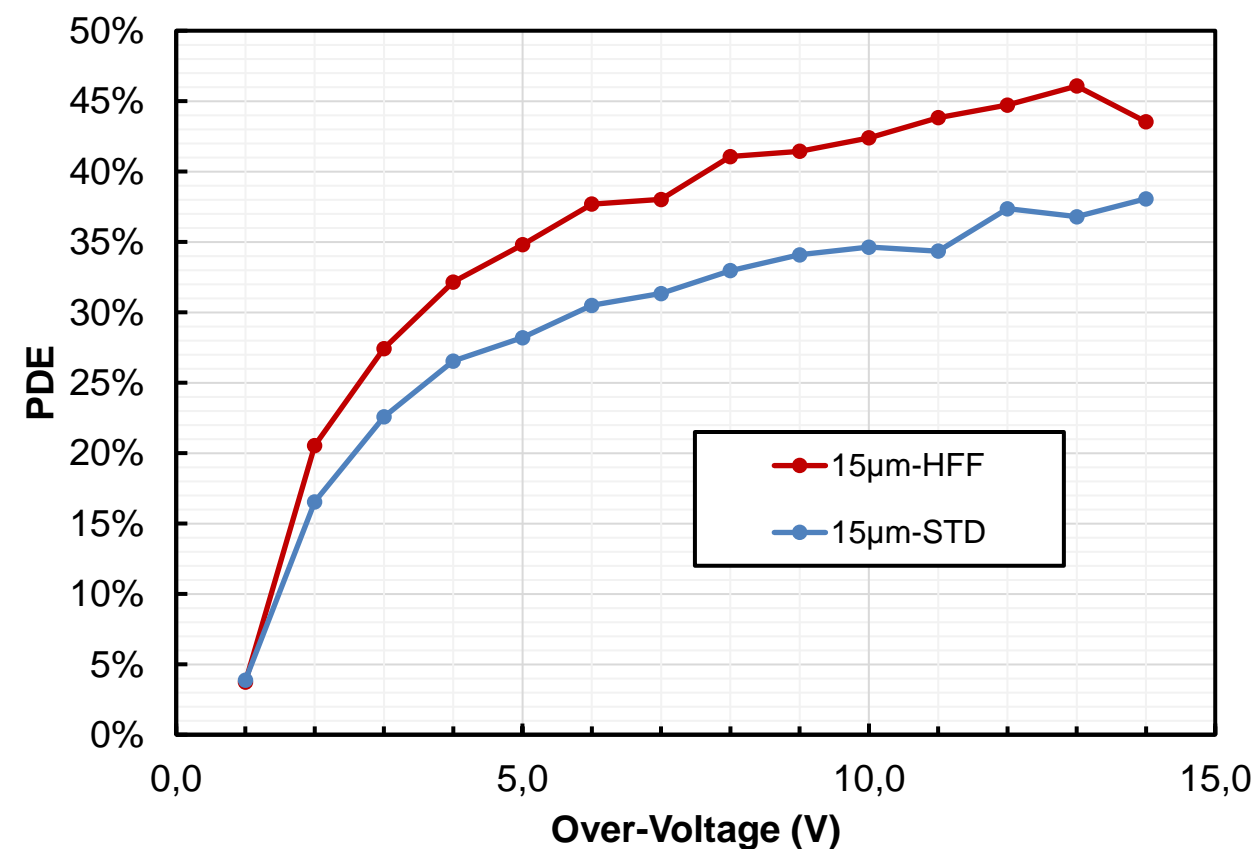
SiPMs with extreme radiation tolerance are required for the Barrel Timing Layer of the CMS experiment, at CERN: 1.9×10^{14} 1 MeV n_{eq}/cm^2 .

Custom SiPM technology was developed, combining *electric field engineering with small-pitch SiPM technology*, for enhanced radiation hardness.



FoM measured by from CMS collaboration:
A. Heering, Y. Musienko, M. Lucchini et al.)

NUV-HD-RH SiPMs



The advantage of using small cells for radiation hardness is relevant *only if they can still provide very high PDE*



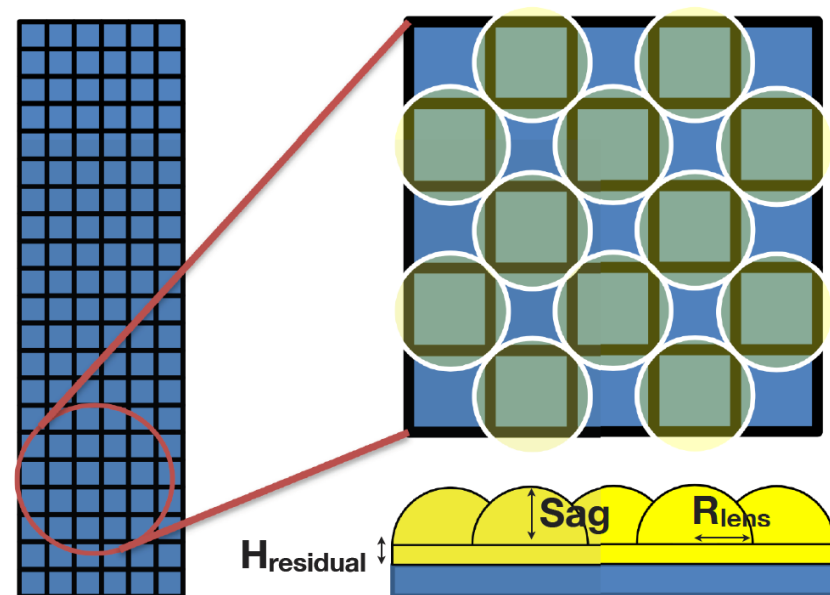
Light Concentration



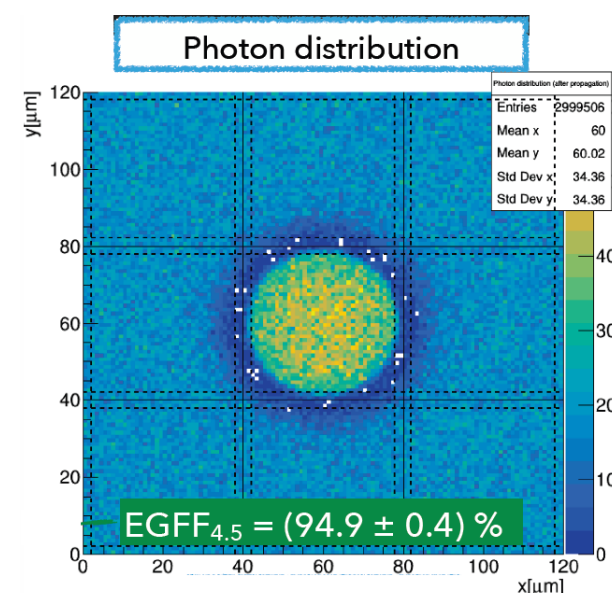
Light concentration Microlenses

Microlenses can be used to *enhance the Fill Factor (FF) and thus the PDE of the SiPM microcells.*

- Exploratory project between FBK and EPFL for LHCb SciFi tracker → Sensitivity-enhanced SiPMs
- Effectiveness *depends on the angular distribution of photons.*



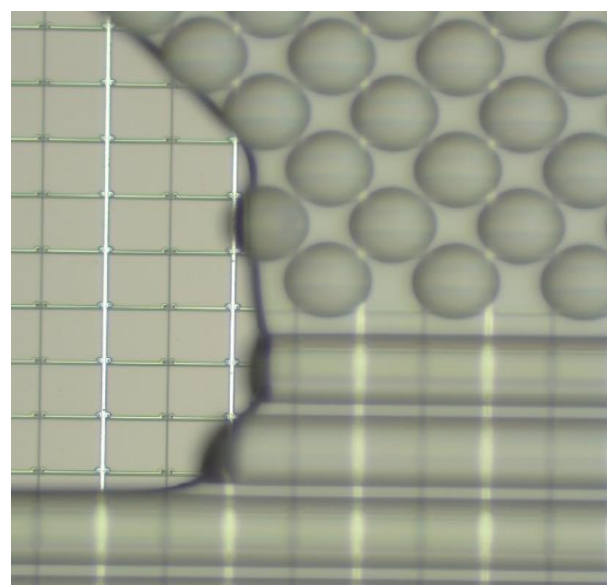
Proposed microlens geometry



95% FF on 40 um SiPM microcells
(80% without microlenses)

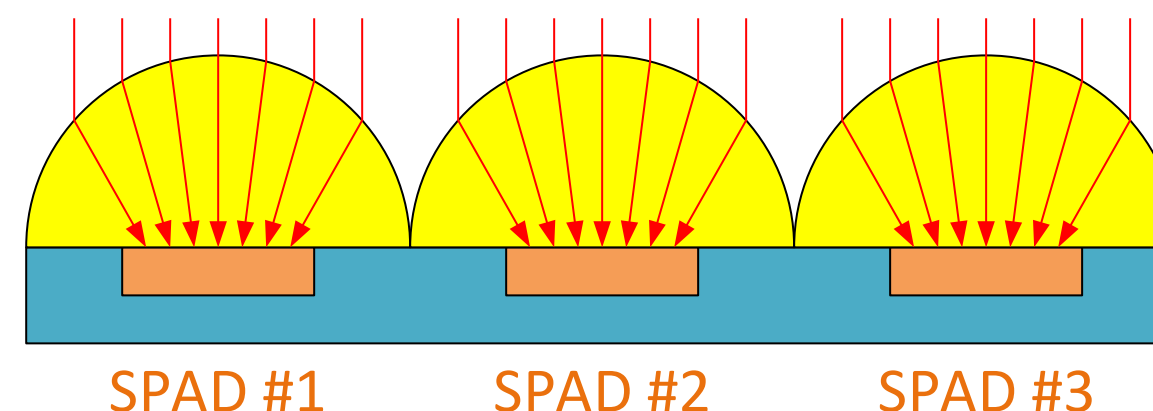
Microlenses to enhance radiation hardness

- Photons can be focused on a much smaller light-sensitive area within each microcell.
- The silicon *area sensitive to radiation damage is reduced.*



23% improvement!

Courtesy of C. Tripll, G. Haefeli
<https://doi.org/10.1016/j.nima.2022.167216>



SiPM

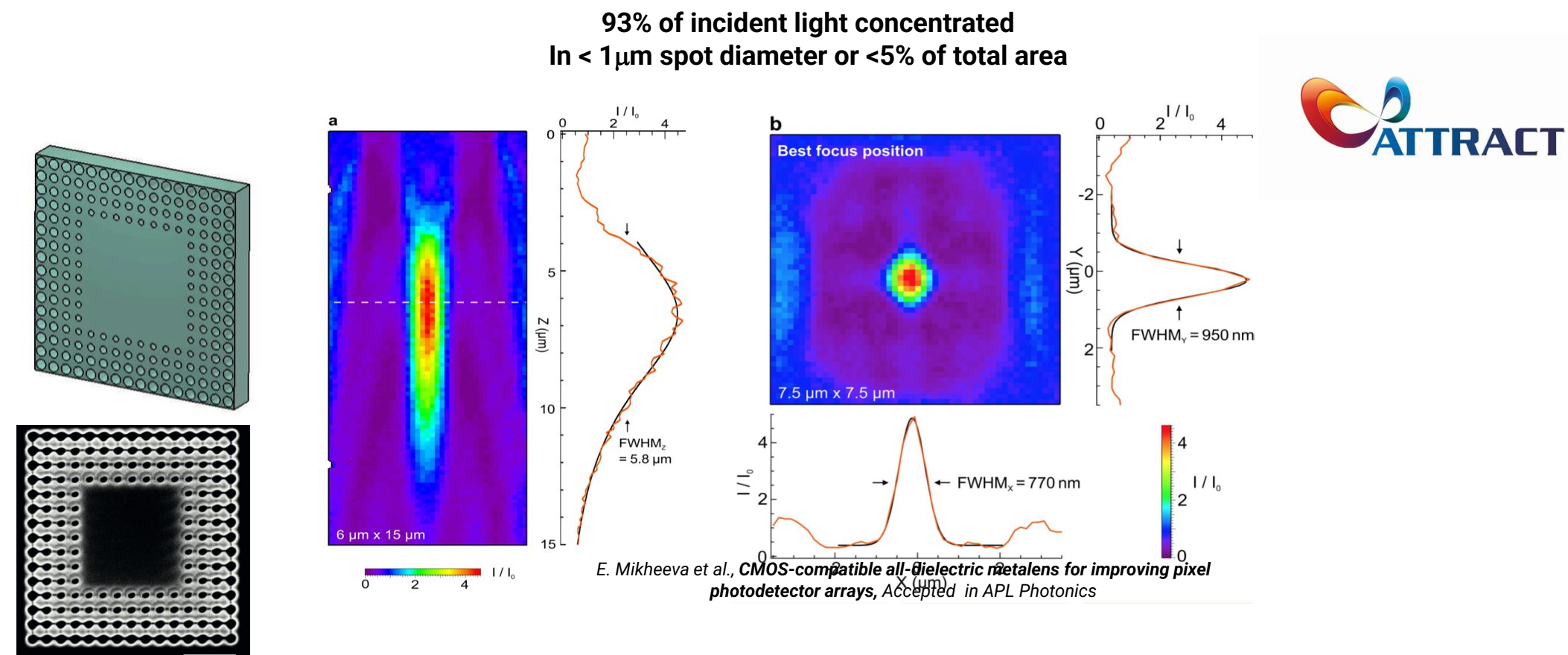
Light concentration Metasurfaces and Metamaterials



FBK investigated the possibility of *using nanophotonics to enhance SiPM performance* in the context of the PHOTOQUANT ATTRACT project.

Metalens-based light concentrators can work similarly to microlenses *to enhance SiPM radiation hardness*.

- Advantages: rad-hard metalens material (TBC), compatibility with CMOS planar processing.



Experimental metalens designed and fabricated 4x4 μ m Nb₂O₅ metalens with refractive index gradient introduced by holes of varying diameter, (joint ATTRACT project CERN, FBK, Institut Fresnel.)



E. Mikheeva et al., *CMOS-compatible all-dielectric metalens for improving pixel photodetector arrays*, Accepted in APL Photonics



Next generation developments: 2.5D and 3D integration



2.5D and 3D Integration

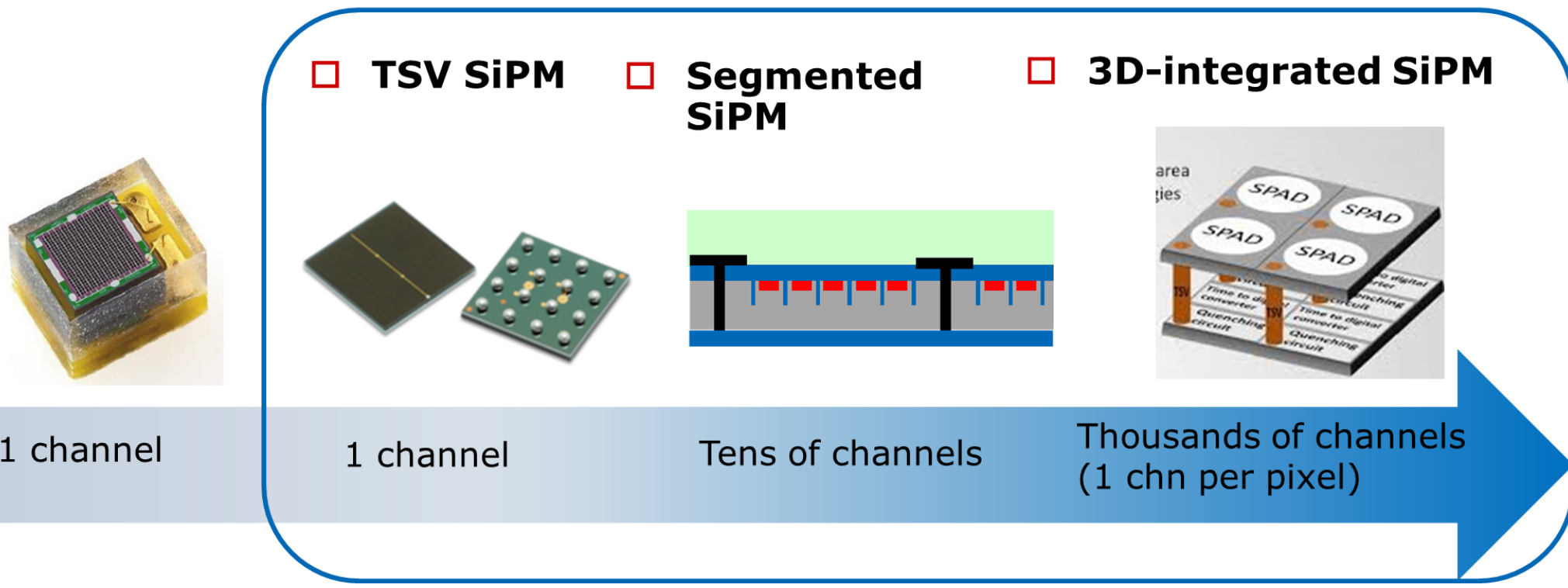
FBK IPCEI clean-room upgrade

FBK is part of the *IPCEI on microelectronics* project (Important Project of Common European Interest - €1.75 billion total public support, 12 M€ to FBK).

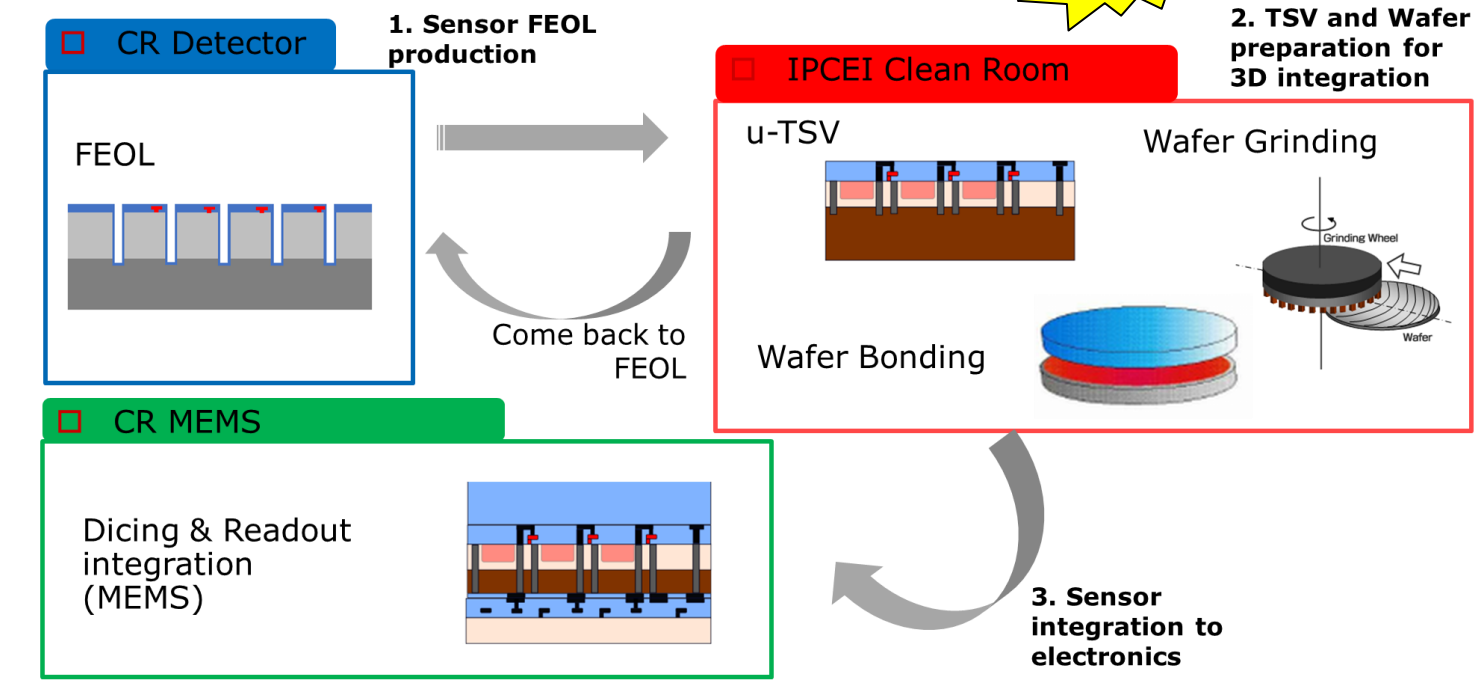
The goal for FBK is upgrading its optical sensors technologies, by *developing TSVs, micro-TSV and Backside Illuminated SiPMs*. This will allow high-density interconnections to the front-end and high-segmentation.

Customized TSVs will be optimized to preserve the NUV-HD electro optical and timing performance.

New clean-room under construction for 3D integration



Range of technologies being developed within IPCEI



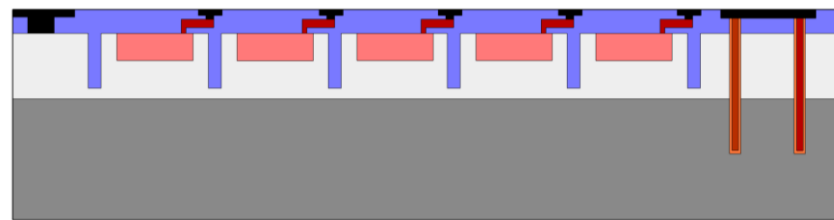
The future system composed of 3 research clean-rooms in FBK.

2.5D and 3D Integration

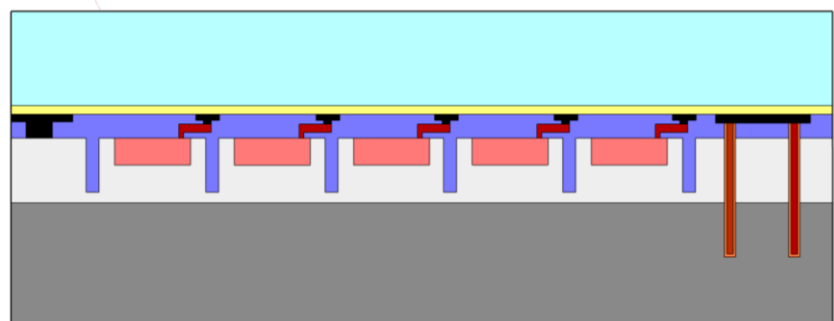
TSV – via mid: process flow

In the via-mid process, the *TSV is formed during the fabrication of the SiPM, modifying its process flow.*

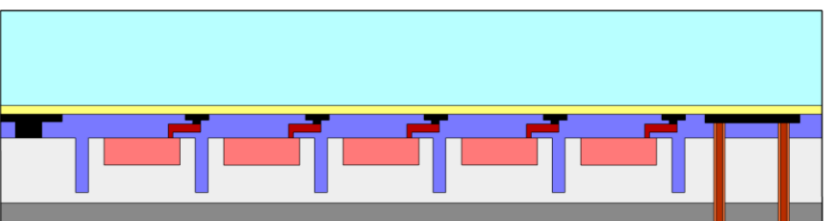
- SiPM fabrication + TSV formation



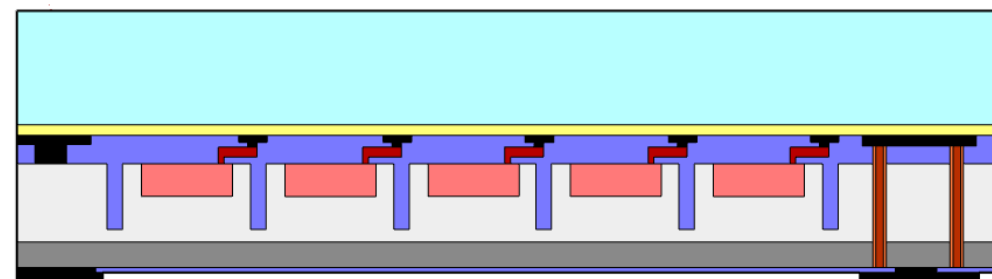
- Edge Trimming + BONDING



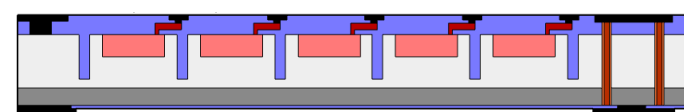
- THINNING



- Contacts formation



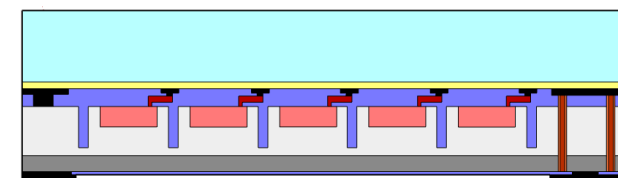
- DEBONDING



Thickness at least 150 μm

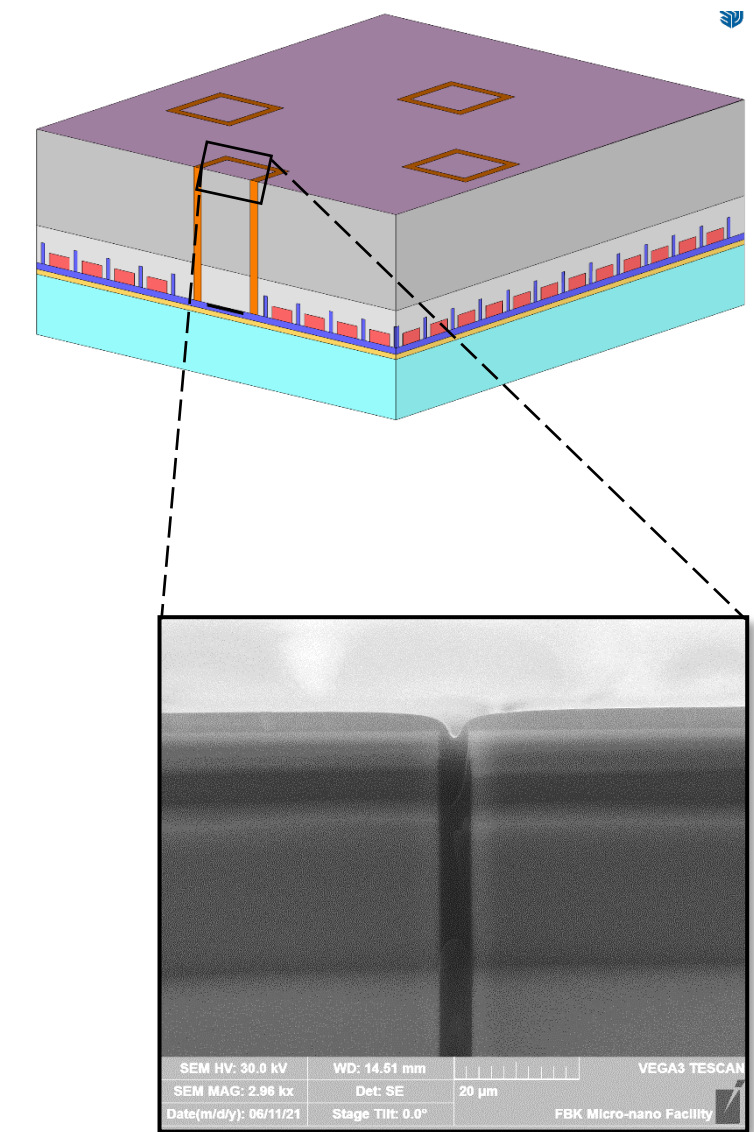
Glass-less TSV
concept
500 μm SiPM pitch

- NO-DEBONDING



Thickness 10-50 μm

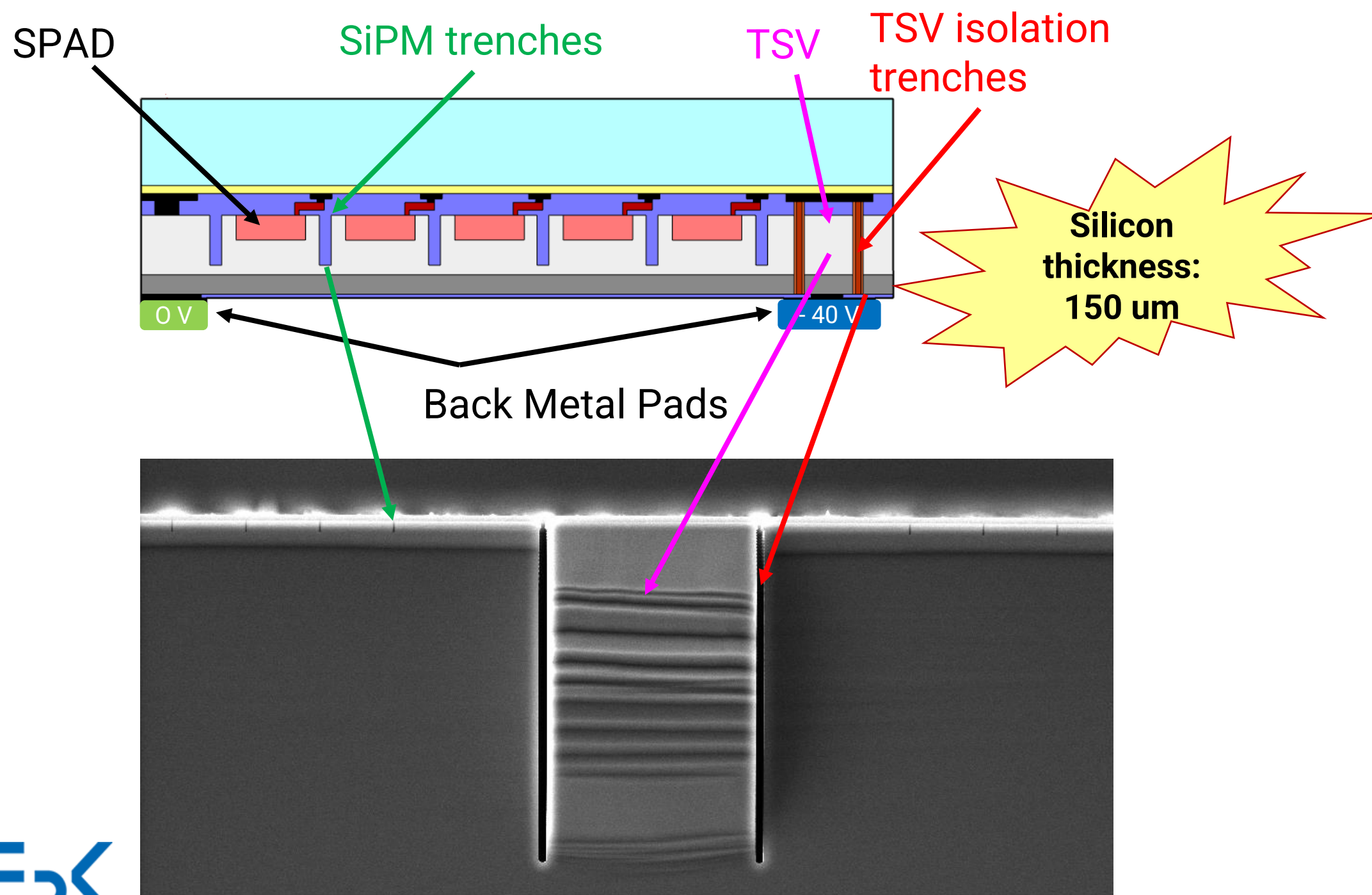
Standard TSV
microTSV
< 50 μm SPAD pitch



2.5D and 3D Integration

TSV – via mid: first results

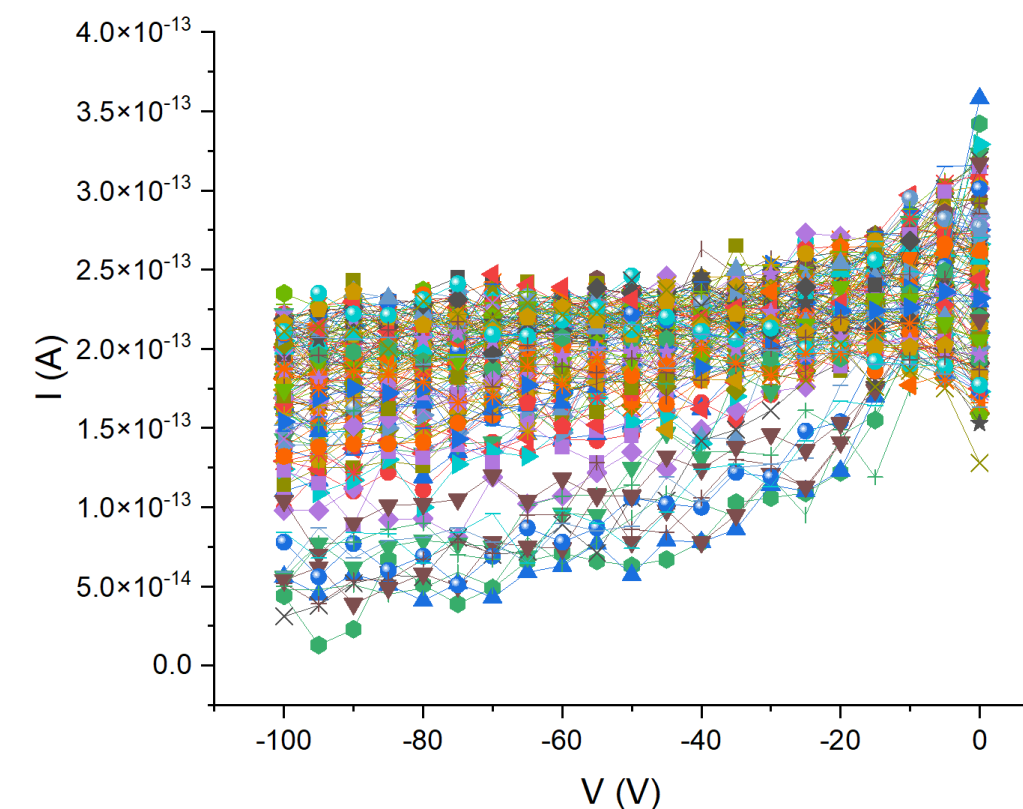
Preliminary results on TSV via-mid development, with partial SiPM process, to *check isolation and continuity* (no Geiger-mode multiplication).



At **-100 V** of bias applied the intensity varies from **30 to 200 fA**



Trough Silicon Vias – Via Mid are isolated from the bulk silicon contact

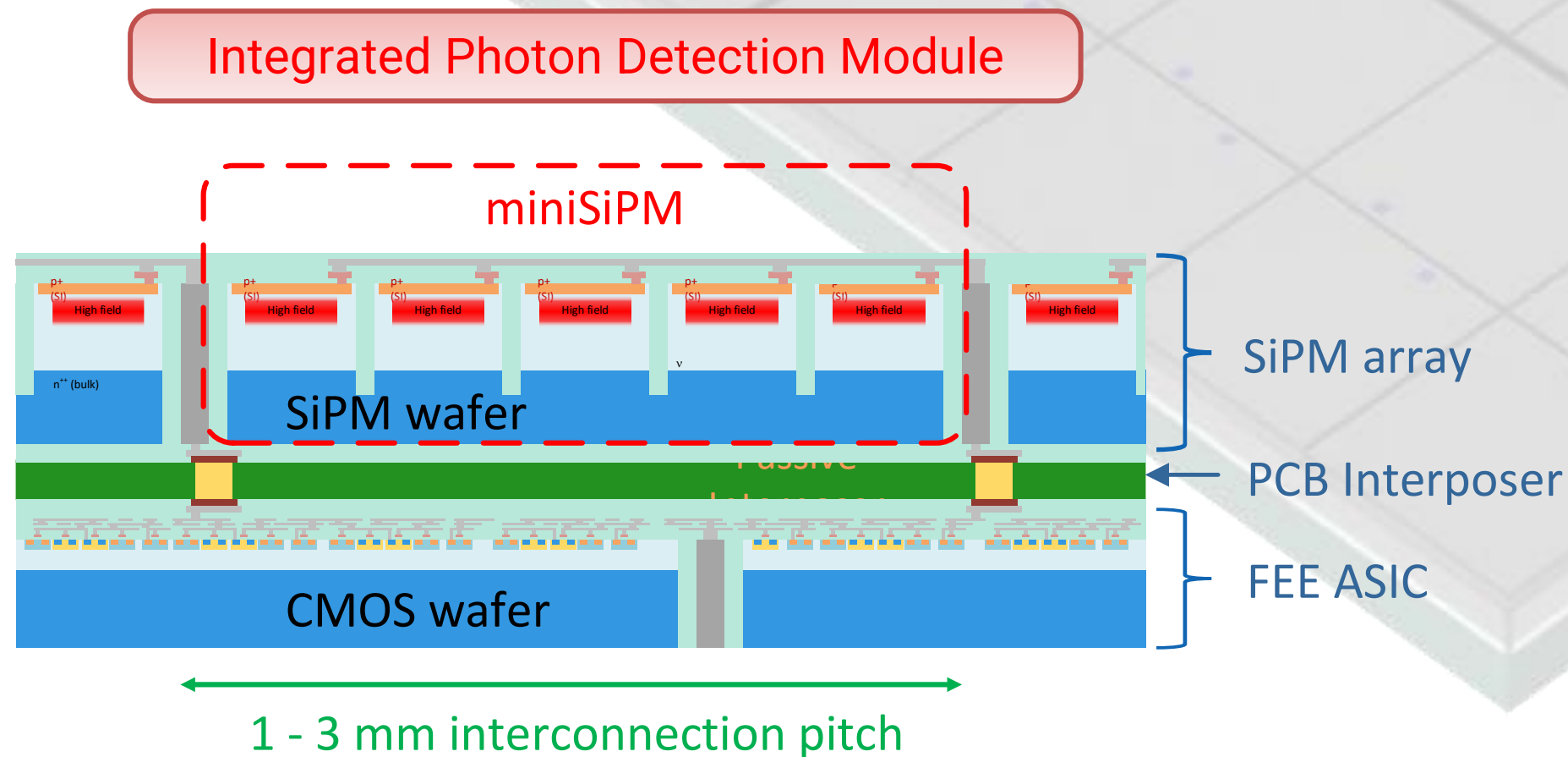


2.5D and 3D Integration

2.5D integrated SiPM tile

In the *short and medium term*, medium density interconnection seems the sweet spot to obtain *excellent performance (e.g. timing) on large photosensitive areas while not increasing complexity and cost too much*.

We propose a Photon Detection Module (PDM) in which *SiPMs with TSVs down to 1 mm pitch* are connected to the *readout ASIC on the opposite side of a passive interposer*, in a *2.5D integration scheme*.



Core partners:



Jožef Stefan Institute



MASSACHUSETTS
GENERAL HOSPITAL



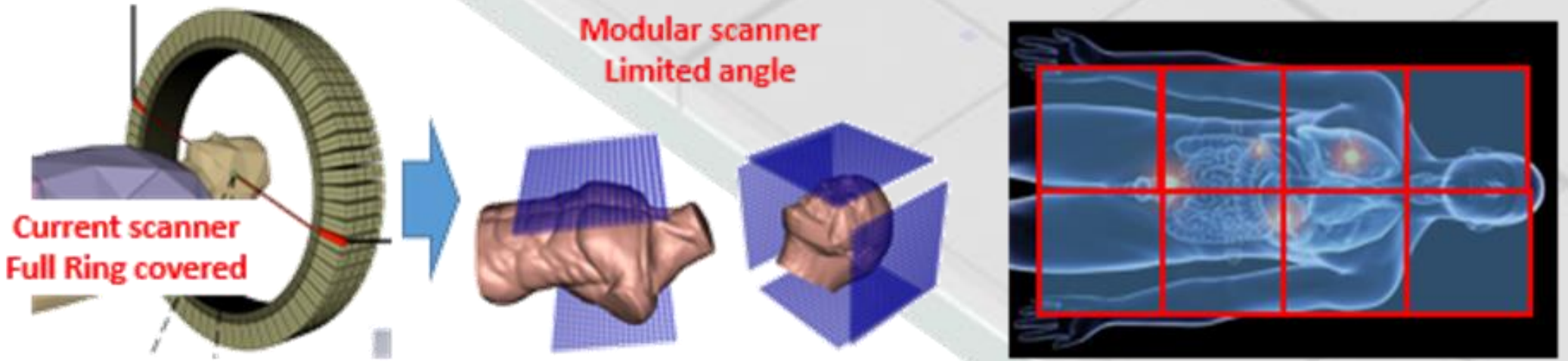
Hybrid SiPM module being developed for ultimate timing performance in ToF-PET

2.5D and 3D Integration

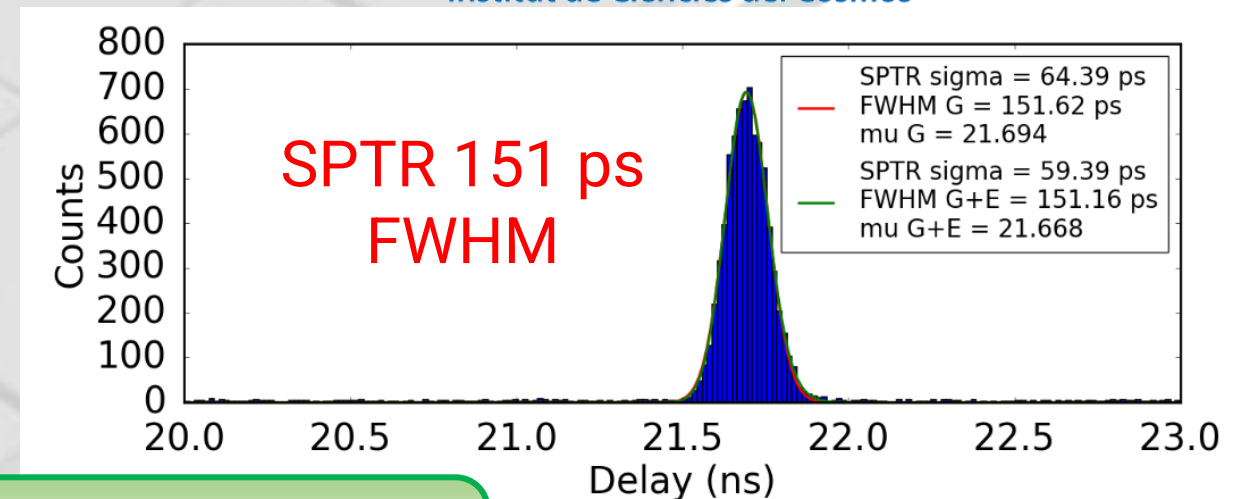
2.5D integrated SiPM tile for timing

The 2.5D integrated PDM (50x50 mm²) will be the basis of a *30x30 cm² ToF-PET panel*, which will be used to build limited-angle ToF-PET systems, for brain PET, Cardiac PET and full-body scanners.

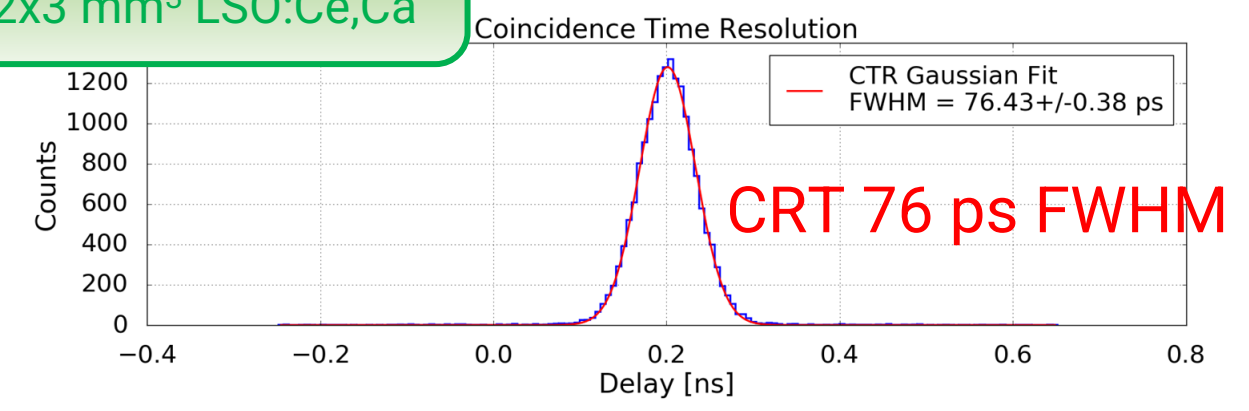
We *expect very good timing performance*, supported by preliminary measurements achieved with NUV-HD SiPMs coupled to FastIC ASIC.



Application of the PDM to build large panes used in new, limited-angle PET applications: Brain Pet, Cardiac PET, whole-body PET

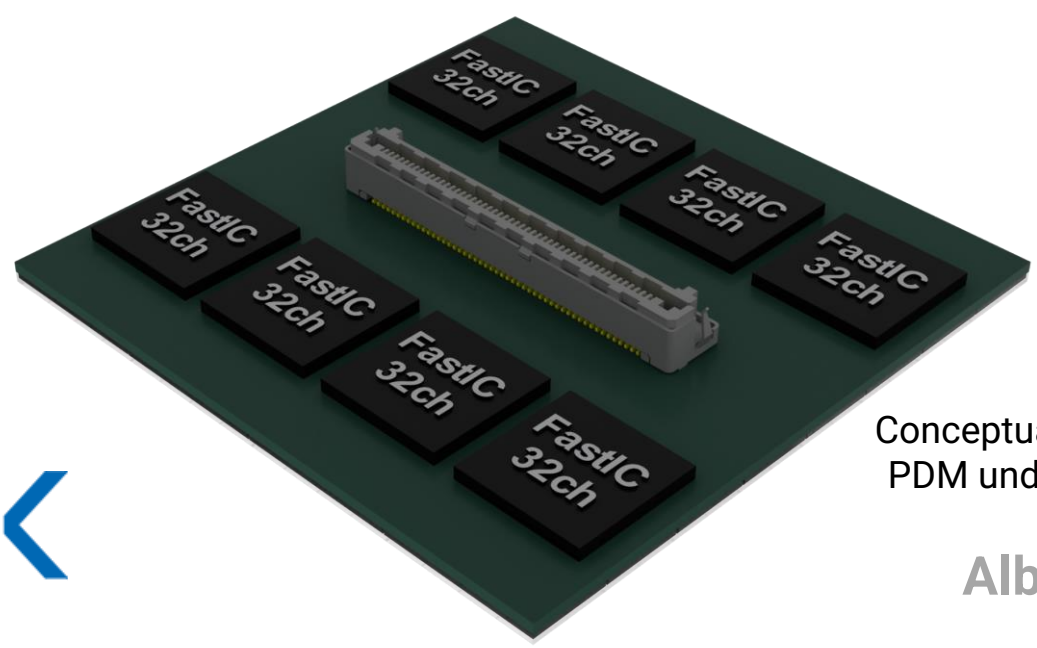


2x2x3 mm³ LSO:Ce,Ca

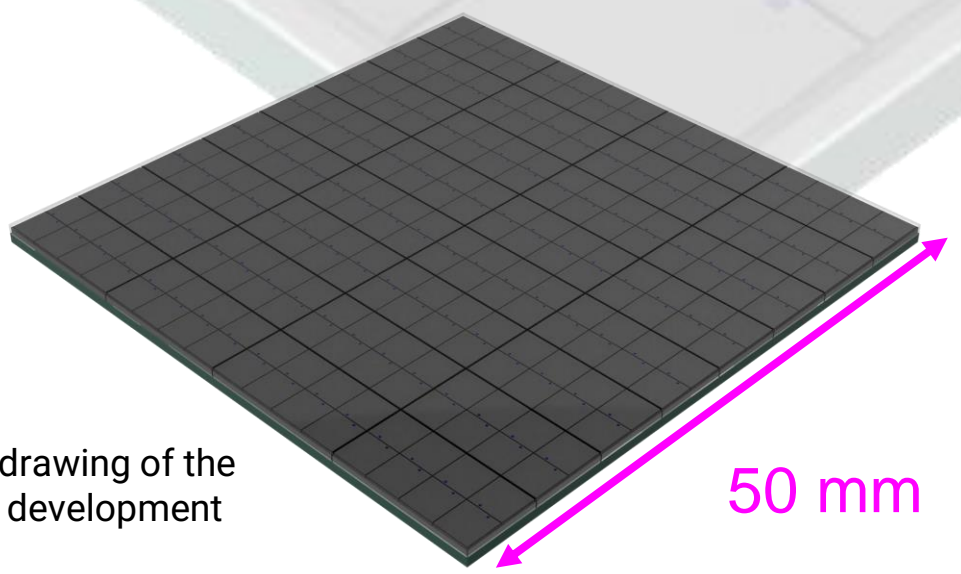


SPTR and CRT measured at FBK NUV-HD-SiPMs read by the FastIC ASIC developed by ICCUB.

Sensor: NUV-HD-LFv2 SiPMs, 3x3 mm²
Scintillator: 2x2x3 mm³ LSO:Ce,Ca
Power consumption: 3 mW / channel



Conceptual drawing of the PDM under development

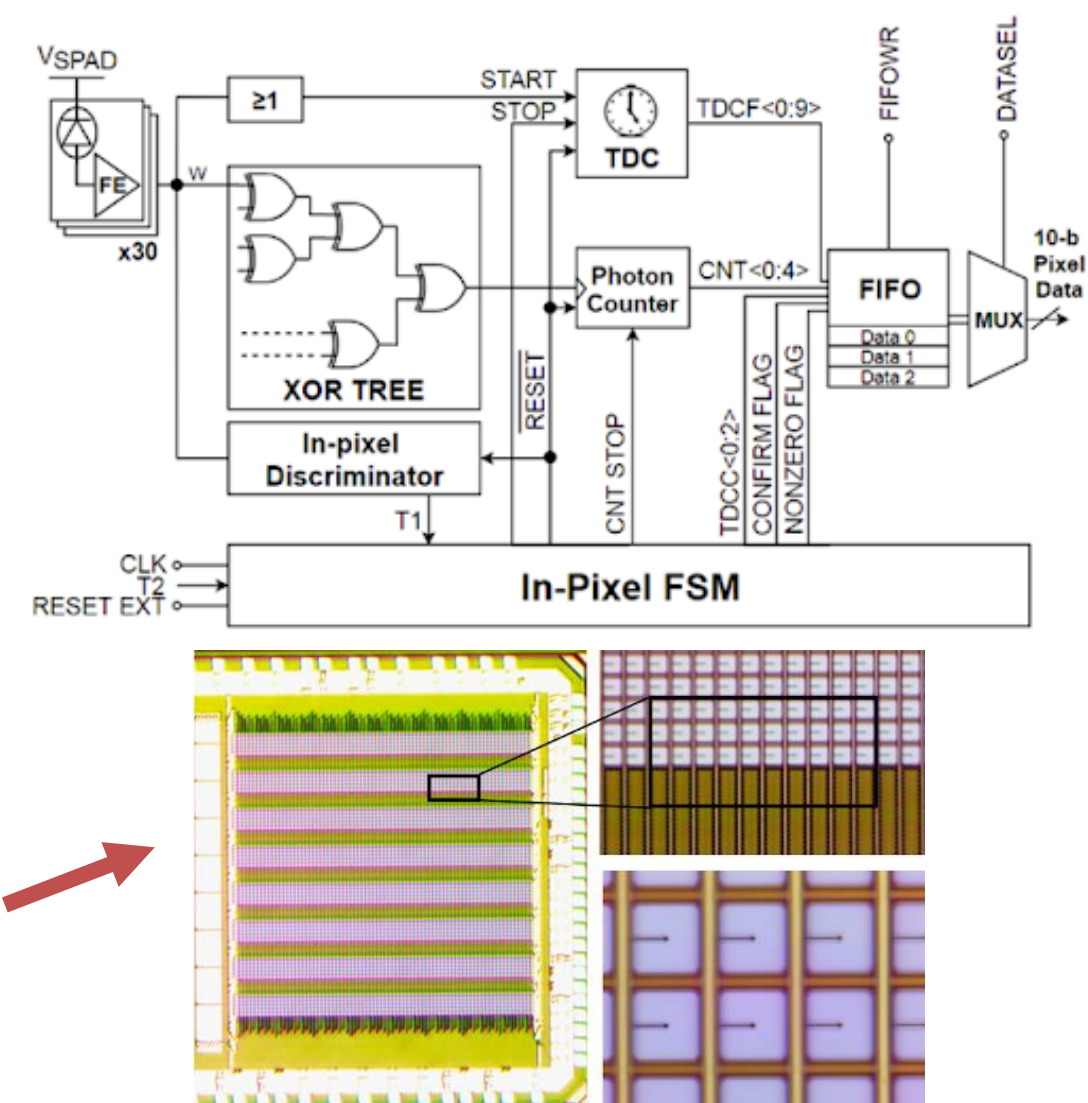
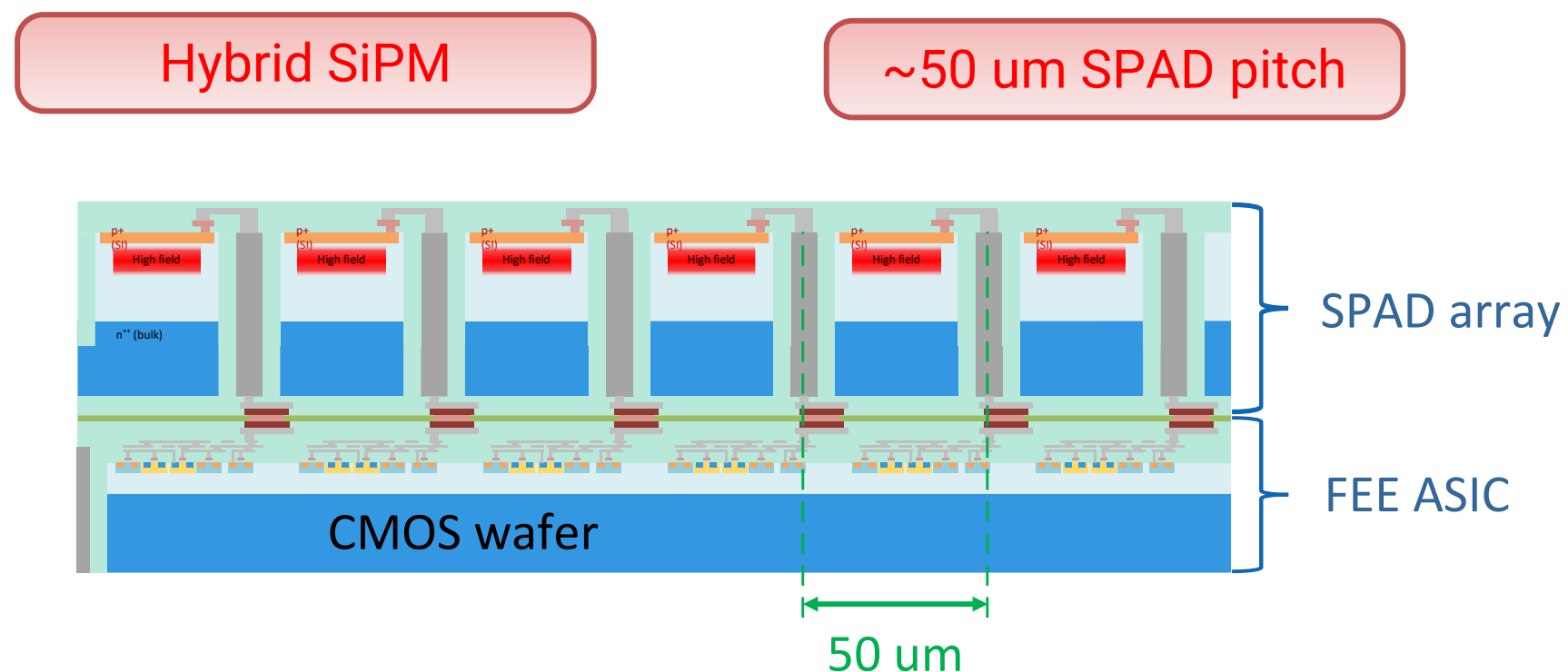
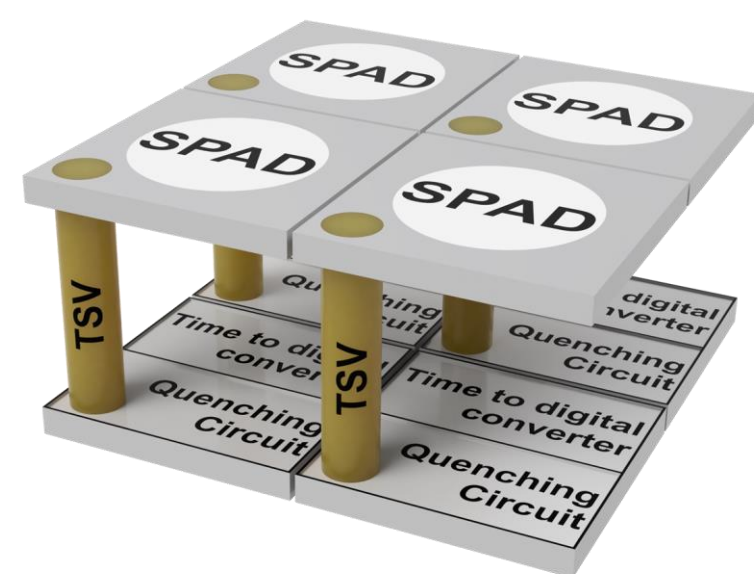


50 mm

2.5D and 3D Integration

Full 3D integration with micro TSVs: Hybrid SiPM

FBK is investigating the potential of microTSVs to achieve *single cell connection*. While complexity of the system increases, it might provide *ultimate timing performance*.



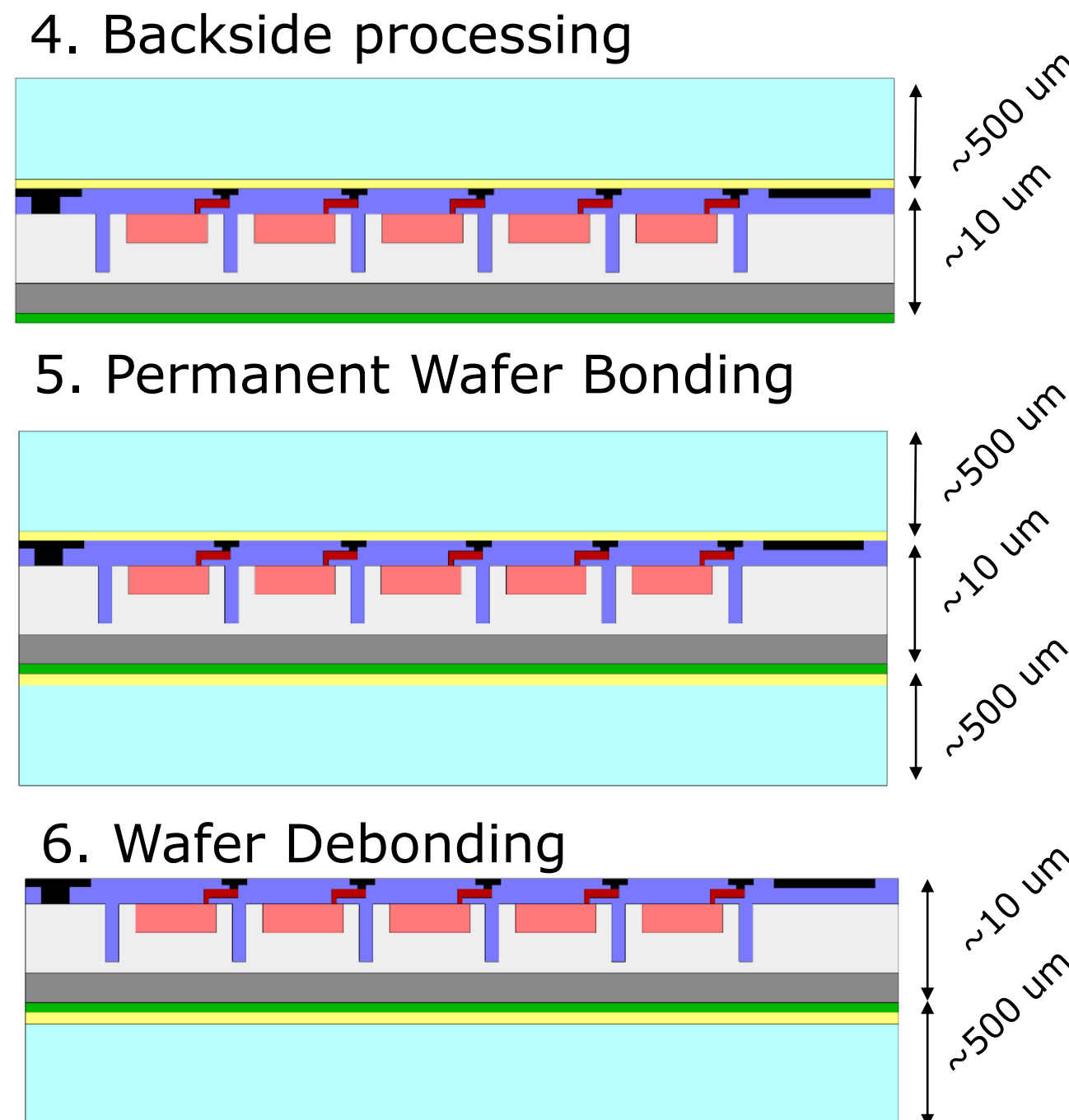
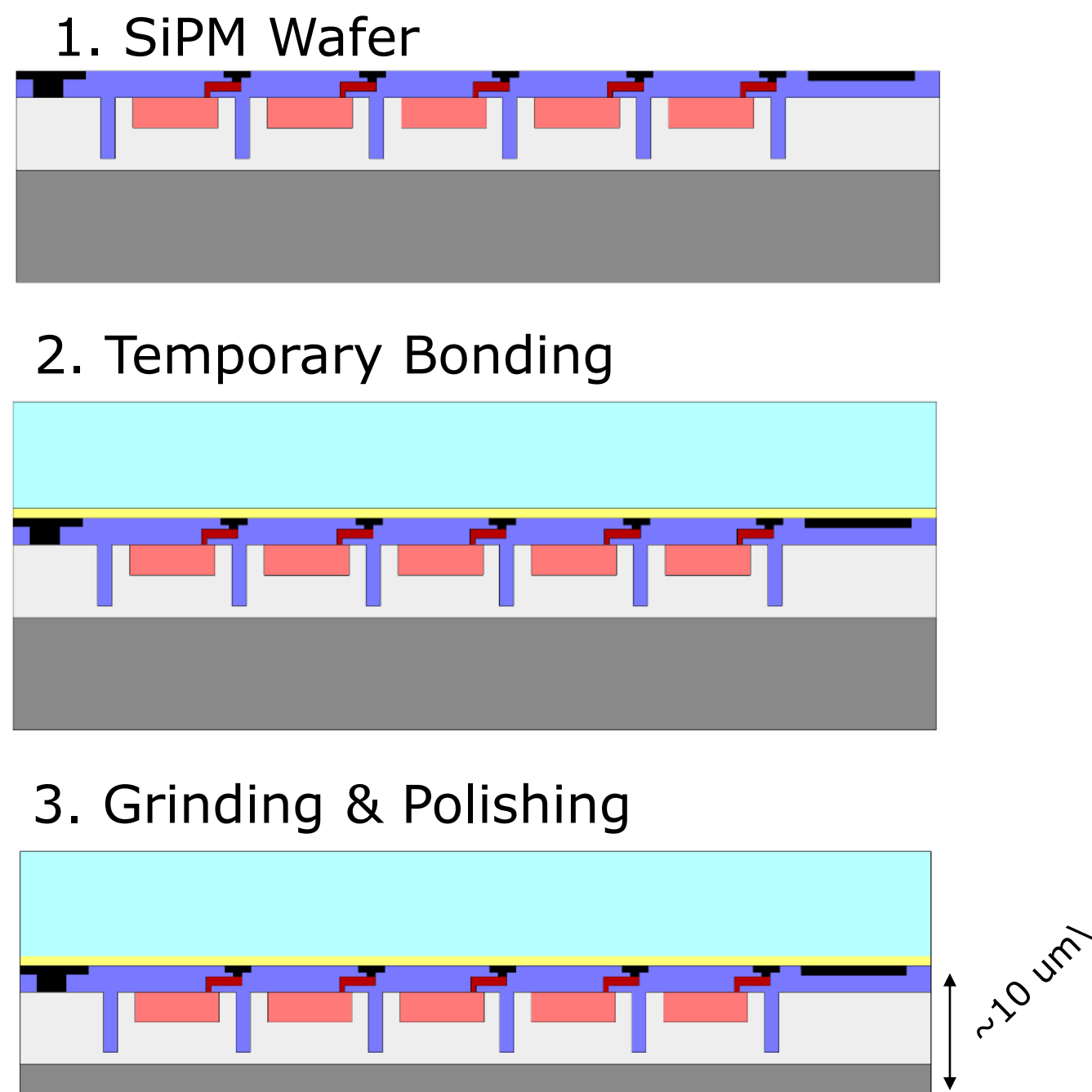
- FBK can apply all the *know-how on system architecture* already developed in the field of digital SiPMs.
- Finally solve the duality between analog and digital SiPM: *Hybrid SiPM concept* → get the best of both worlds.

Example of dSiPM architecture developed at FBK (SBAM project)

2.5D and 3D Integration

Backside Illuminated SiPMs: process flow

BSI development started on *NIR-sensitive SiPMs* → *no need to create a new entrance window* on the backside with high efficiency in the NUV.



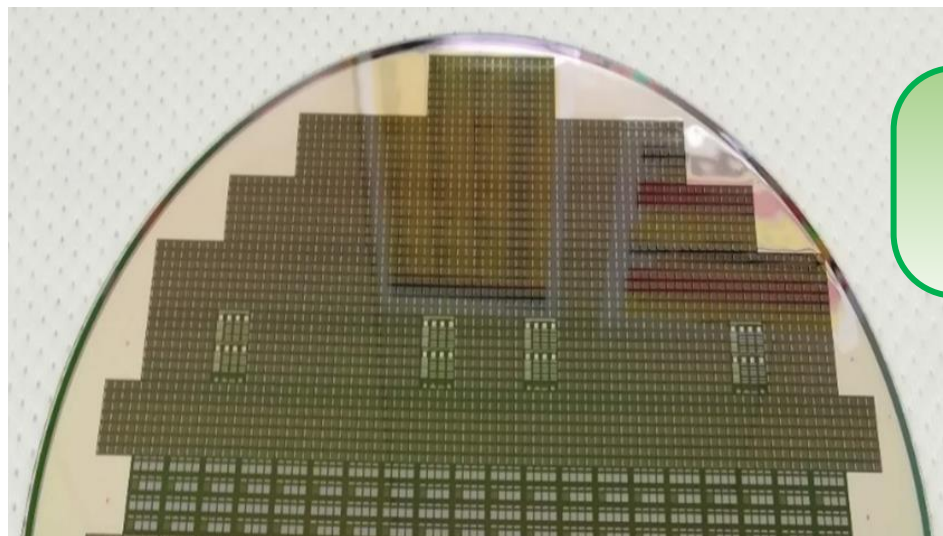
2.5D and 3D Integration

BSI NIR SiPMs: first results

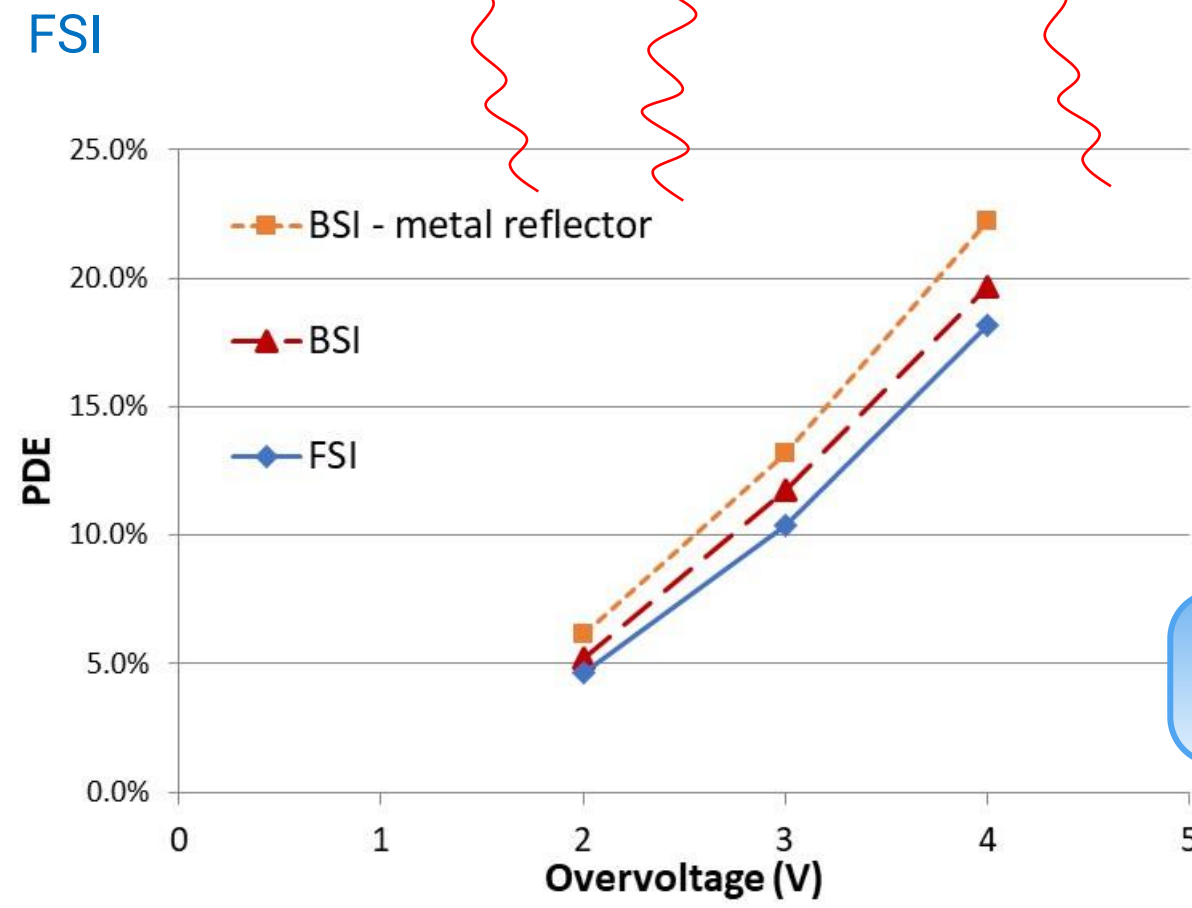
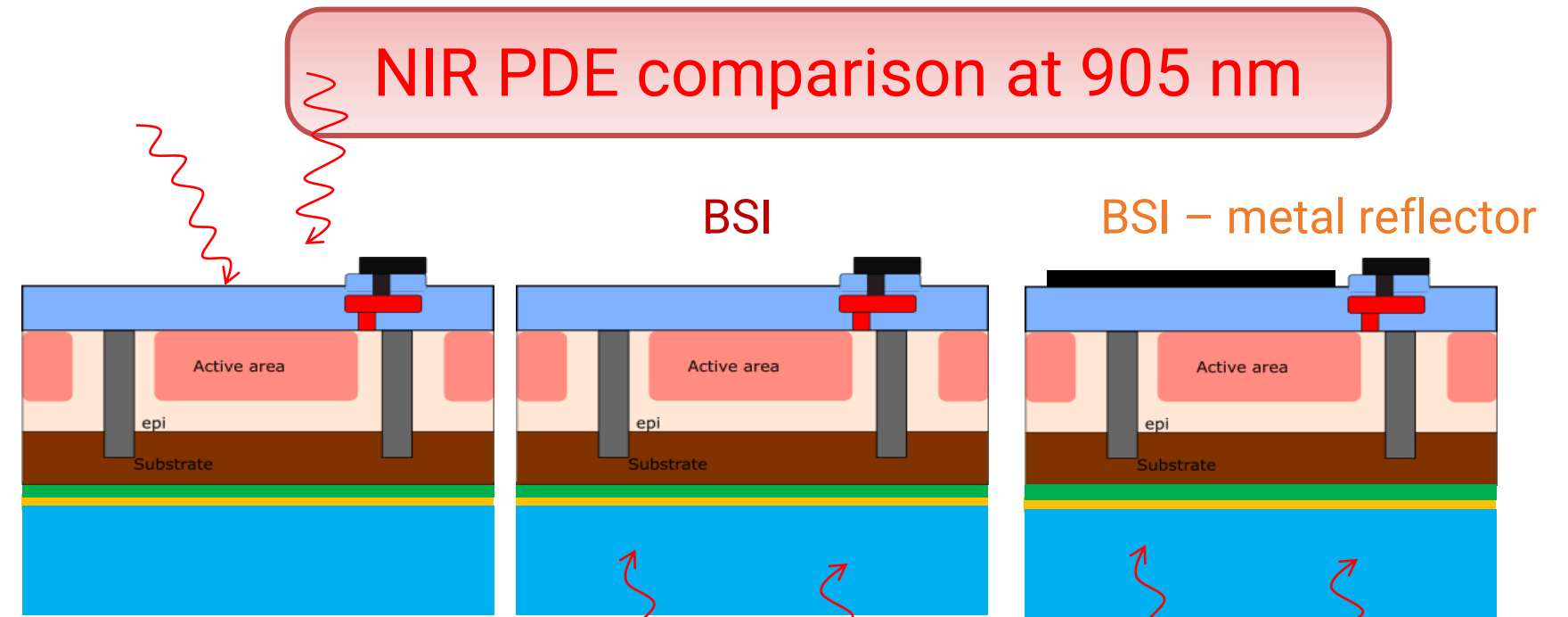
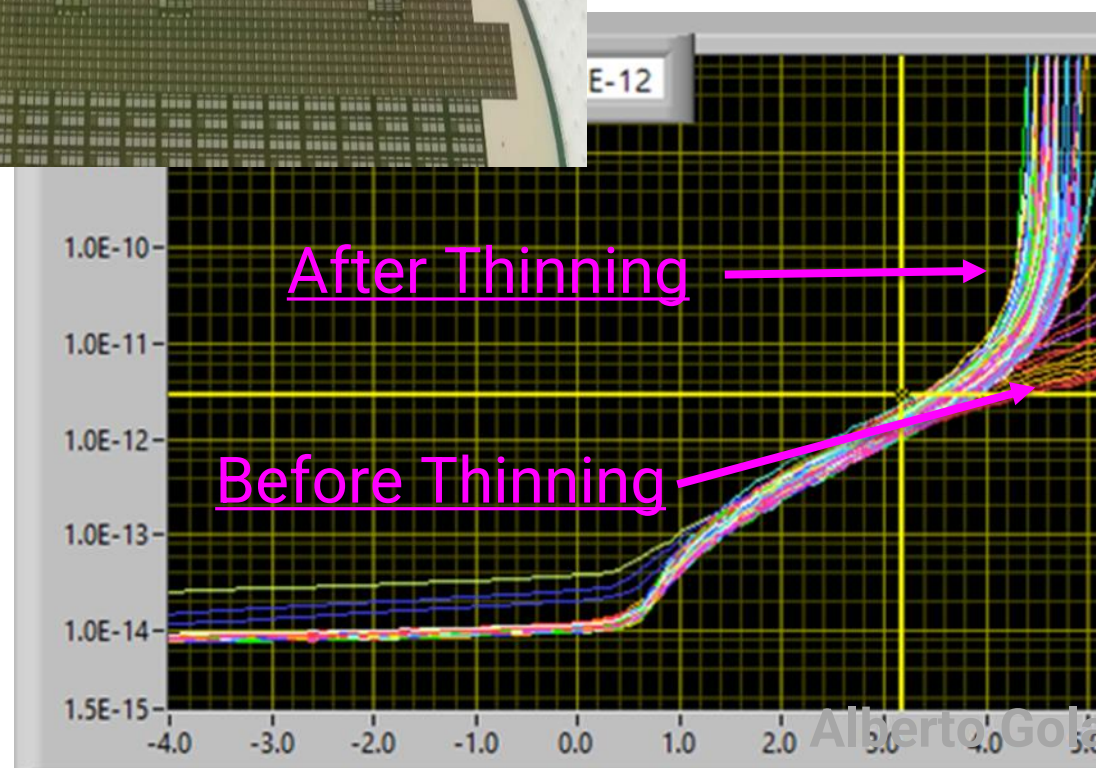
The *first NIR-sensitive BSI wafers were fabricated* in FBK clean room (1x1 mm² devices).

Minor differences in the IVs after thinning, compared to the FSI devices (without thinning).

Ultrathin substrate (~ 10 μm)



NIR BSI process is working!



Recharge time < 10 ns

2.5D and 3D Integration

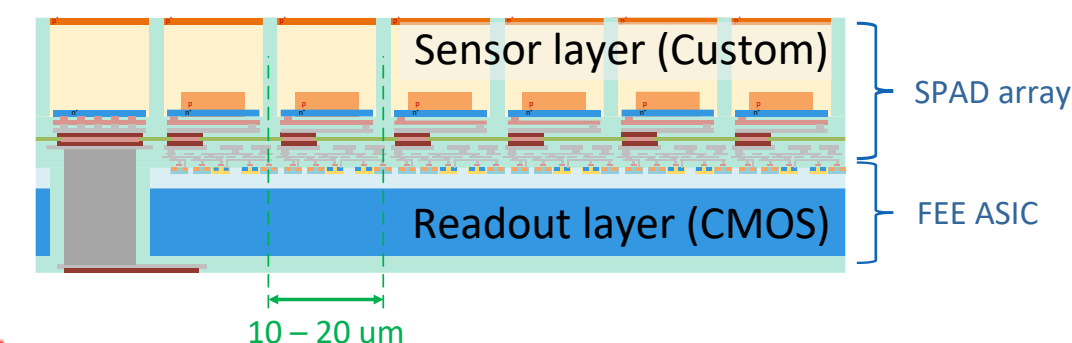
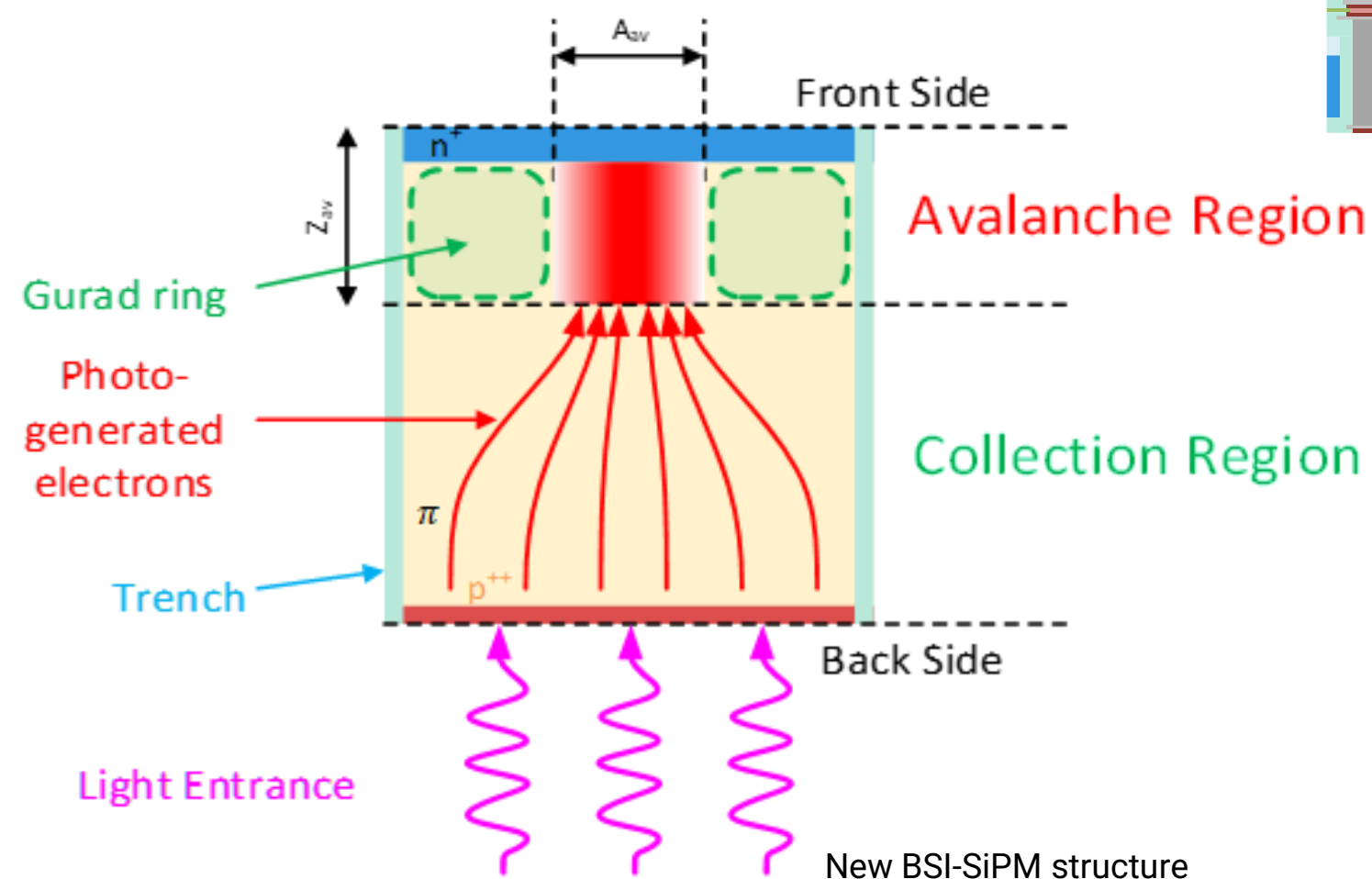
Next-generation development: Backside Illuminated SiPMs

The next-generation of developments, currently being investigated at FBK, is building a *backside-illuminated, NUV-sensitive SiPM*. Several technological challenges should be overcome.

Clear *separation between charge collection and multiplication regions*.

Potential Advantages:

- Up to 100% FF even with small cell pitch
- Ultimate Interconnection density: < 15 μm
- High speed and dynamic range
- Low gain and external crosstalk
- (Uniform) entrance window on the backside, ideal for enhanced optical stack (VUV sensitivity, nanophotonics)
- Local electronics: ultra fast and possibly low-power.



Development Risks:

- Charge collection time jitter
- Low Gain \rightarrow SPTR?
- Effectiveness of the new entrance window

Radiation hardness:

- The SiPM area sensitive to radiation damage, is much smaller than the light sensitive area
- **Assumption**: the main source of DCR is field-enhanced generation (or tunneling).



Thank you!

Thanks to all the members of the team working on custom SiPM technology at FBK:

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